

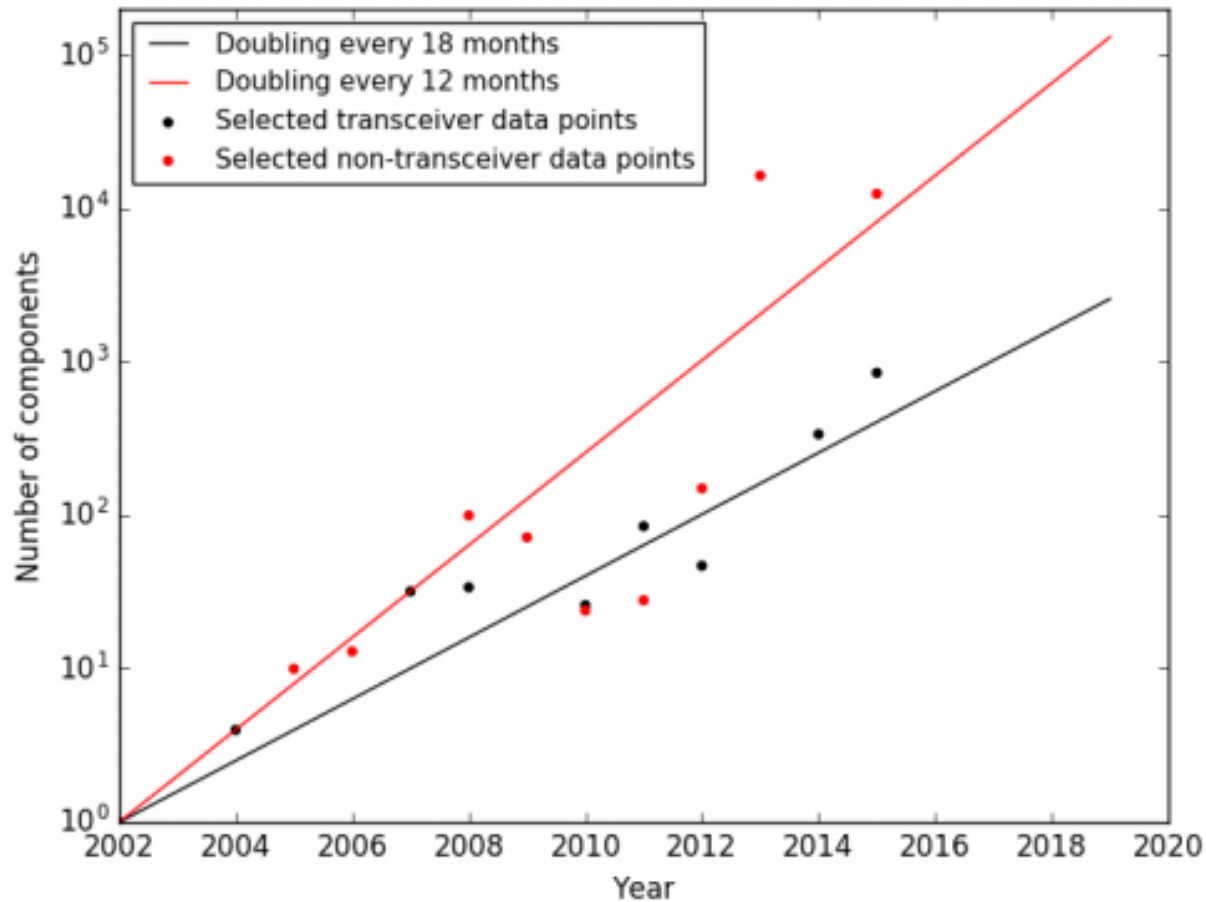
NOVEL DEGREES OF FREEDOM FOR DESIGN OF SILICON MICRORINGS

Candidate: Ang Li

Promotor: Prof. Wim Bogaerts

BACKGROUND

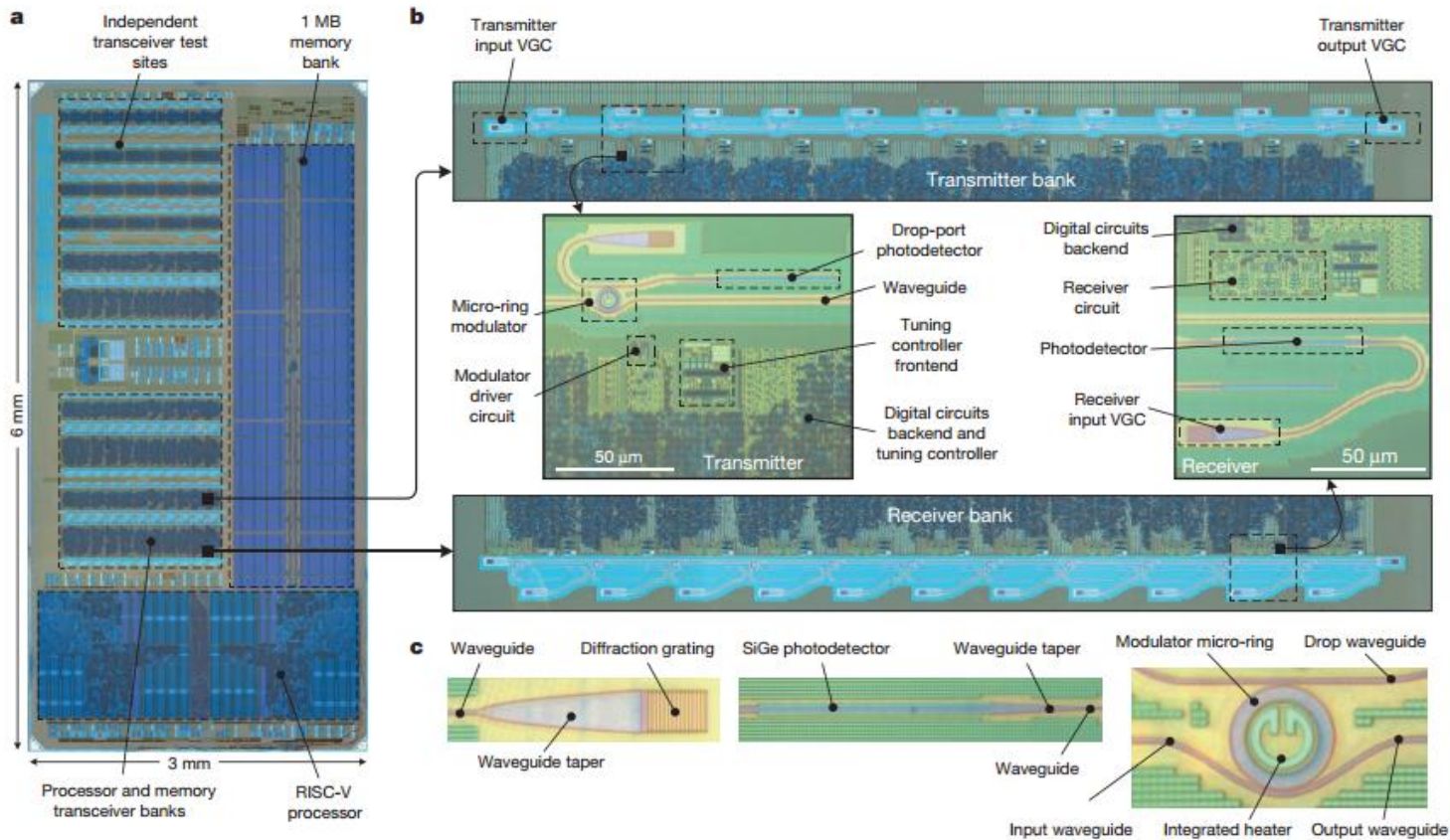
- At the stage of maturation of silicon photonics



A. Khanna, OFC, Th1B.3, 2017

BACKGROUND

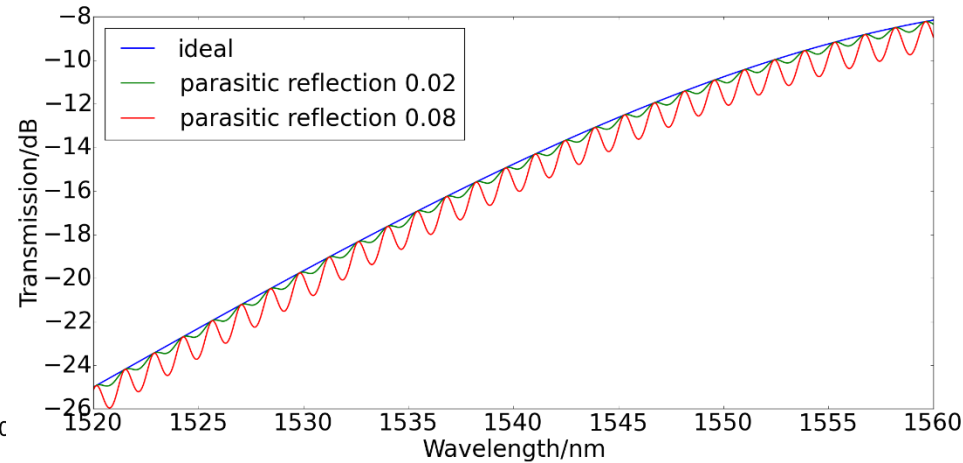
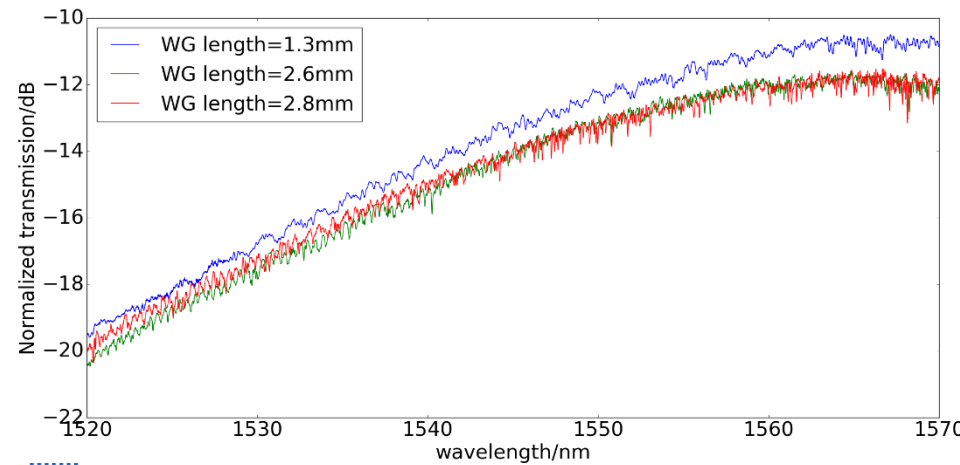
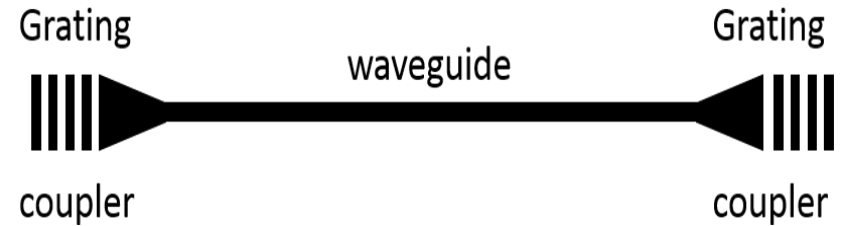
- Large scale PICs around corner
- State of the art silicon PIC contains >1000 optical components



C. Sun, Nature volume 528, pages 534–538, 2015

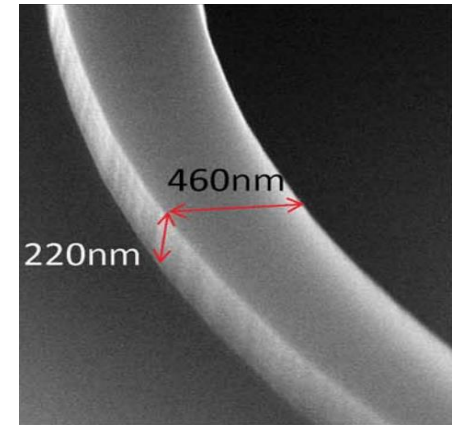
PARASITICS IN SILICON PIC

- Emerging issues
 - Variability
 - **Parasitics**
 - Unwanted effects
 - Substrate coupling, radiations, reflections etc.
 - Severe in high integration density

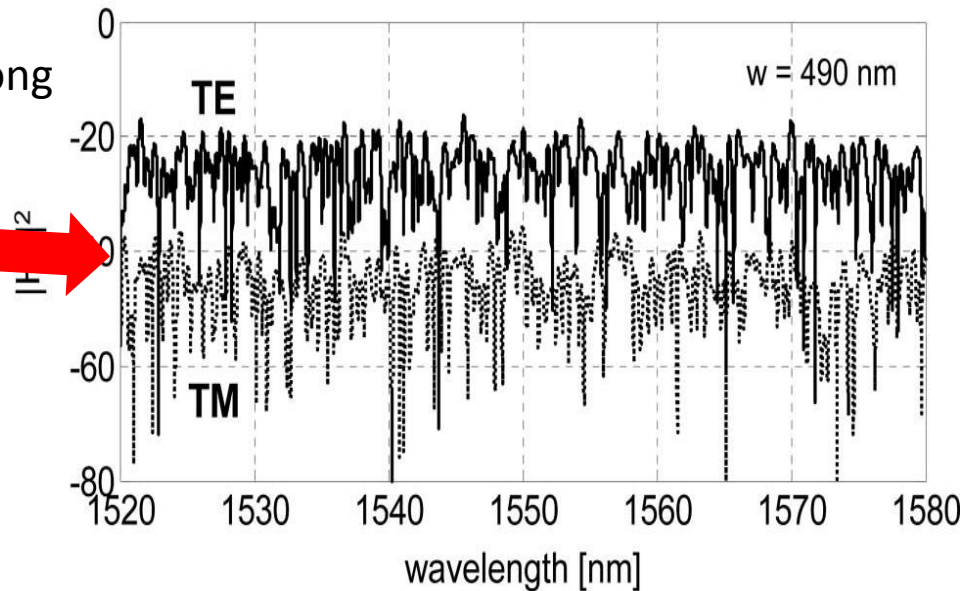


BACKSCATTERING IN SILICON WAVEGUIDE

- Roughness
 - Lithography and etching leads to sidewall roughness
 - loss and backscattering

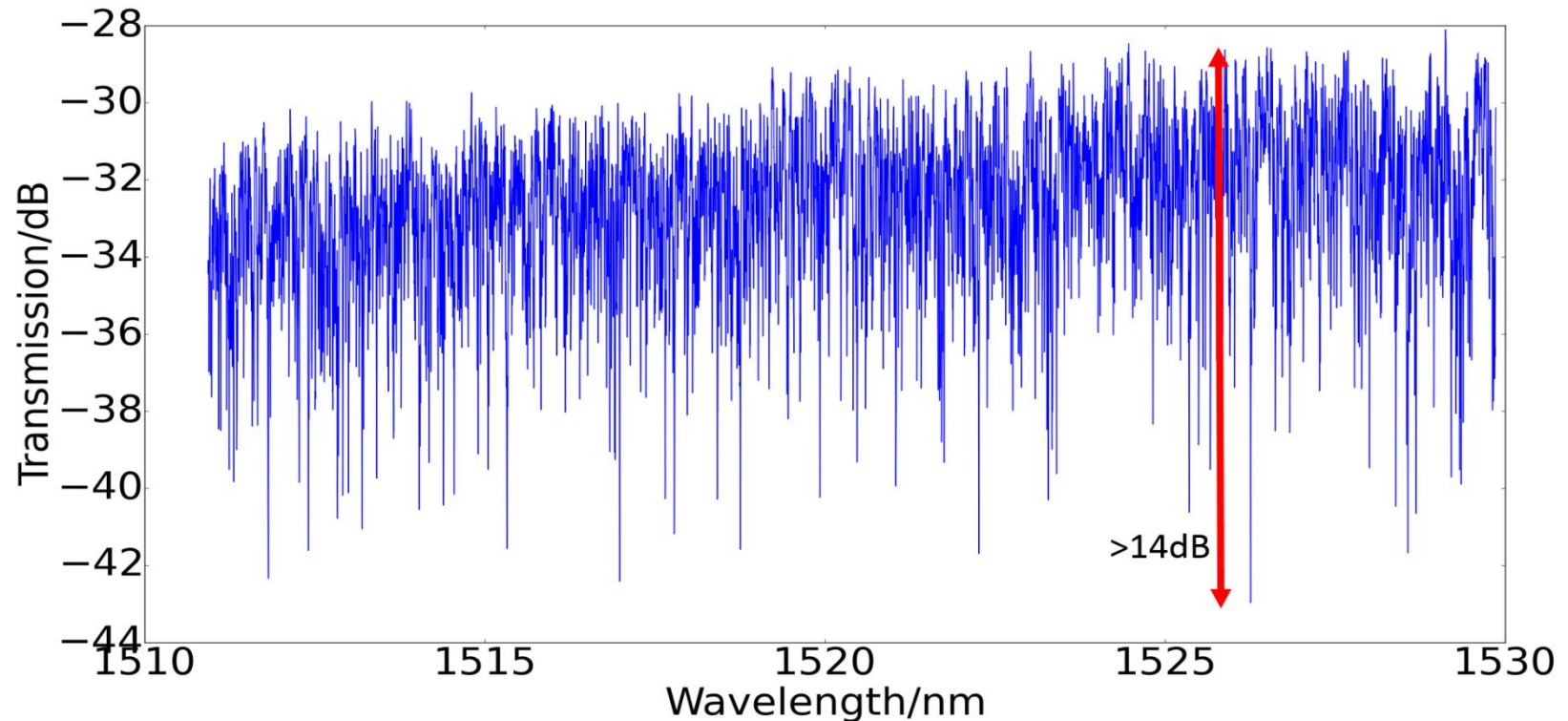


- Backscattering
 - Numerous distributed reflections along propagation
 - Induce stochastic reflections
 - also influence transmission



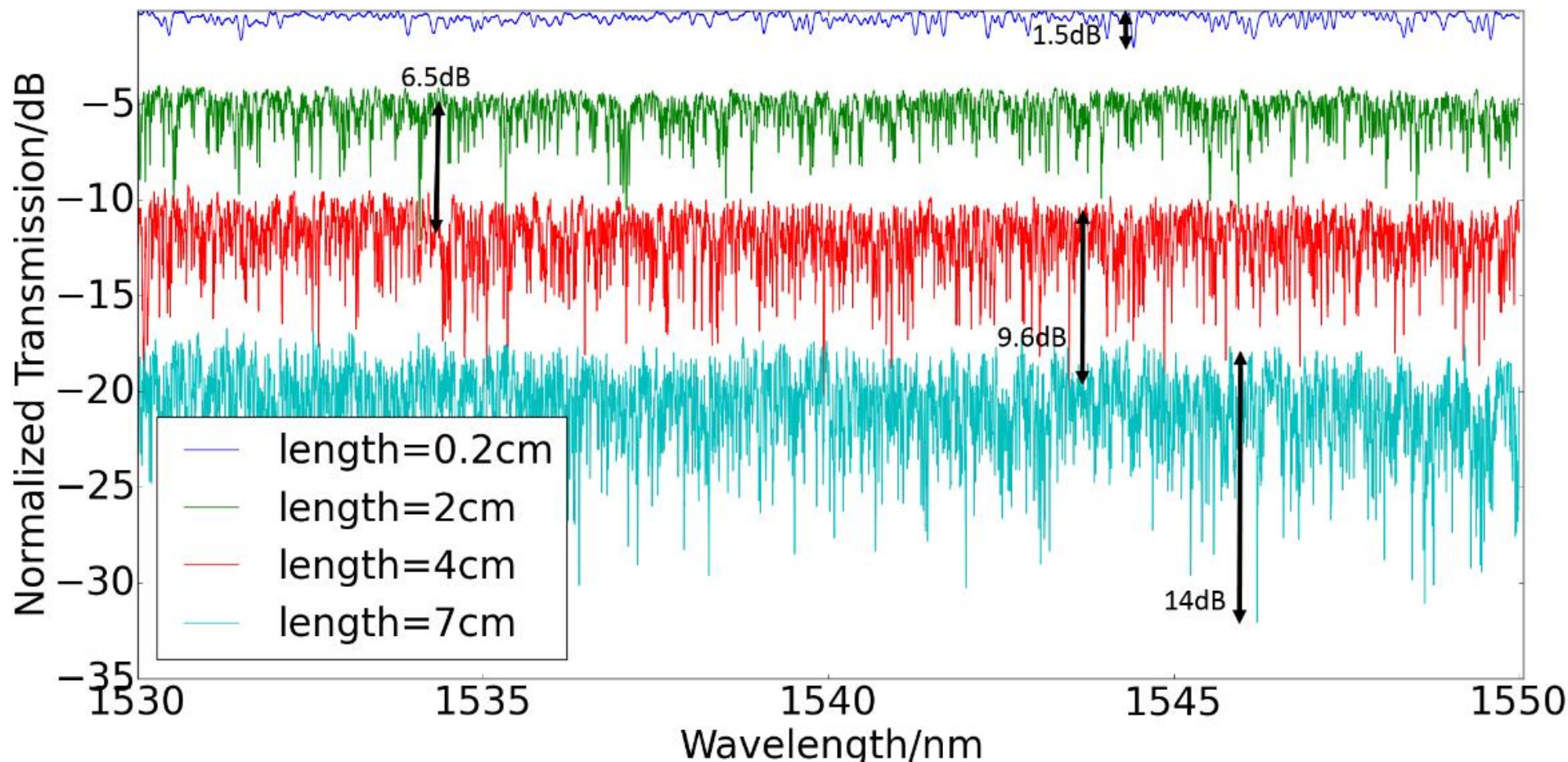
BACKSCATTERING IN SILICON WAVEGUIDE

- Fluctuations in transmission spectral
 - Unacceptable for sensors, reservoir computing, chip scale interconnect etc.



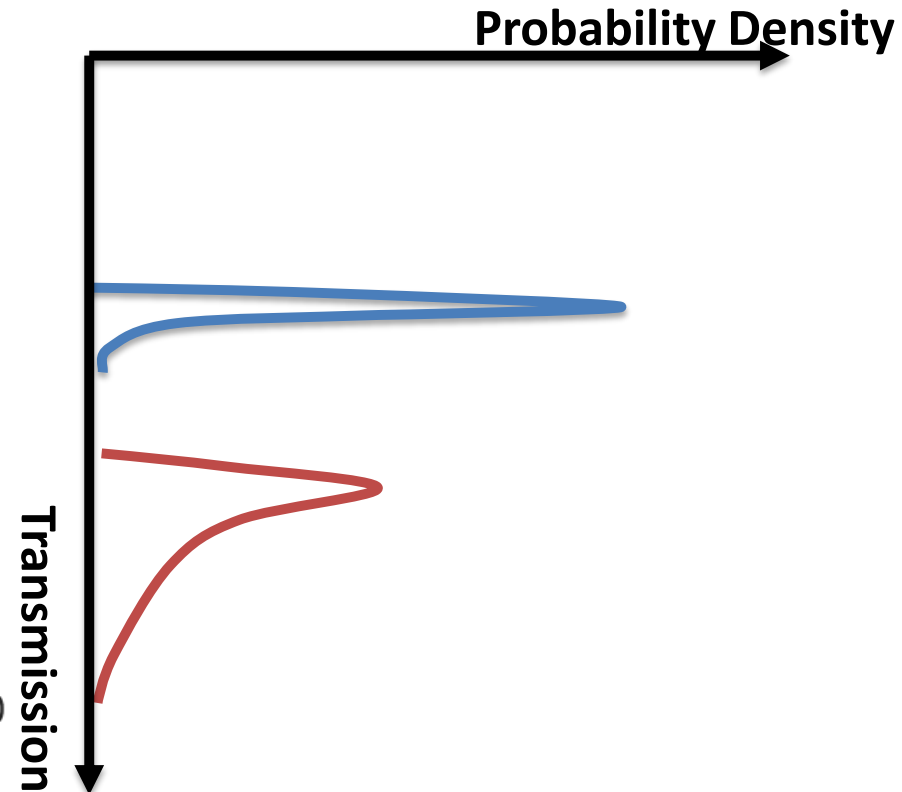
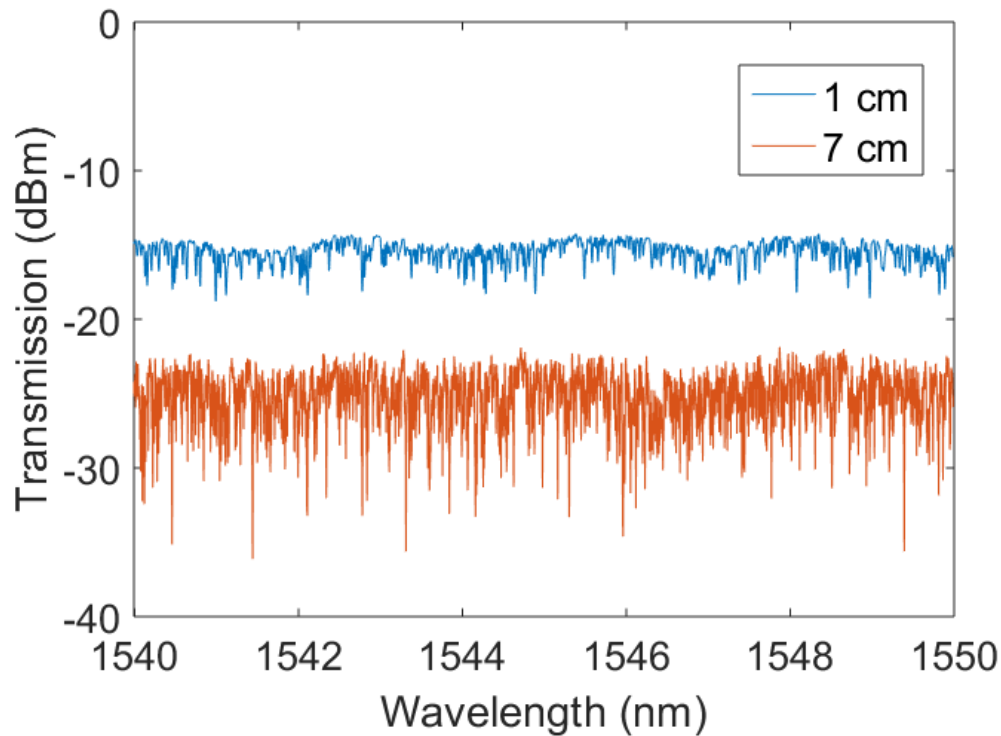
BACKSCATTERING IN SILICON WAVEGUIDE

- Fluctuations in transmission spectral
 - Appears universally in air-clad strip WG
 - Waveguide length dependent



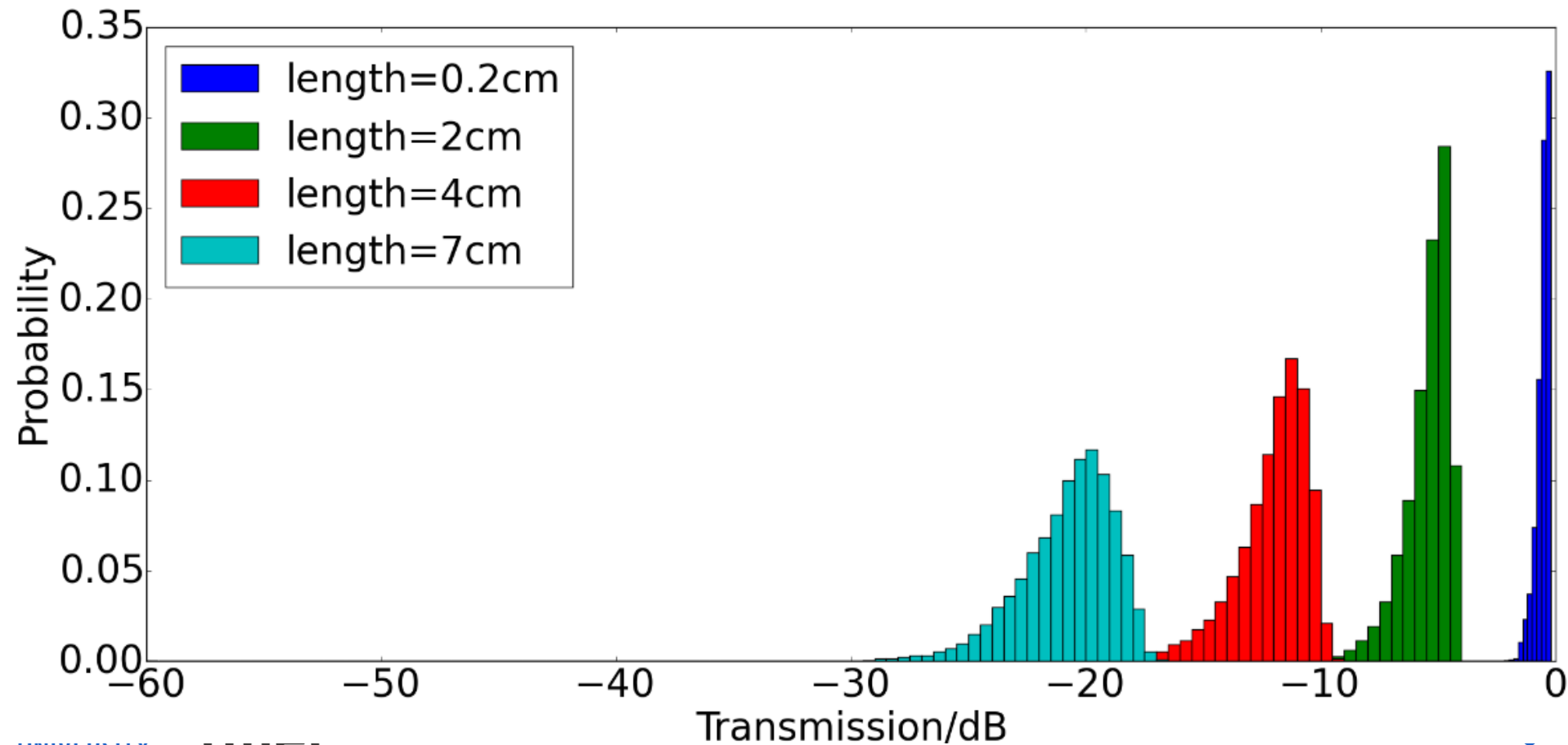
BACKSCATTERING IN SILICON WAVEGUIDE

- PDF of the spectrum gets broader
 - WG transmission becomes non-deterministic
- WG Shall be characterized with a model instead of a loss factor
 - Yufei working on it



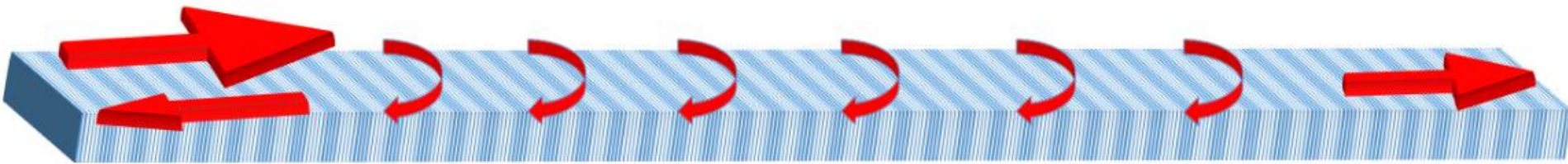
BACKSCATTERING IN SILICON WAVEGUIDE

- Fluctuations in transmission spectral
 - Extreme value distribution fits well

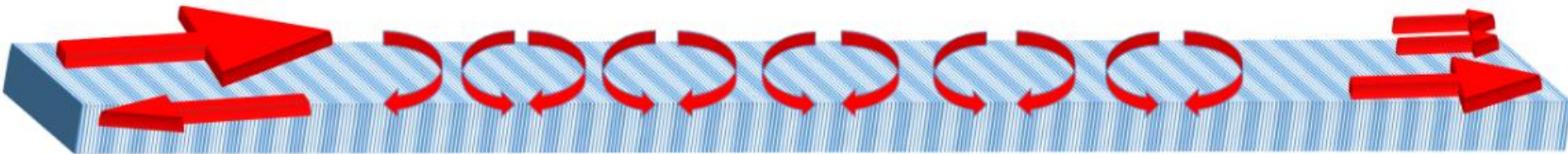


BACKSCATTERING IN SILICON WAVEGUIDE

- Origin attributed to coherent multi-backscattering events
 - Numerous beams interfere at the output
 - Not new in photonics crystal WG. First reported in strip WG



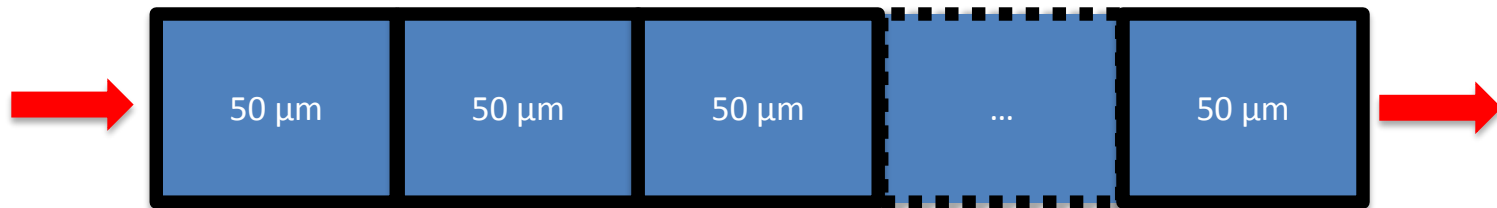
(a) Roughness: radiation loss + distributed backscattering



(b) Roughness: Coherent multi-scattering; Transmission influenced

BACKSCATTERING IN SILICON WAVEGUIDE

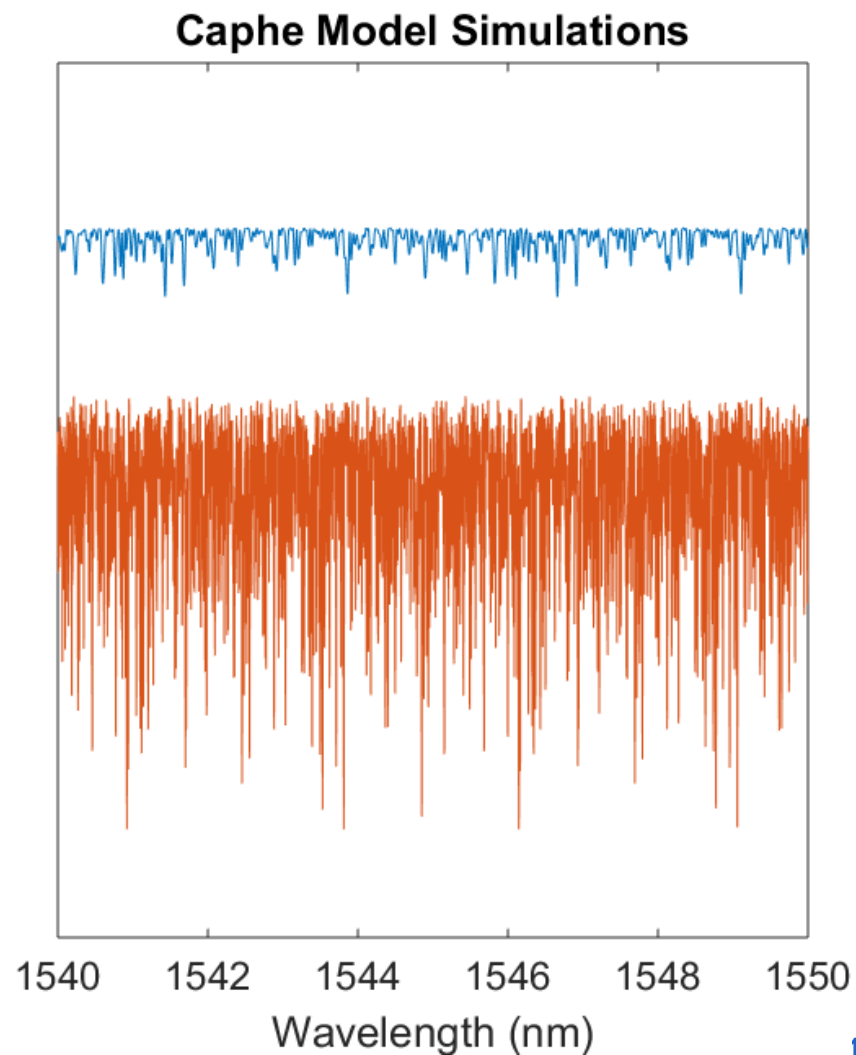
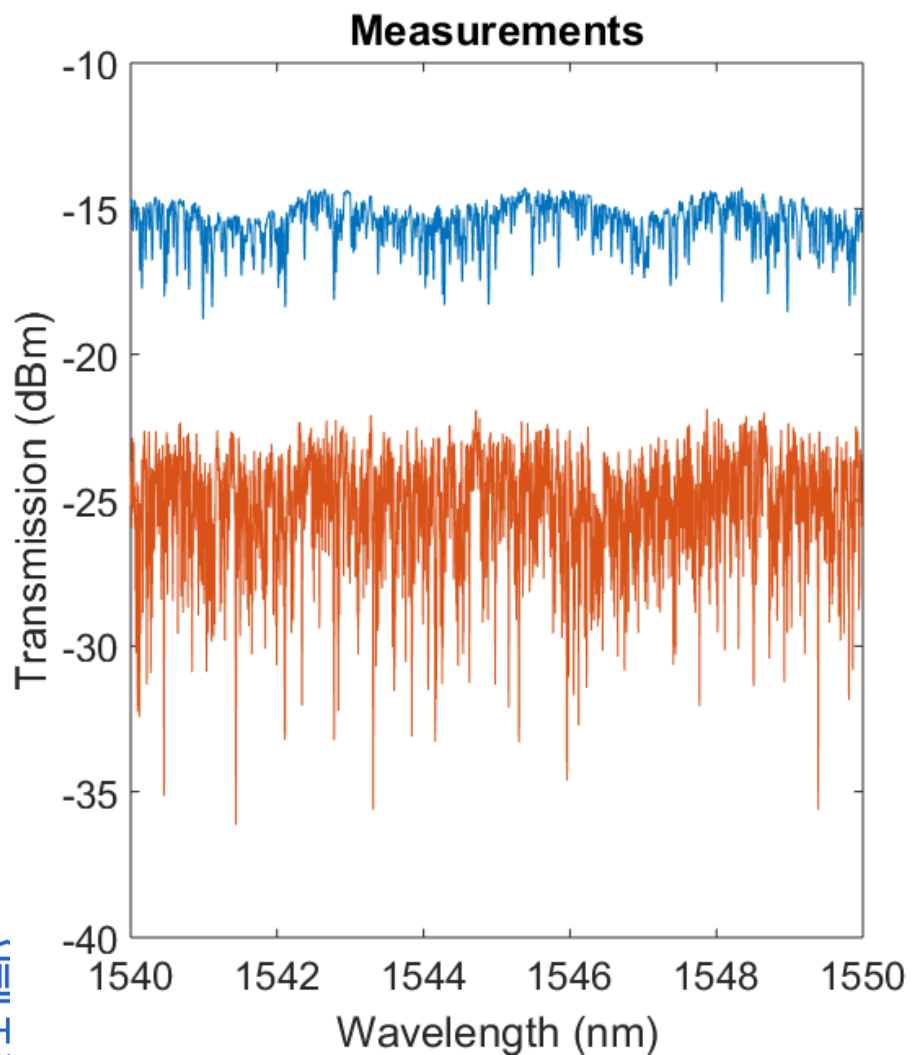
- Optical circuit model
 - Sectionize a WG into segments with reflector in between
 - Parameters :
 - Loss α
 - Reflectivity $r \rightarrow$ constant
 - Reflection phase $\phi \rightarrow$ random



Y. Xing et al. OWTNM 2016, Poland

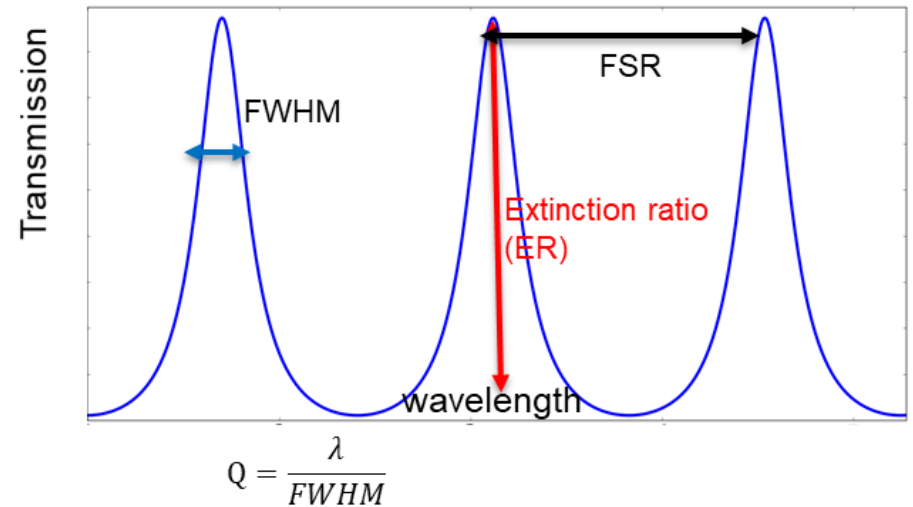
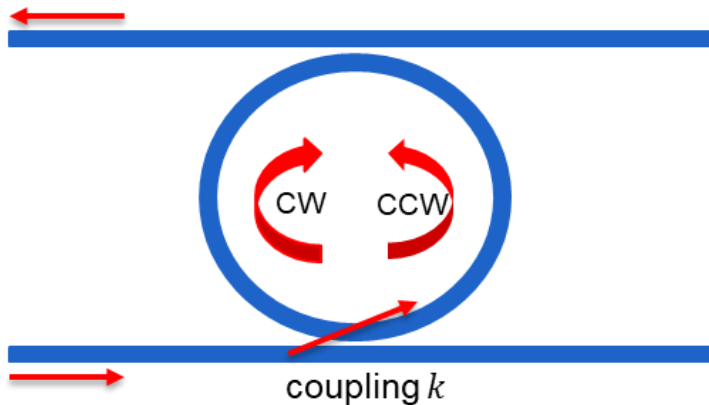
BACKSCATTERING IN SILICON WAVEGUIDE

- Optical circuit model



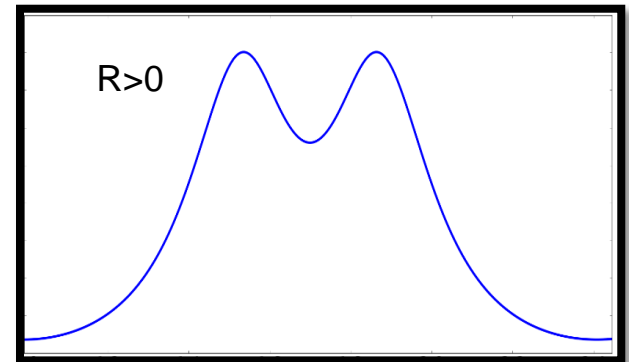
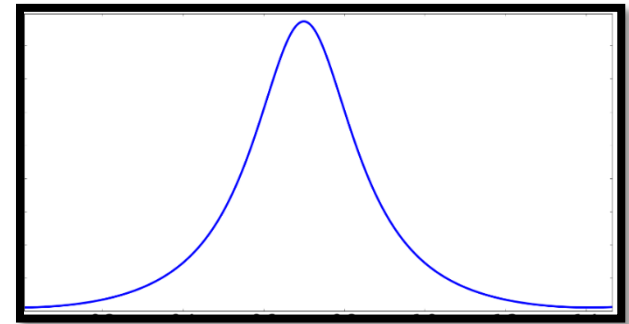
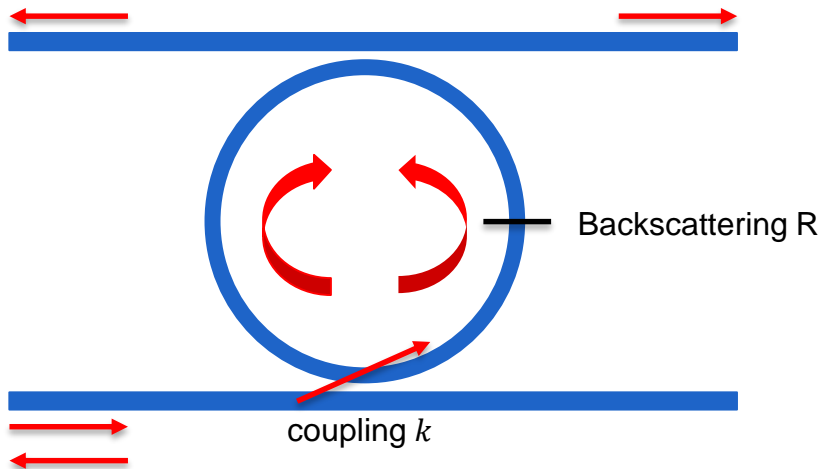
PARASITICS IN SILICON MICRORING

- Parasitics in resonator are more severe, as light travels multiple rounds
- Two degenerate circulating modes (CW and CCW)
- Only two parameters to be manipulated for a ring resonator
 - Total roundtrip length L
 - Coupling coefficient k



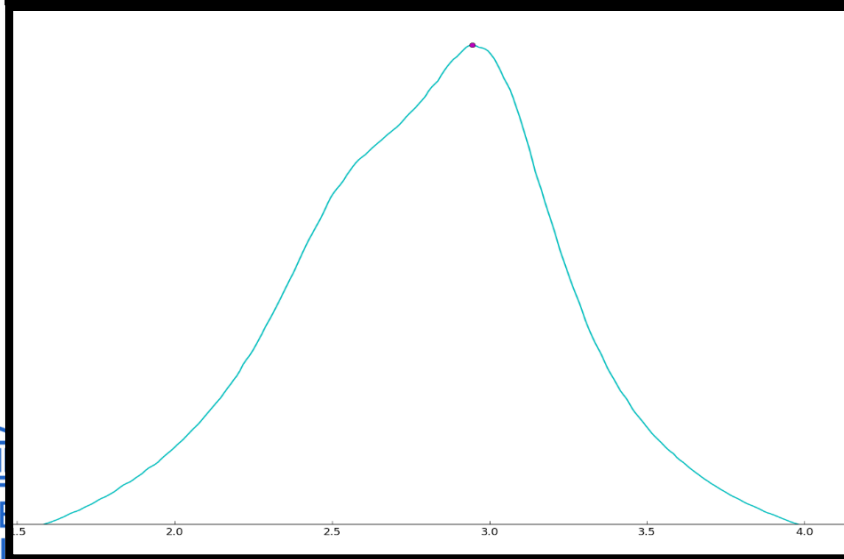
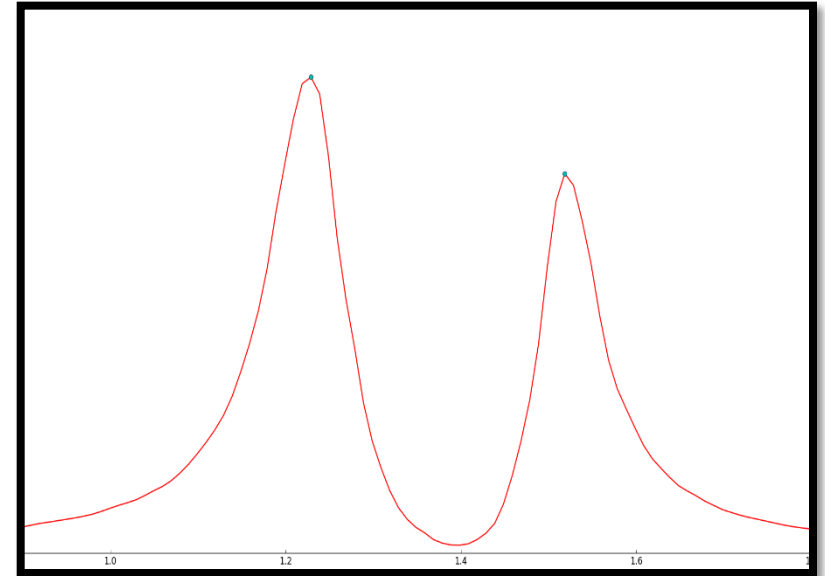
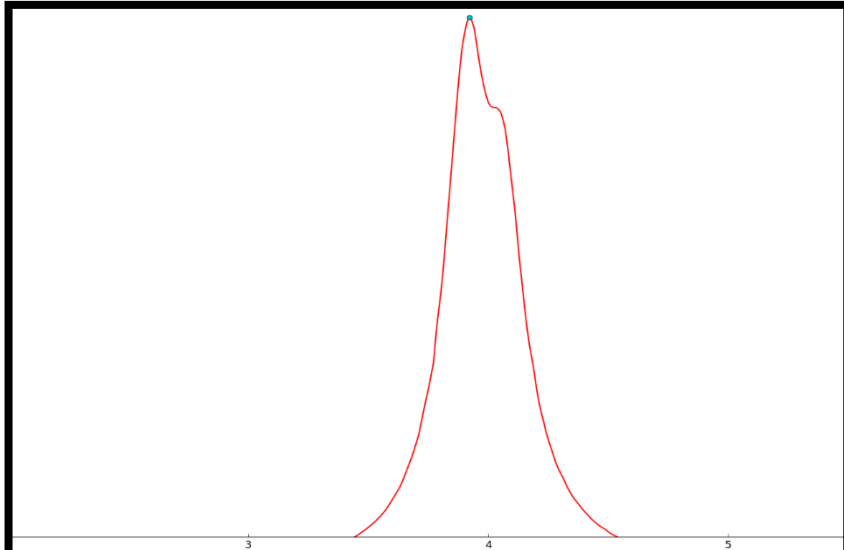
PARASITICS IN SILICON MICRORING

- Backscattering/reflections
 - couples two modes and break degeneracy \rightarrow splitting



PARASITICS IN SILICON MICRORING

- Real examples



Real world gives resonance splitting!

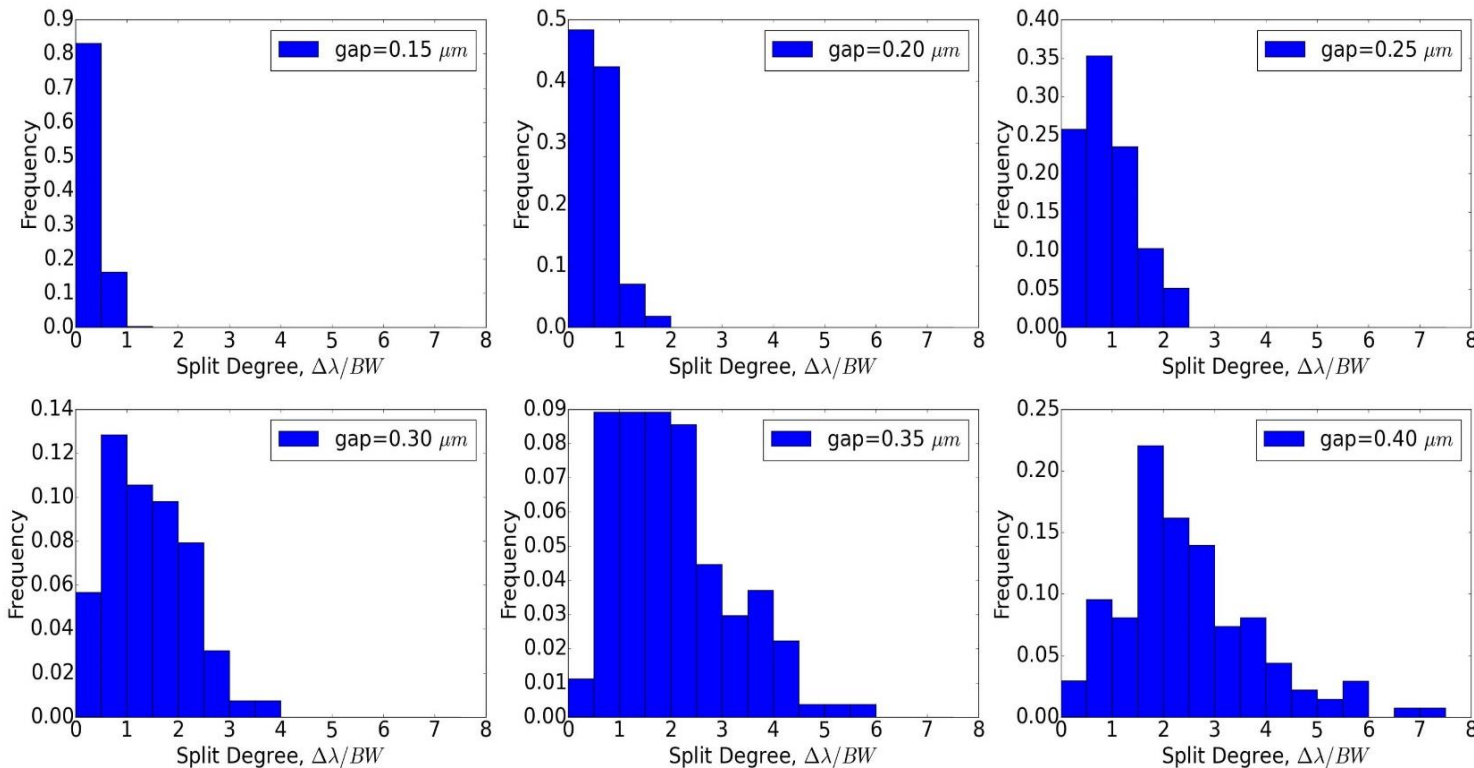
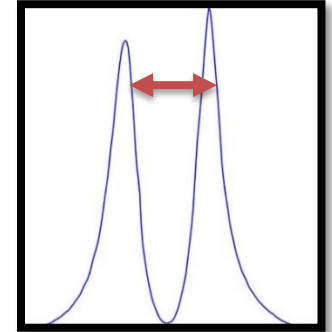
PARASITICS IN SILICON MICRORING

Split distance : $\Delta\lambda$

Bandwidth : BW

Split degree: $\Delta\lambda/BW$

- Statistics
 - Measured 50+ rings with 1000+ resonances
 - 550 show splitting



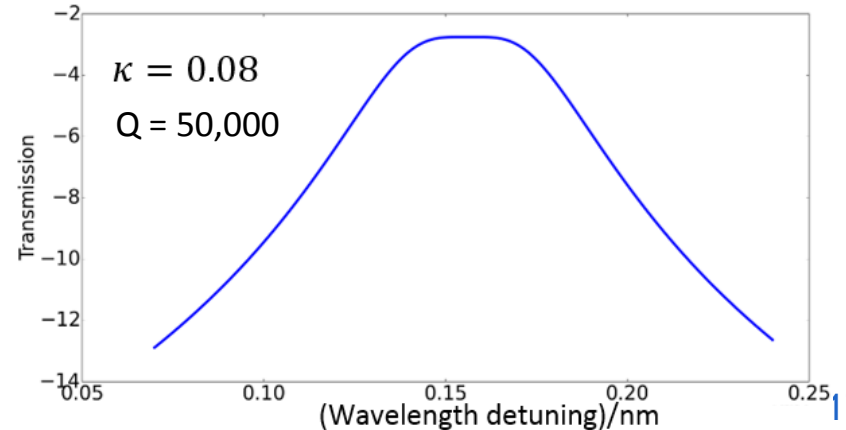
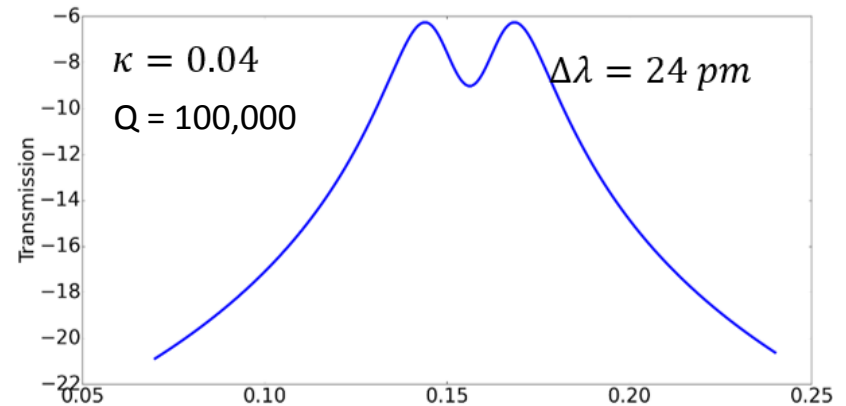
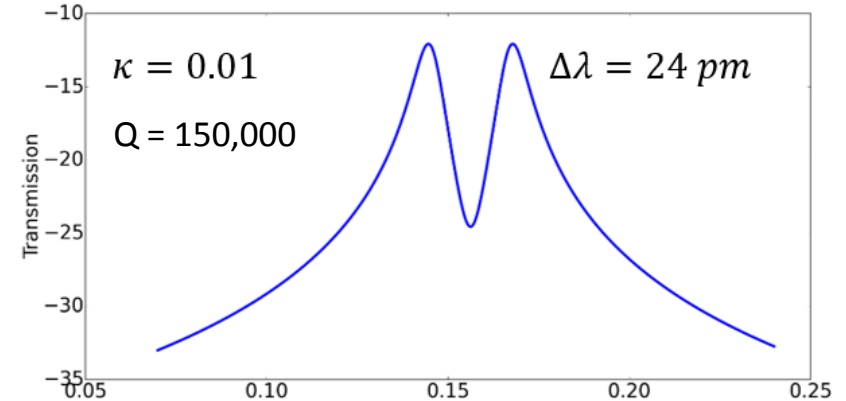
Split degree under different coupling gaps

PARASITICS IN SILICON MICRORING

- Low Q \rightarrow less splitting

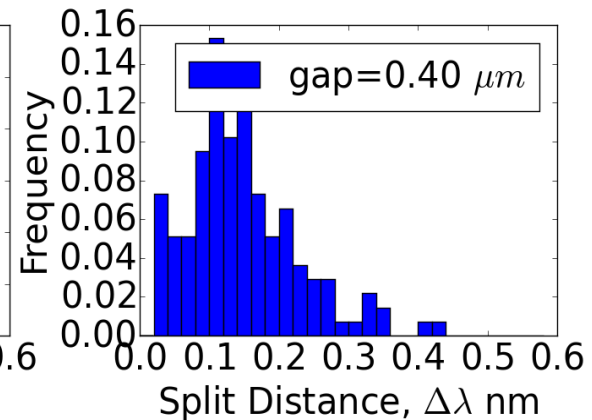
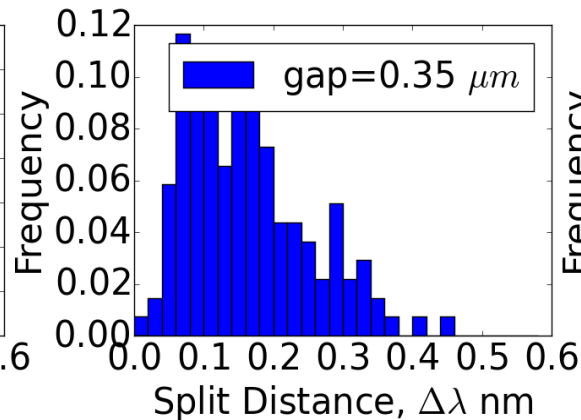
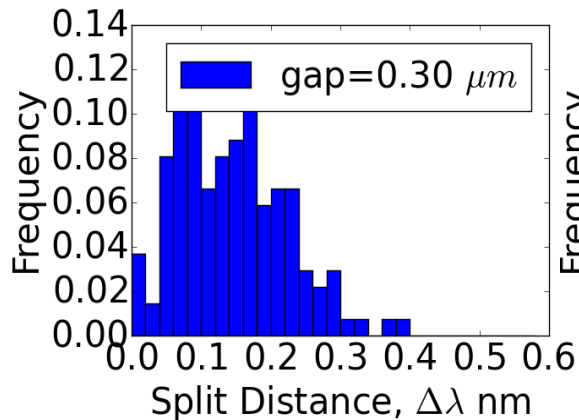
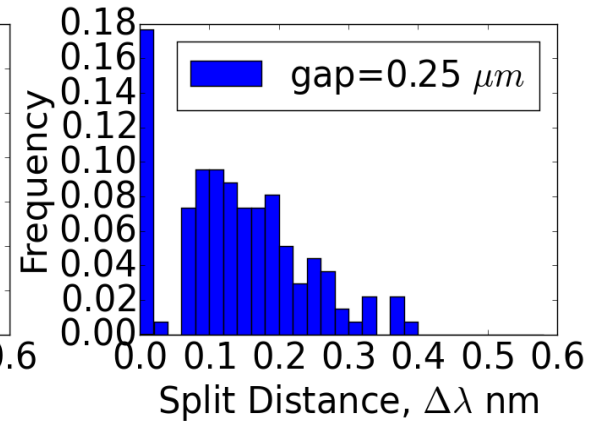
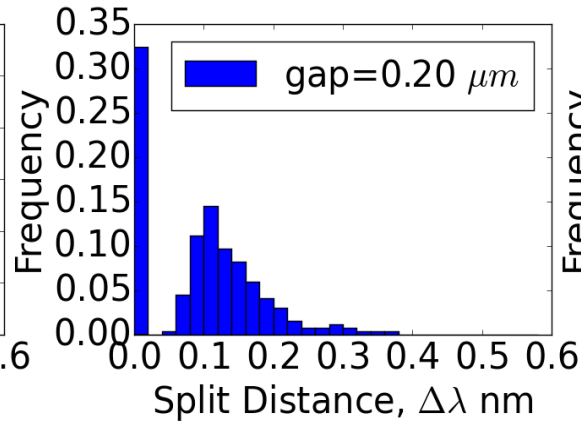
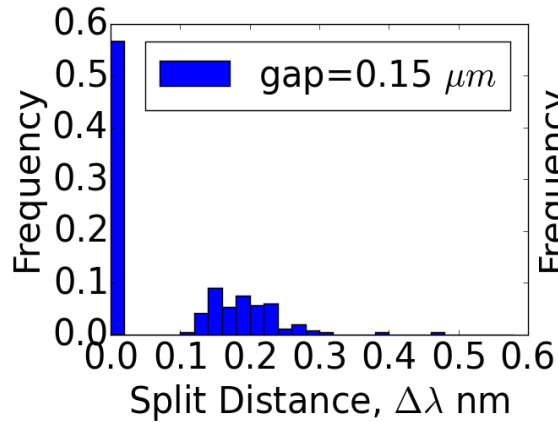
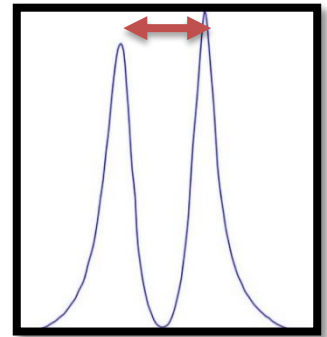


- Low Q \rightarrow invisible splitting



PARASITICS IN SILICON MICRORING

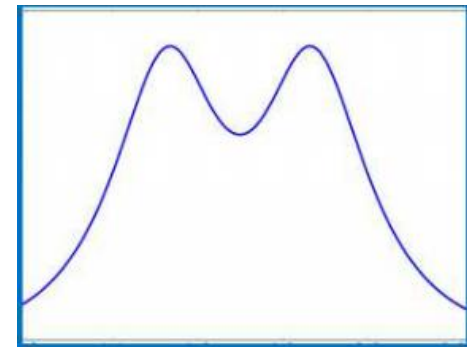
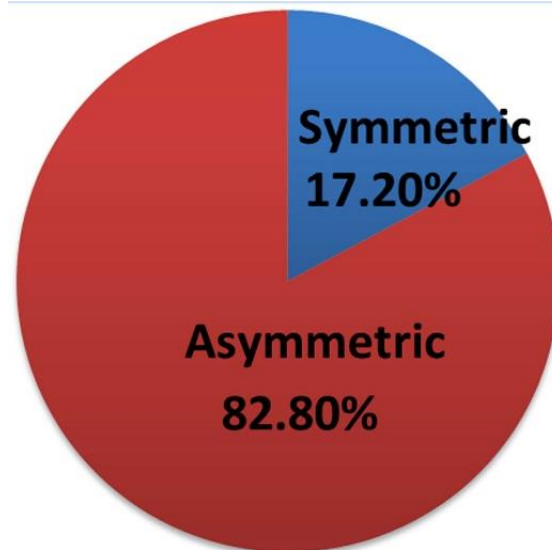
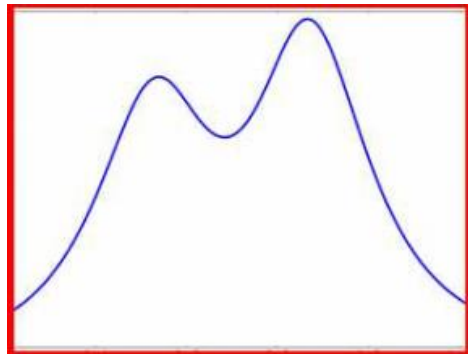
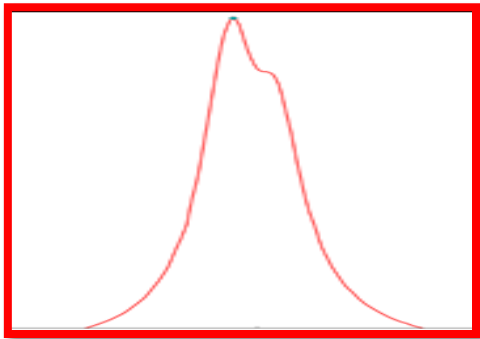
- Statistics
 - Absolute split distance



Split distance under different coupling gaps

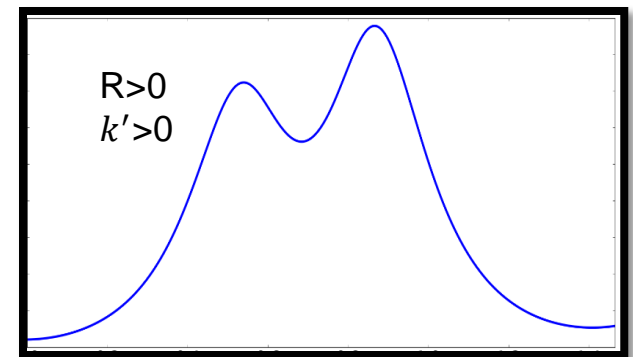
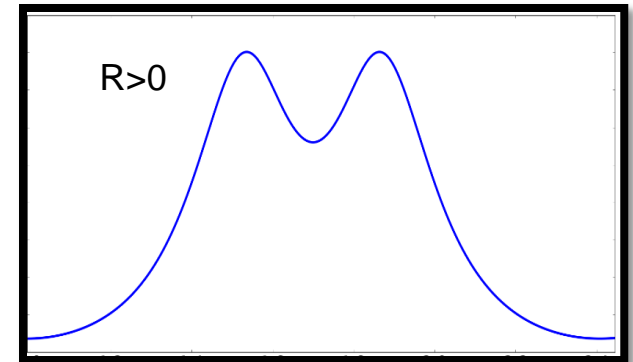
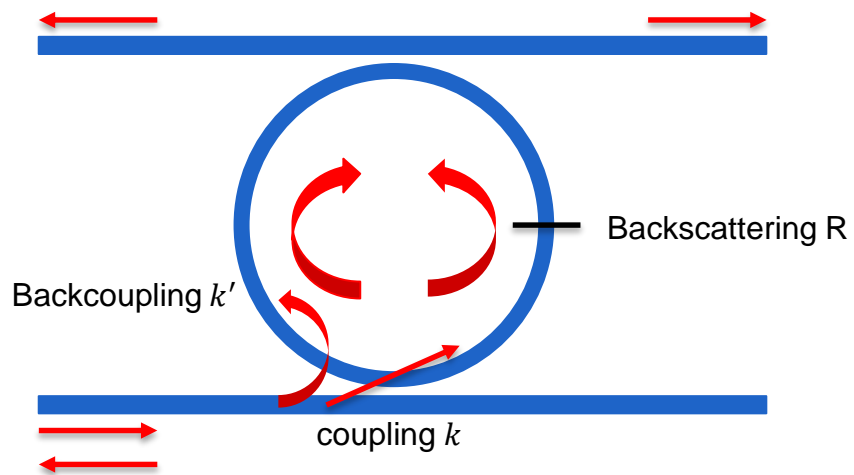
PARASITICS IN SILICON MICRORING

- Statistics
 - 80% of the 550+ split resonances are asymmetric



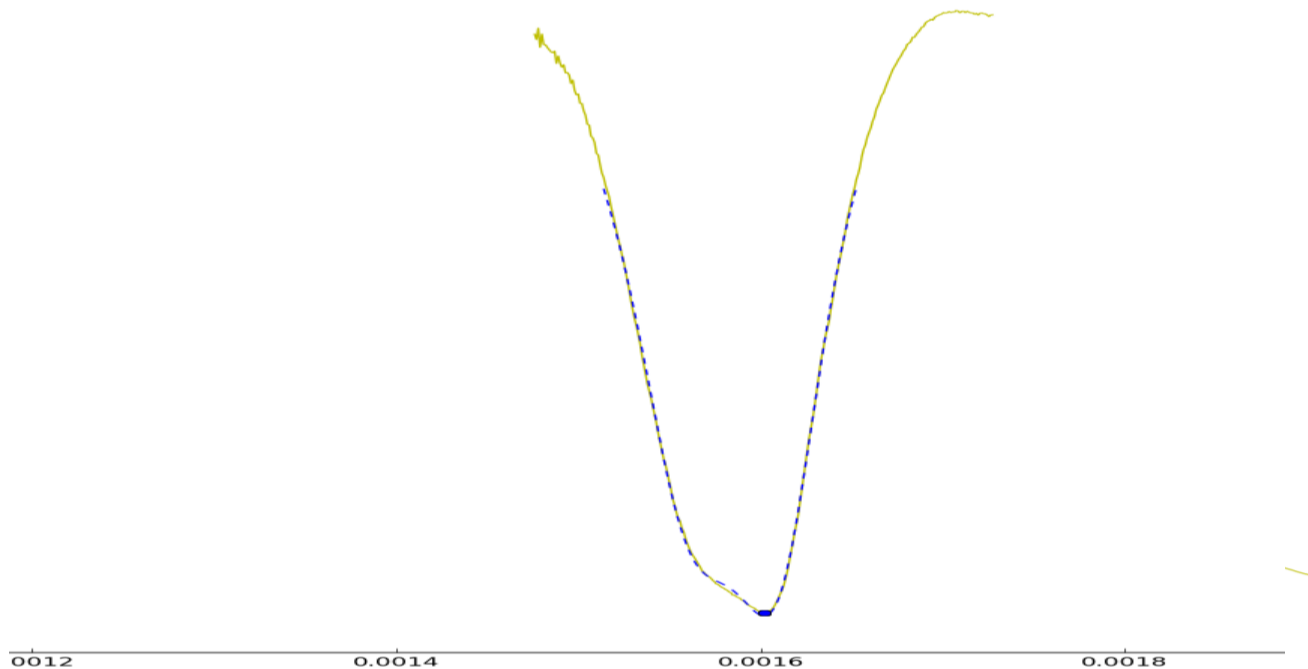
PARASITICS IN SILICON MICRORING

- Backcoupling
 - Affects peak asymmetry



PARASITICS IN SILICON MICRORING

- Model
 - Based on temporal coupled mode theory (tCMT)
 - Incorporate the backcoupling
 - All kinds of resonance can be fitted well, in a automatic way

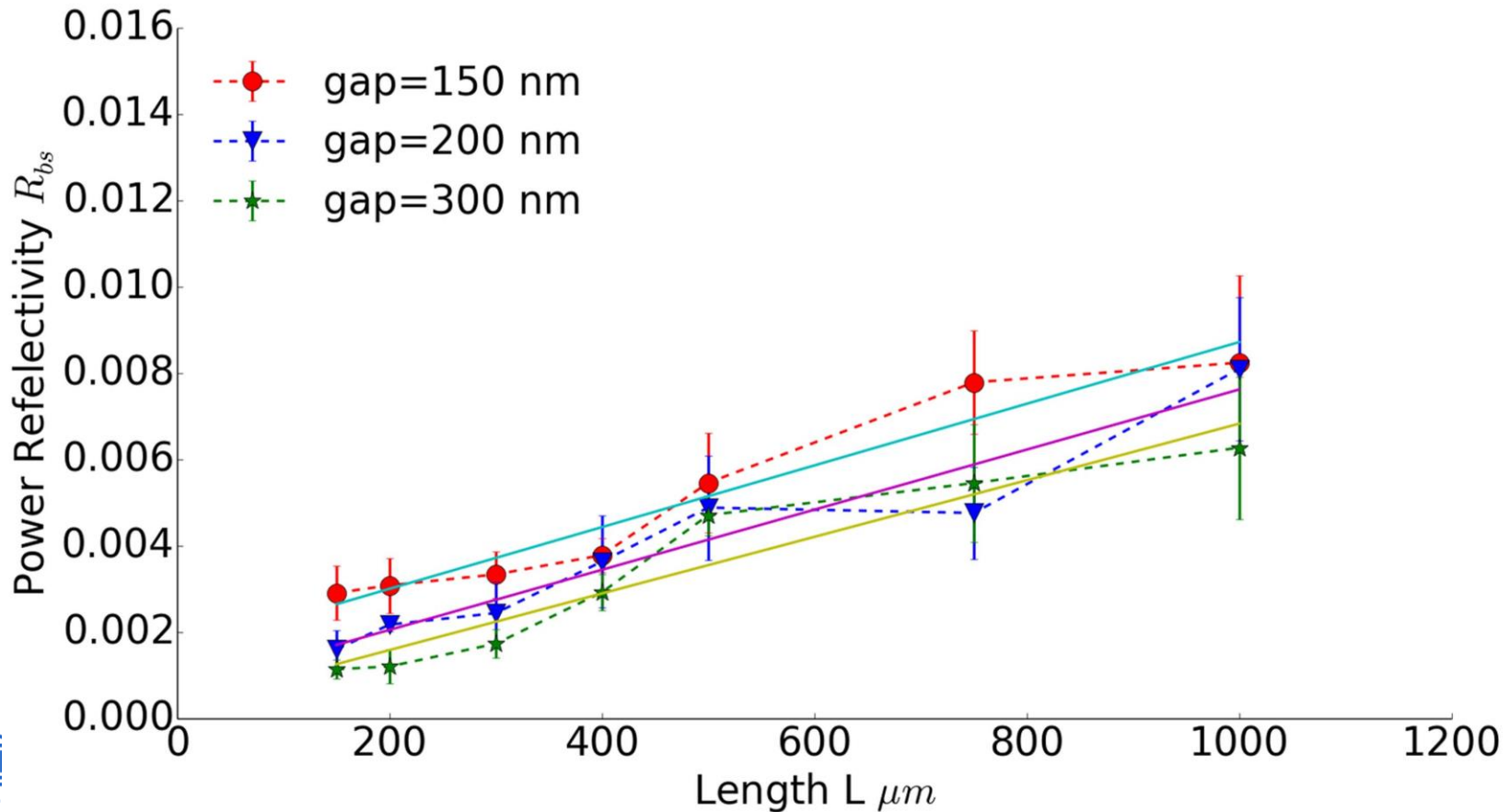


PARASITICS IN SILICON MICRORING

- Quantitative analysis
 - Use the model to extract parameters
 - Backscattering strength (R_{bs})
 - Perform a quantitative analysis of backscattering vs physical parameters (length L , coupling gap g , coupling length L_c)

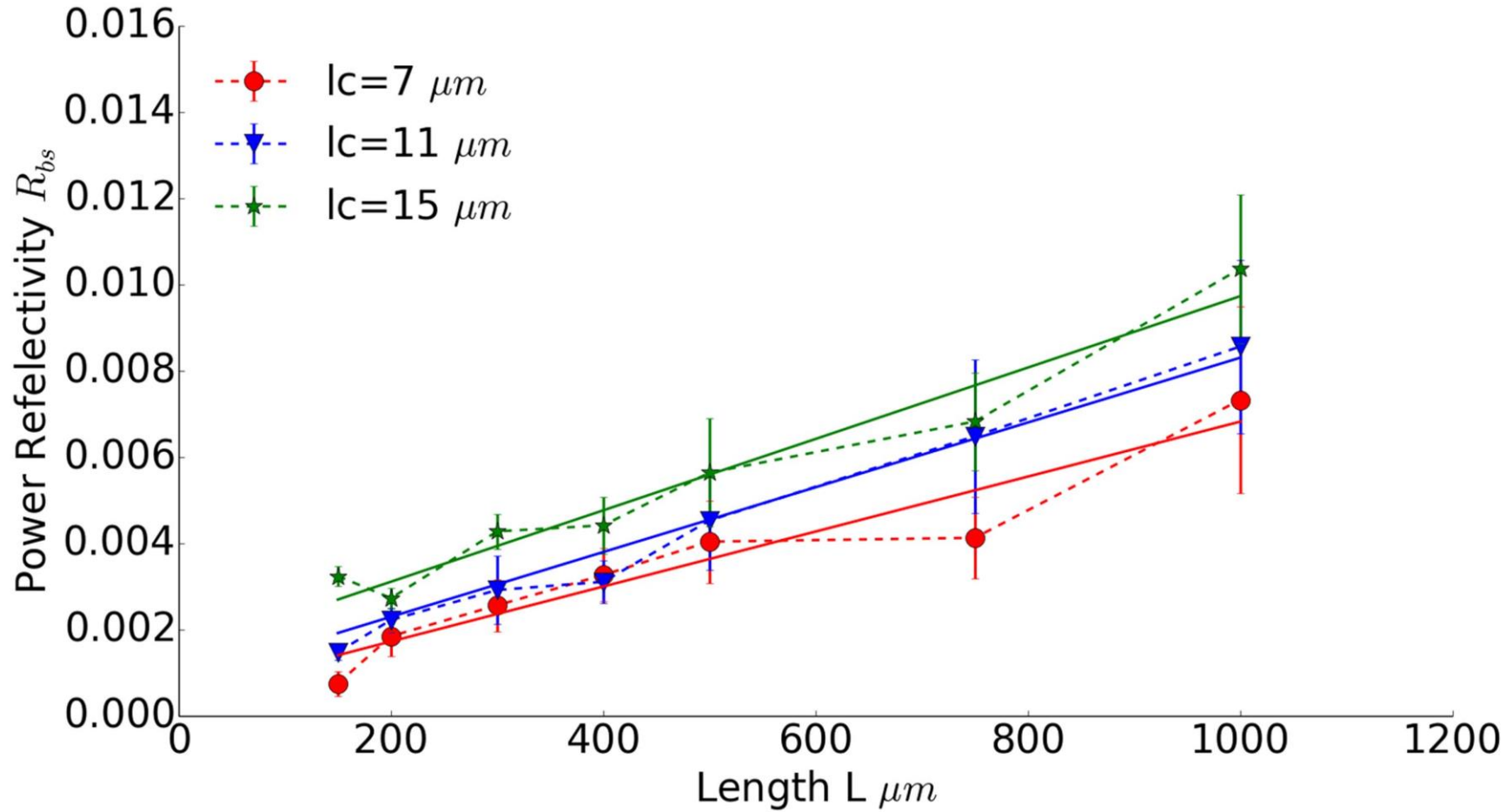
PARASITICS IN SILICON MICRORING

- Quantitative analysis
 - R_{bs} grows with ring length L
 - R_{bs} grows with decreasing gap g



PARASITICS IN SILICON MICRORING

- Quantitative analysis
 - Rbs grows with coupling length L_c

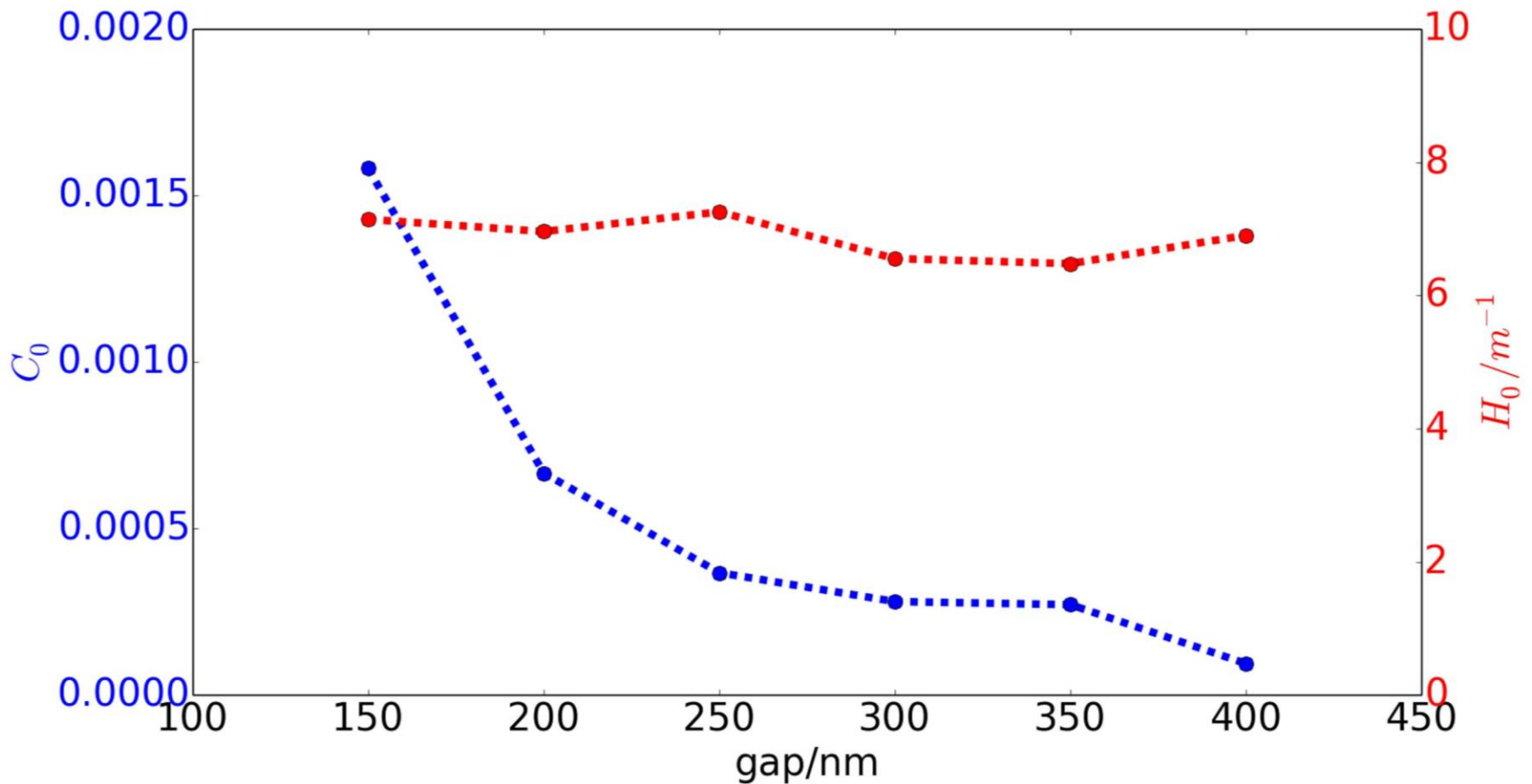


PARASITICS IN SILICON MICRORING

- Quantitative analysis
 - Simple predictive model for Rbs
 - $R_{bs} = H_0 L + C_0$, covers both the contributions from waveguide and couplers
 - H_0 depends on the cross-section of the WG and the quality of the roughness
 - C_0 determined by the couplers

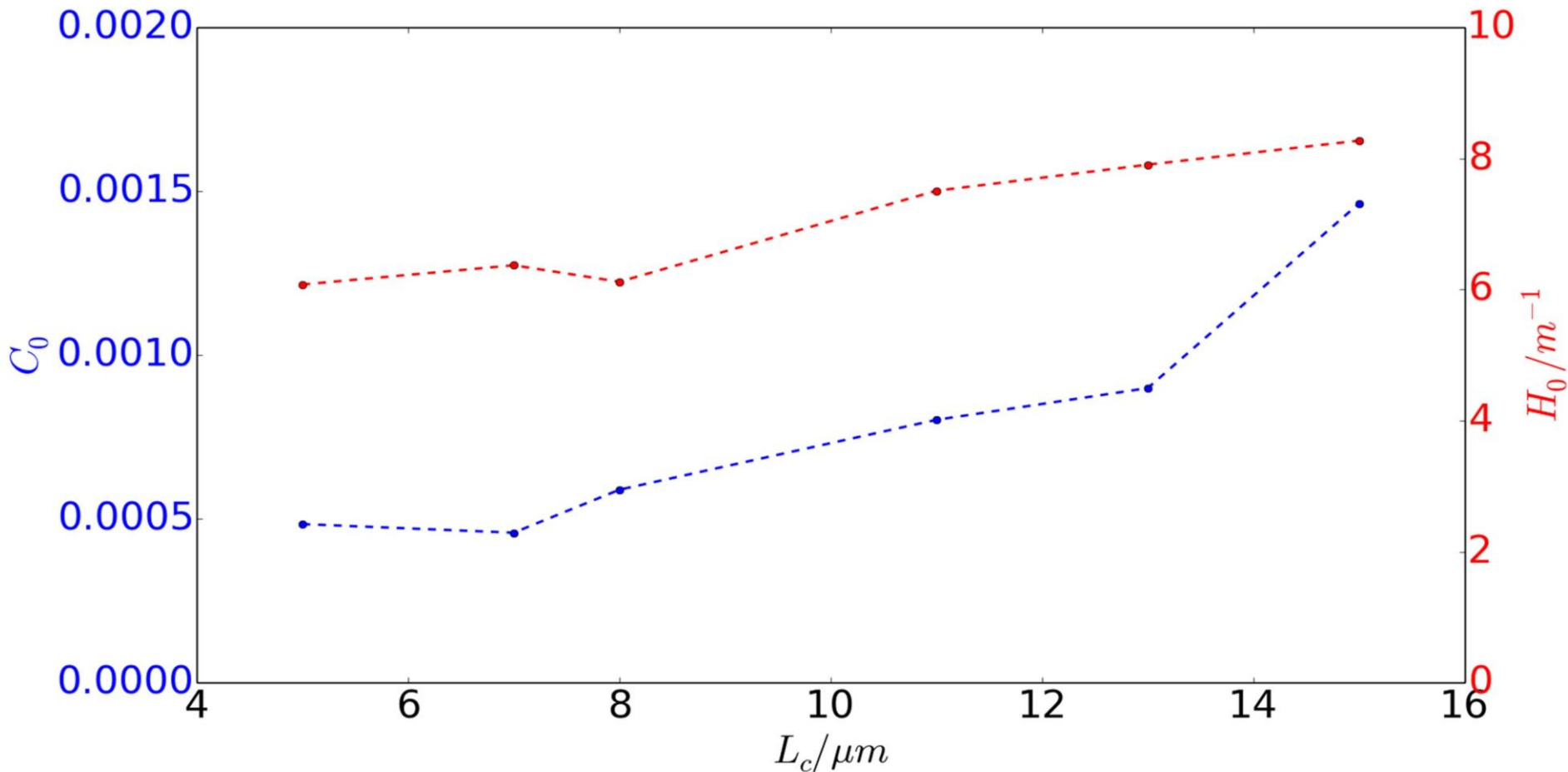
PARASITICS IN SILICON MICRORING

- Quantitative analysis
 - H_0, C_0 vs coupling gap
 - H_0 constant, C_0 decreases



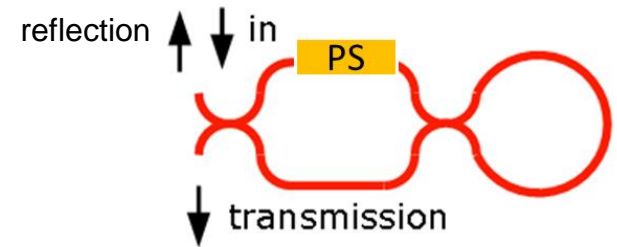
PARASITICS IN SILICON MICRORING

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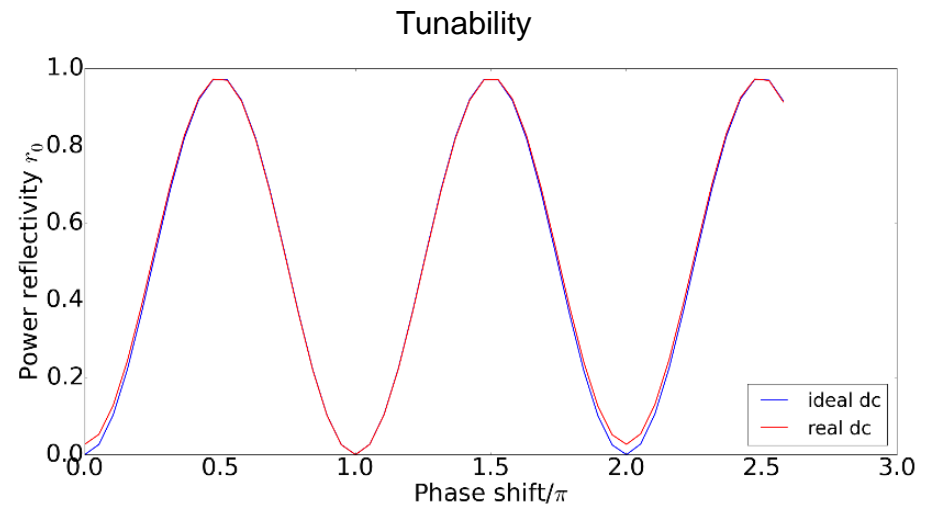


SUPPRESS BACKSCATTERING IN MICRORING

- Fabrication hardly changes \rightarrow BS always there
- Design methods to suppress backscattering
 - Take control of total internal reflections
- Integrated, tunable, low loss CMOS compatible reflector

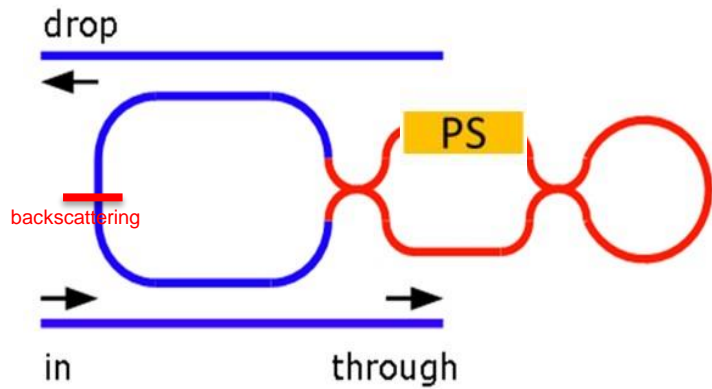


- $0.5 \cdot \pi \rightarrow$ 100% change in reflectivity

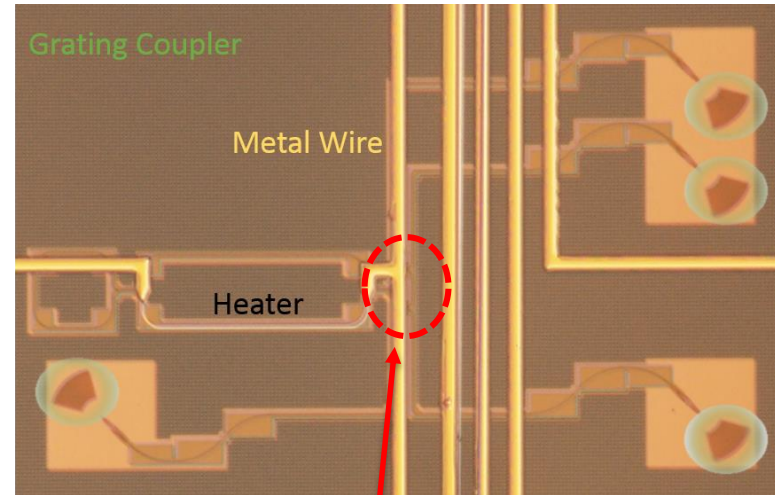


SUPPRESS BACKSCATTERING IN MICRORING

- Schematic



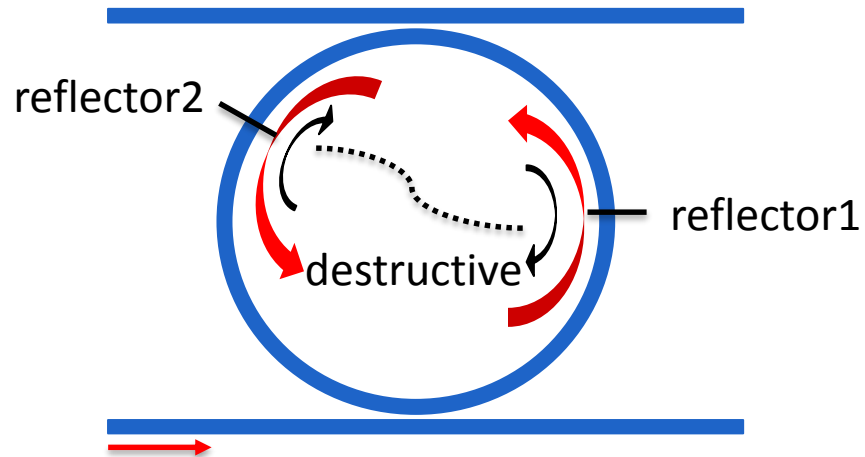
- Device



Ring cavity

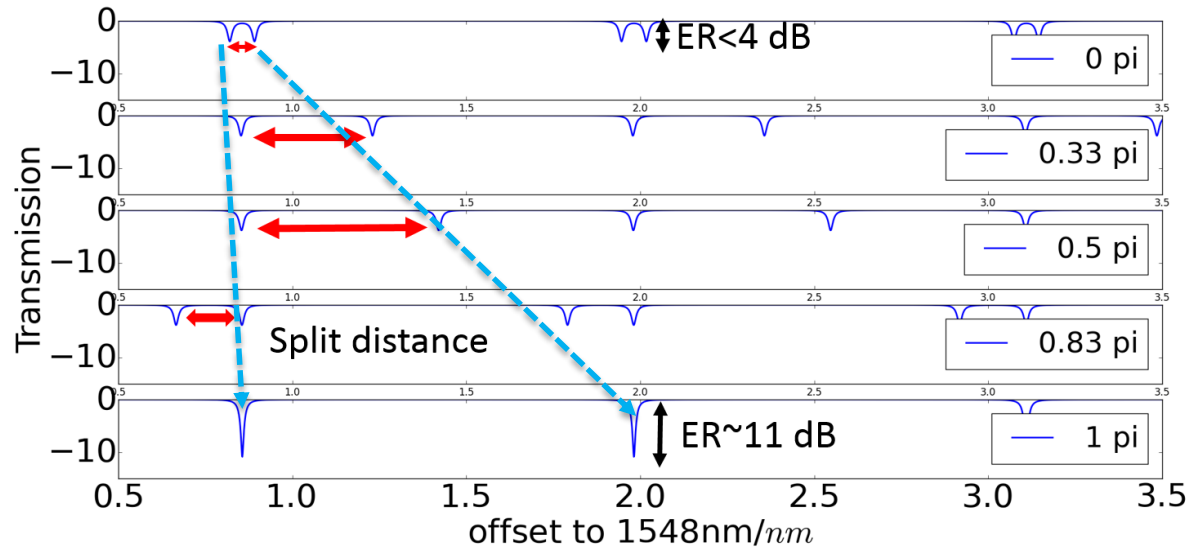
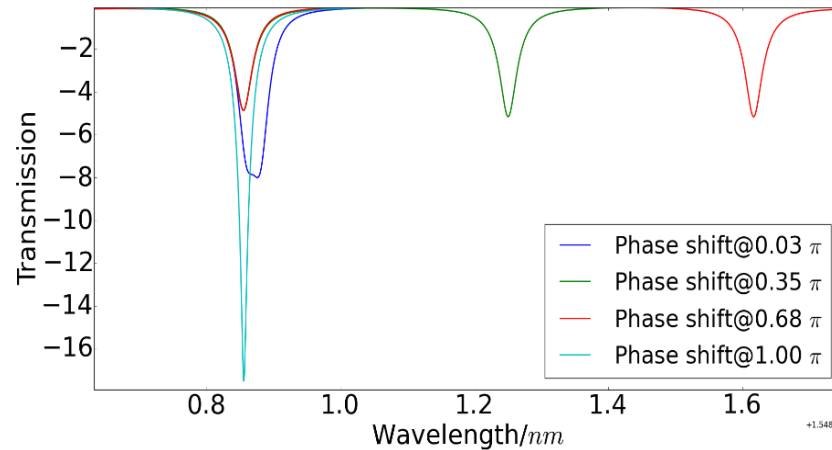
SUPPRESS BACKSCATTERING IN MICRORING

- principle



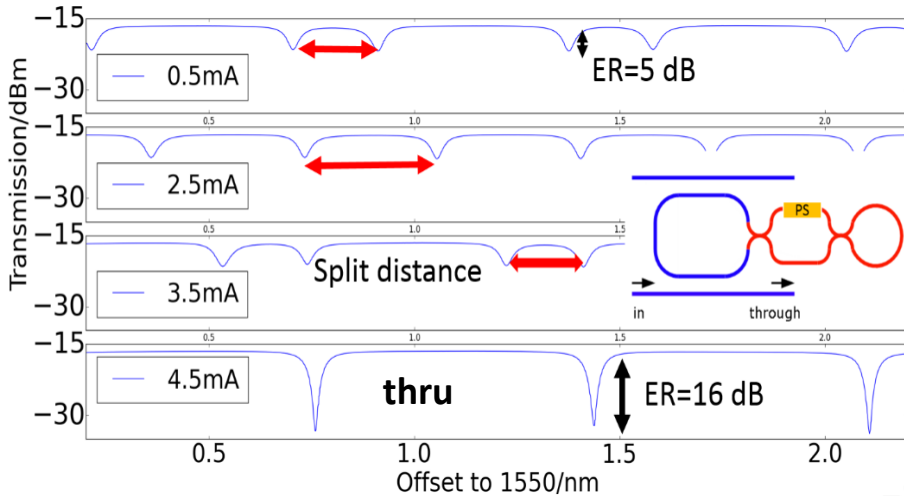
SUPPRESS BACKSCATTERING IN MICRORING

- Simulation – Full control of the resonance

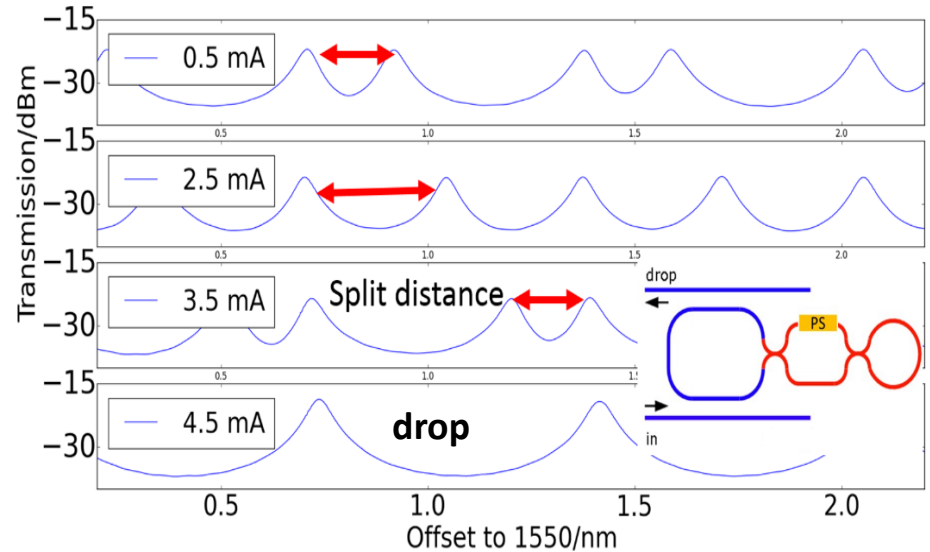


SUPPRESS BACKSCATTERING IN MICRORING

- Measurement - cancel splitting in thru and drop ports with an improved ER

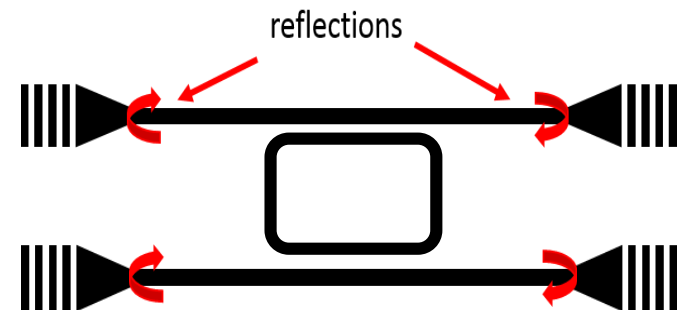
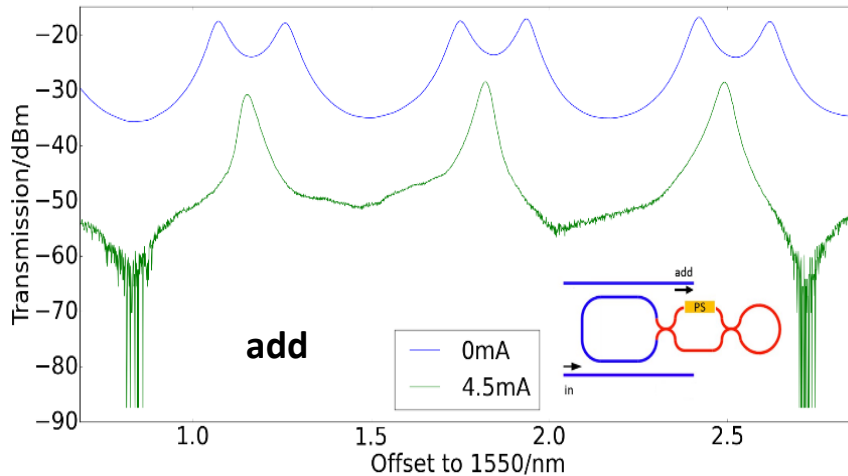


Note how the ER gets recovered

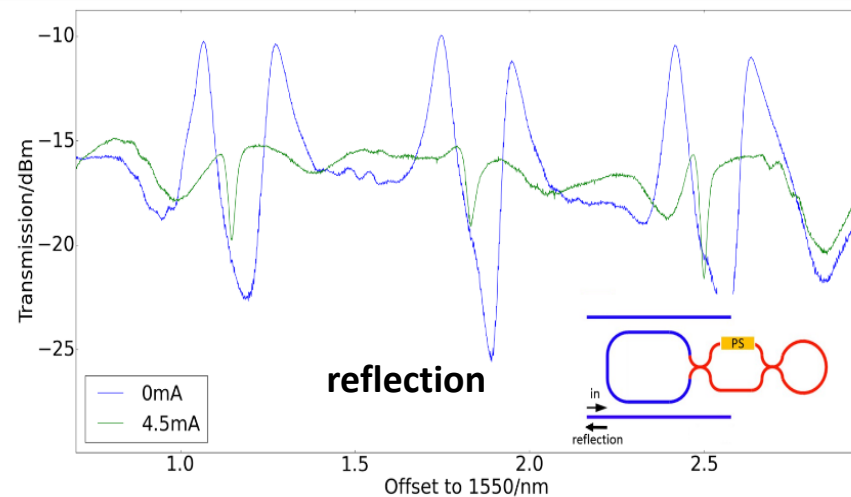


SUPPRESS BACKSCATTERING IN MICRORING

- Measurement - suppress leakage to add port and reflection to in port

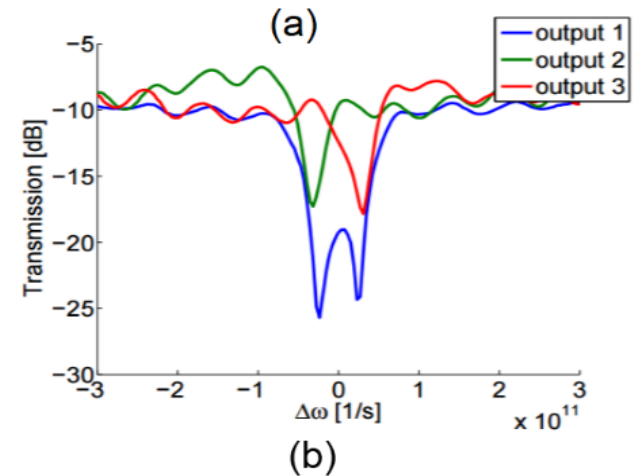
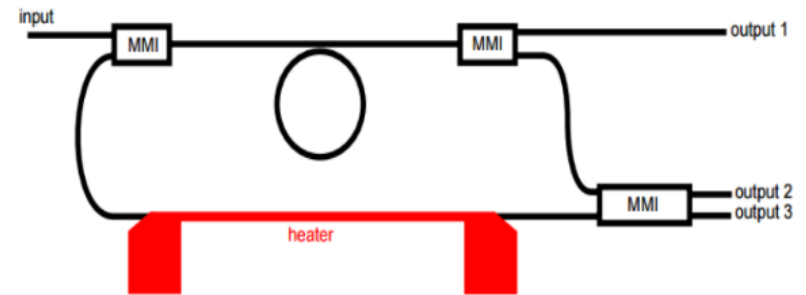


1. Still some leakage due to parasitic reflections
2. Power suppressed and no splitting any more



SUPPRESS BACKSCATTERING IN MICRORING

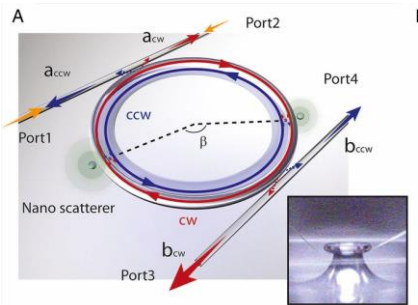
- Other approaches for this problem – post-processing
 - Introduce loss
 - Only solves splitting
 - Quality sacrificed (ER)
 - Single port (thru) solution



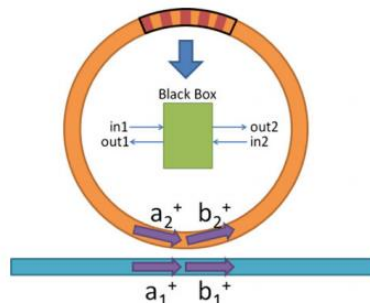
S. Werquin, Optics Express Vol. 21, No. 14, 2013

SUPPRESS BACKSCATTERING IN MICRORING

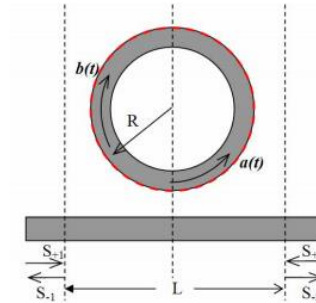
- Other approaches for internal reflections
 - Uncontrollable



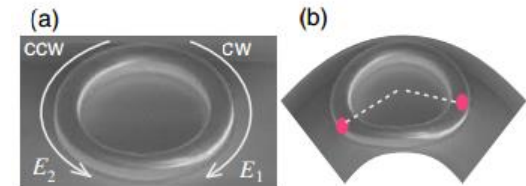
B. Peng, PNAS, 2016, 113(25)



Y. M. Kang, Opt Quant Electron, 2009, 41



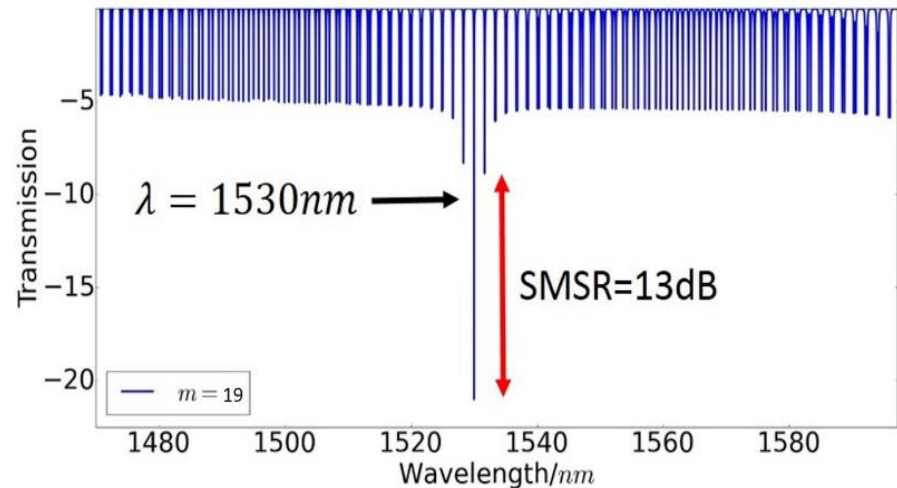
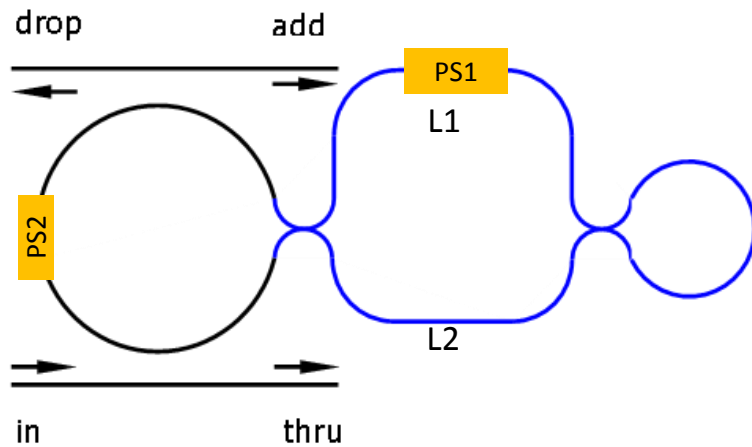
Z. Zhang, Optics Express, 2008, 16(7)



S. Longhi, Photonics Research, 2017, 5(6)

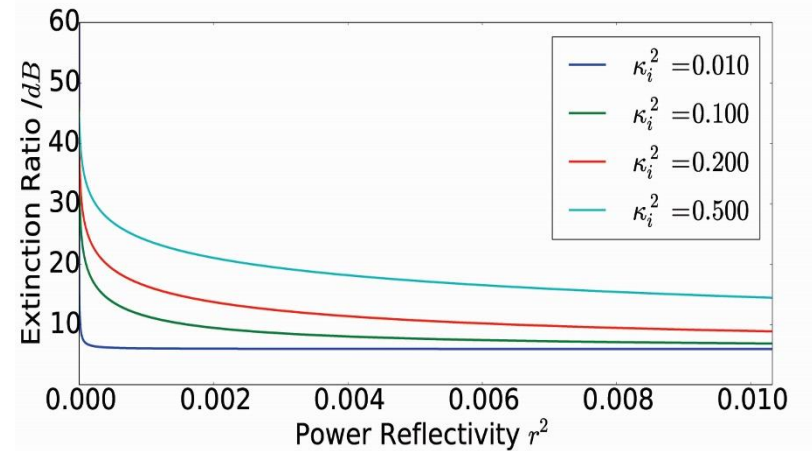
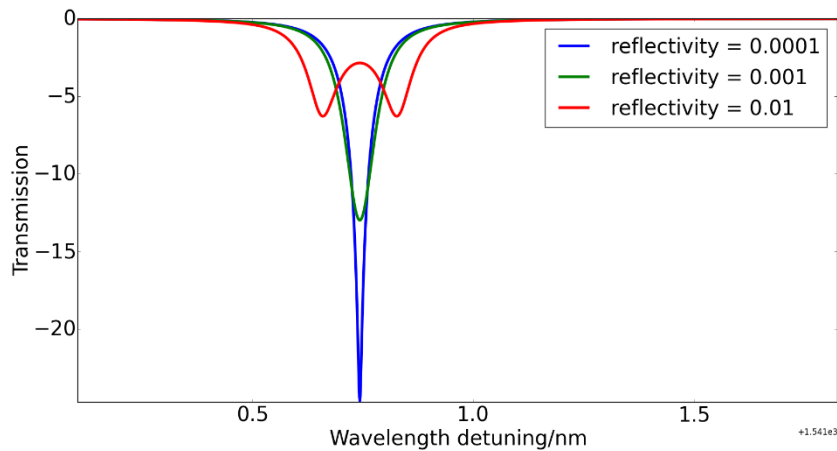
REFLECTIONS ENGINEERING – SINGLE MODE RING

- Suppression of BS is a result of reflections engineering
- Other applications → pseudo single mode filter, ultra wide FSR and tuning range
- Large FSR is desired to sensors, single mode laser cavities etc.



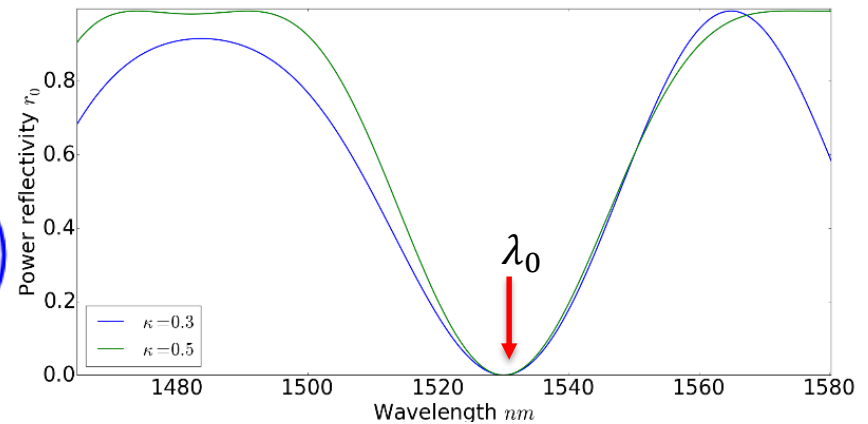
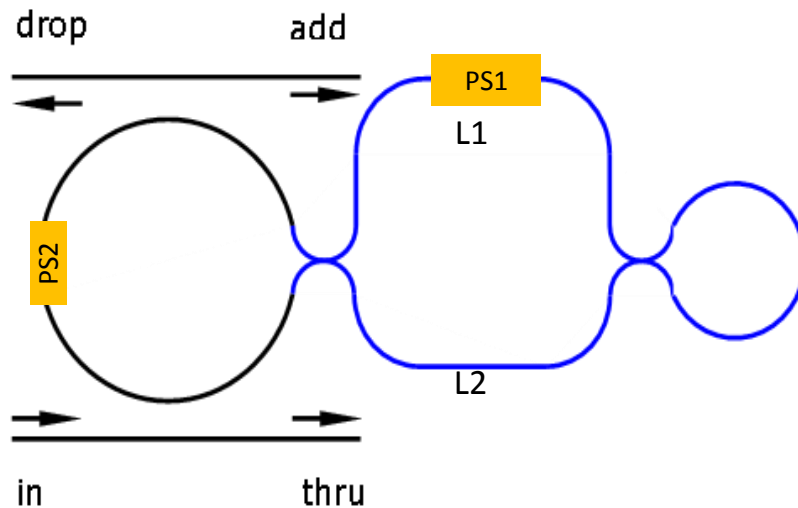
REFLECTIONS ENGINEERING – SINGLE MODE RING

- Principle for wide FSR
 - Ring: Internal reflection \rightarrow splitting + extinction ratio degradation



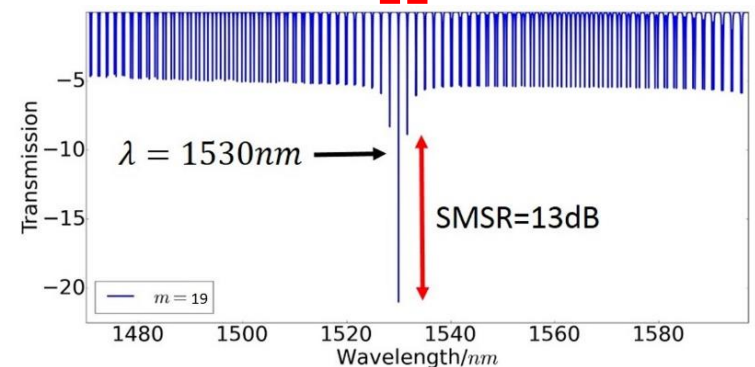
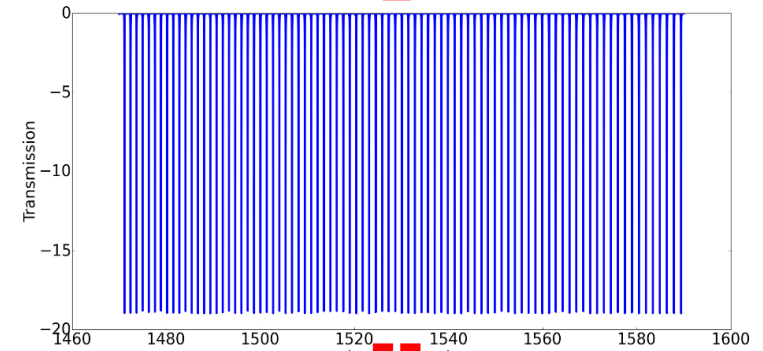
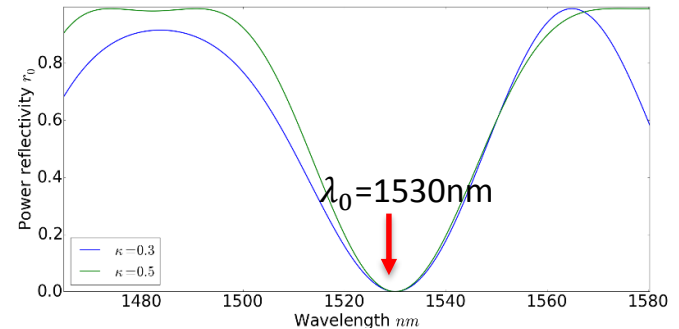
REFLECTIONS ENGINEERING – SINGLE MODE RING

- Principle for wide FSR
 - Reflector: provides a special spectrum
 - $L1 \neq L2$, unbalanced MZI
 - $\frac{2\pi\Delta L}{\lambda_0} = m\pi$, m is the interference order of the MZI
 - Only one wavelength in a very broad range has 0 reflection



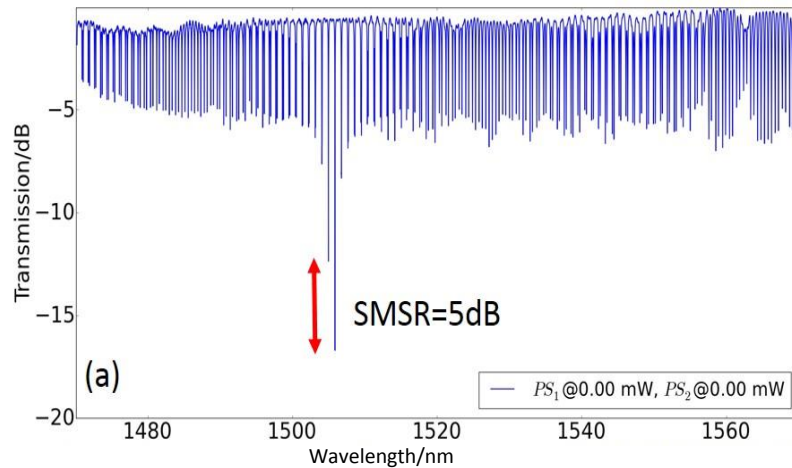
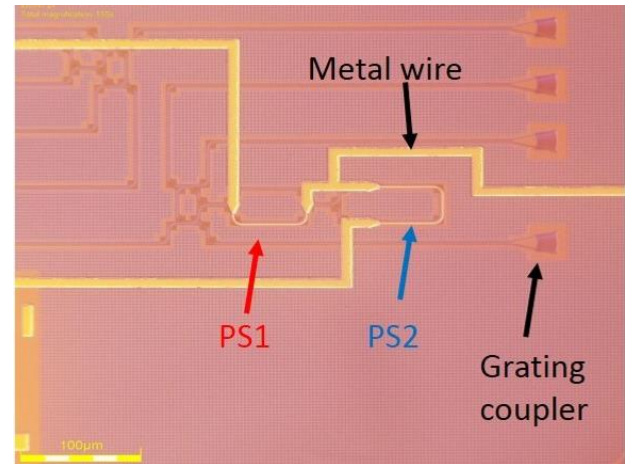
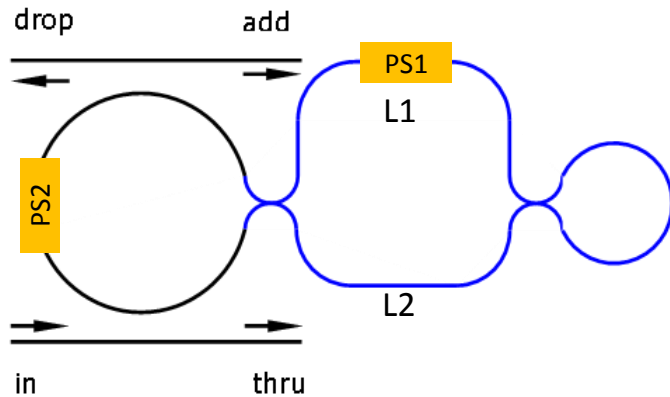
REFLECTIONS ENGINEERING – SINGLE MODE RING

- Principle for wide FSR
- Alignment between Zero-reflection and resonance
- Like a Vernier effect between reflector + ring

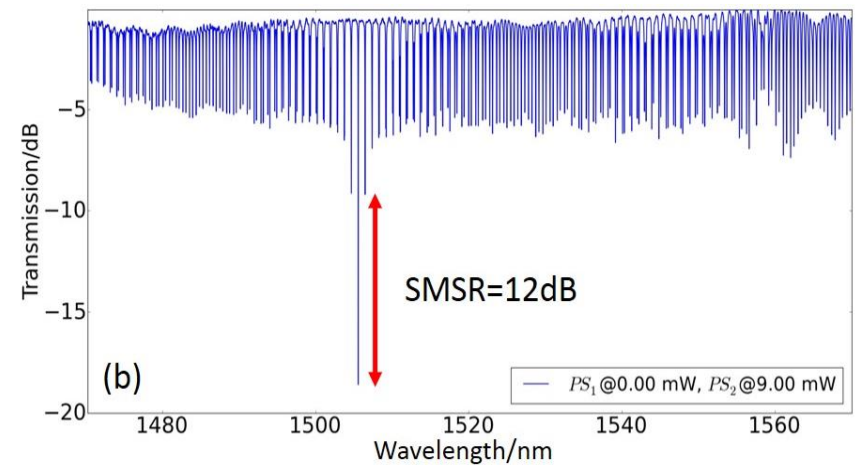


REFLECTIONS ENGINEERING – SINGLE MODE RING

- Measurements of wide FSR



→
tuning PS2



REFLECTIONS ENGINEERING – SINGLE MODE RING

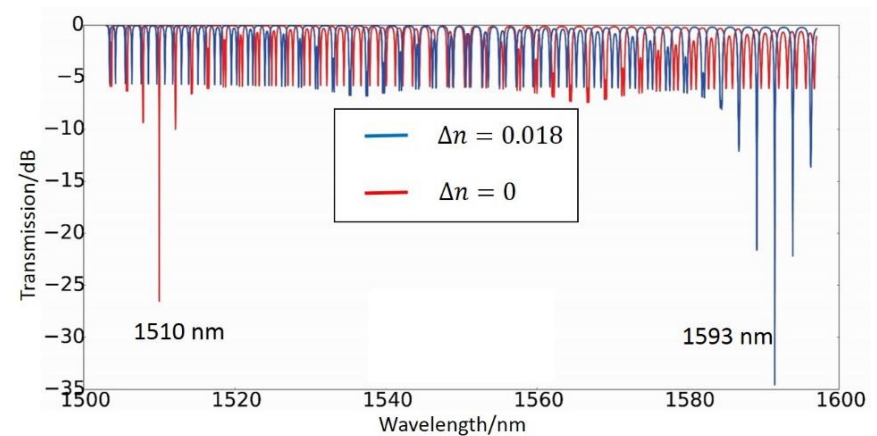
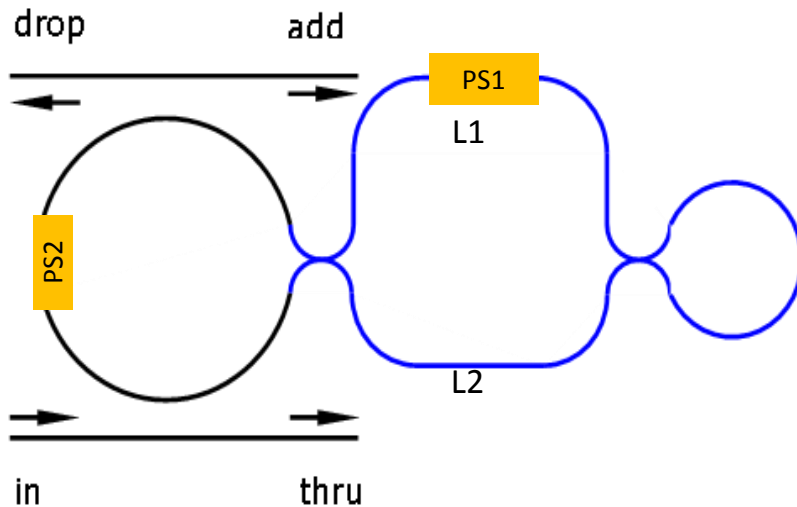
- Principle for ultra wide tuning range

- PS1: shift the zero reflection wavelength. Fast!
- PS2: shift the complete ring spectrum. Slow!

$$\frac{\Delta\lambda}{\lambda_0} = \frac{\Delta n}{n_g} \frac{L_{ps1}}{\Delta L}$$

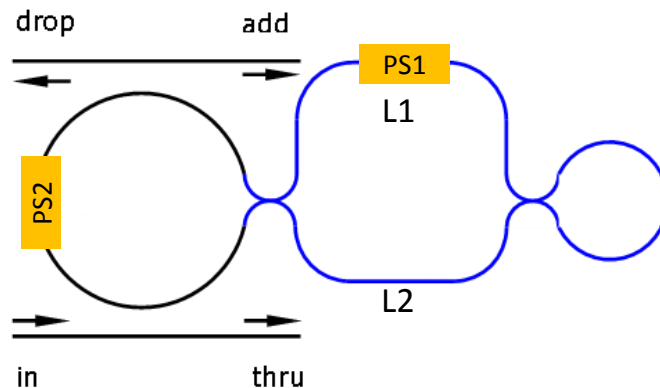
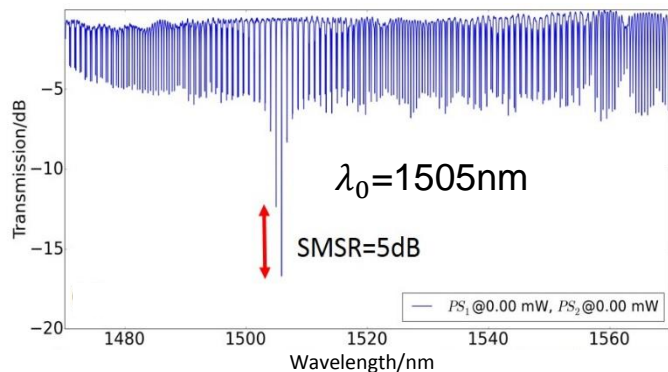
Amplification factor

$$\frac{\Delta\lambda}{\lambda_0} = \frac{\Delta n}{n_g}$$



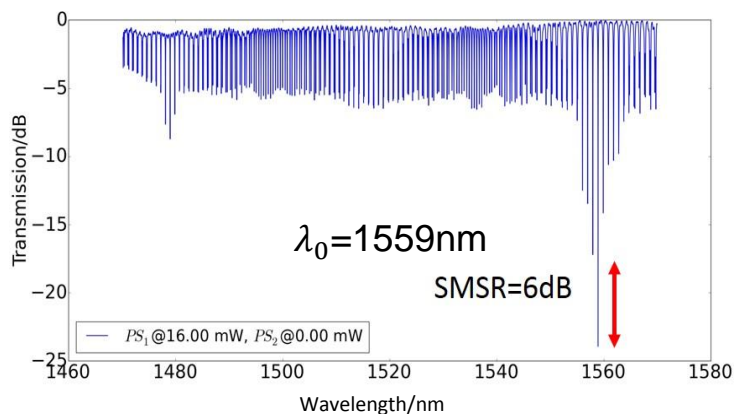
REFLECTIONS ENGINEERING – SINGLE MODE RING

- Measurements of wide tuning range

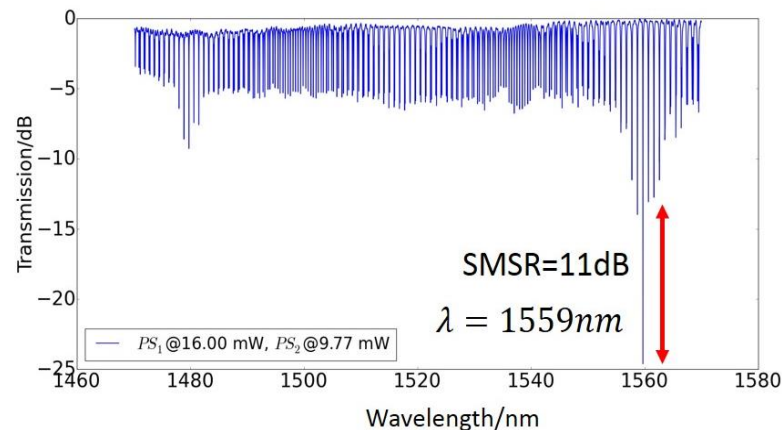


tuning PS1 \downarrow 16mW, $\Delta n=0.014$

11 times wider tuning range !

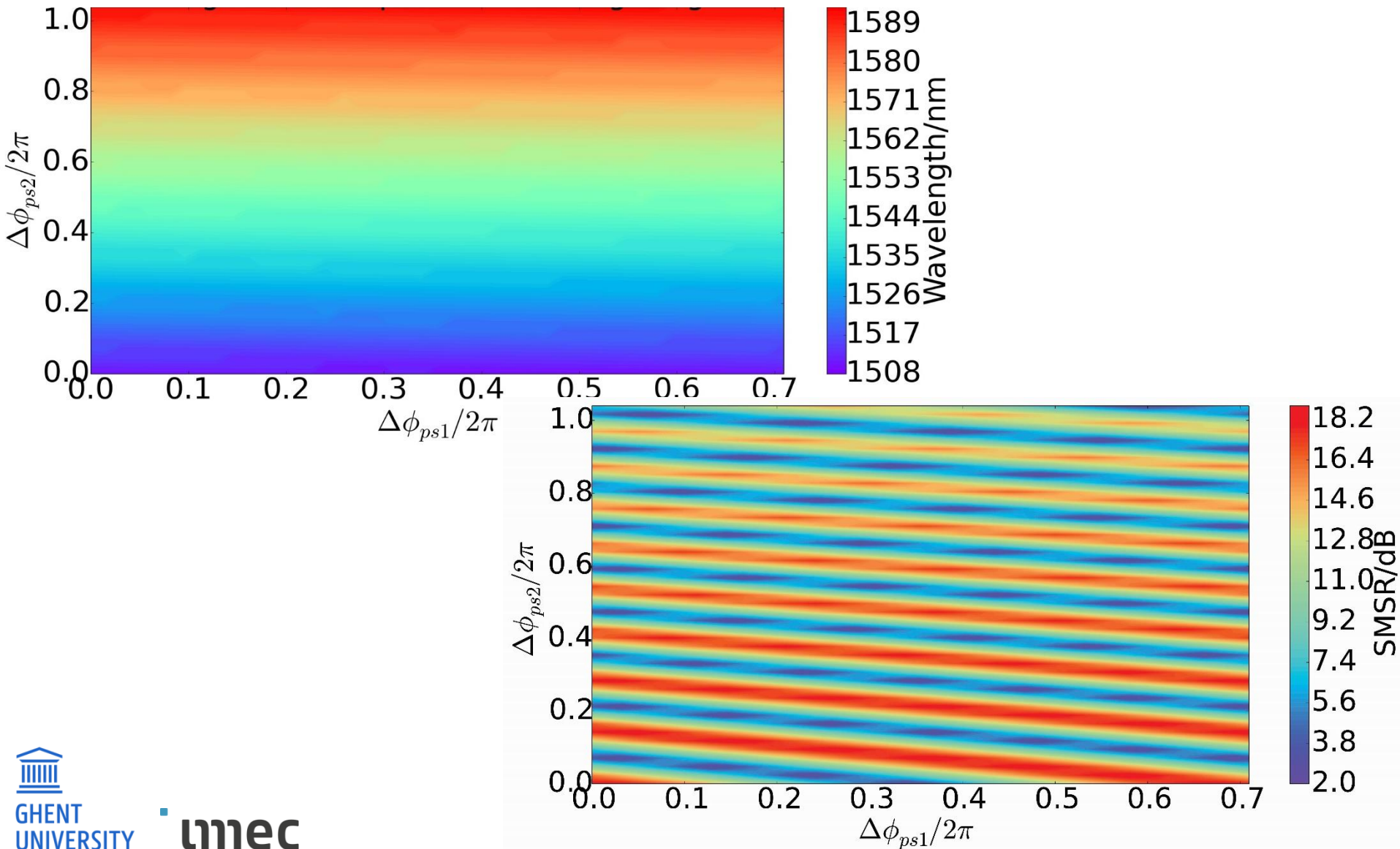


\rightarrow tuning PS2



REFLECTIONS ENGINEERING – SINGLE MODE RING

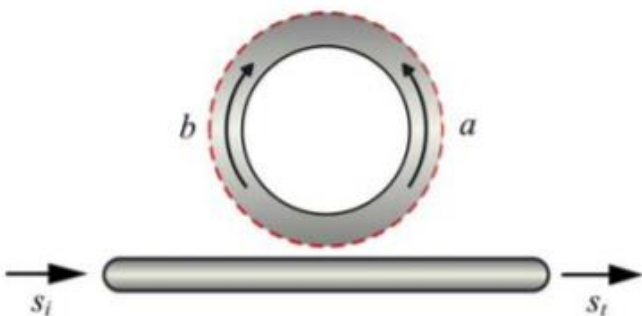
- Contour plots



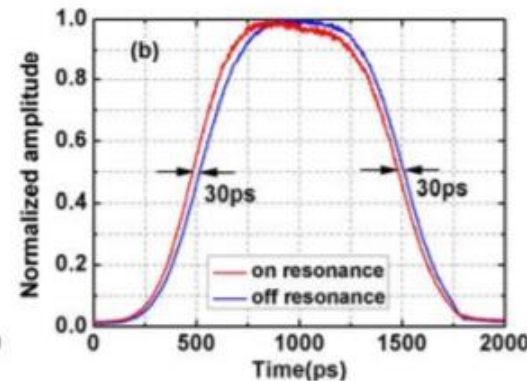
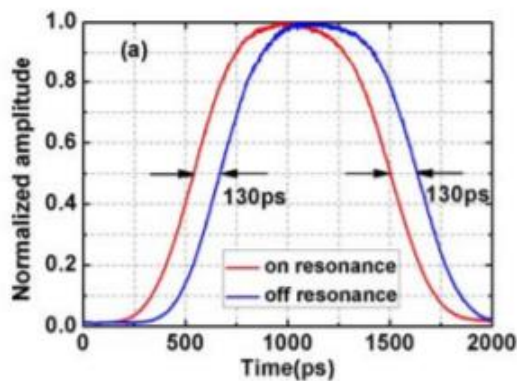
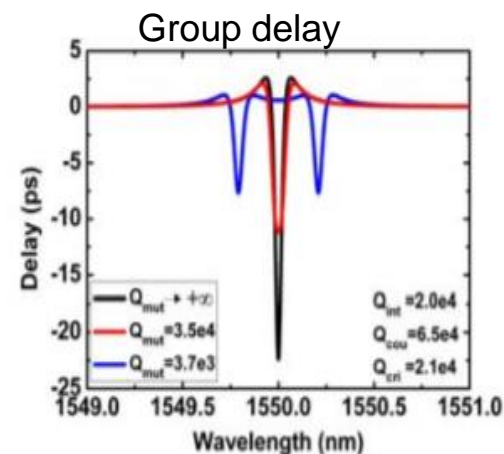
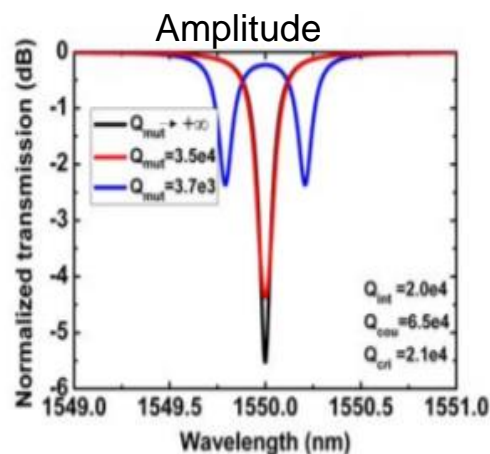
REFLECTIONS ENGINEERING – OTHERS

- Tunable fast light
- Resonance splitting \rightarrow anomalous dispersion \rightarrow pulse advancement

$$v_g = \frac{c}{n(\omega) + \omega \frac{dn(\omega)}{d\omega}} \bigg|_{\omega = \omega_c} = \frac{c}{n_g}$$

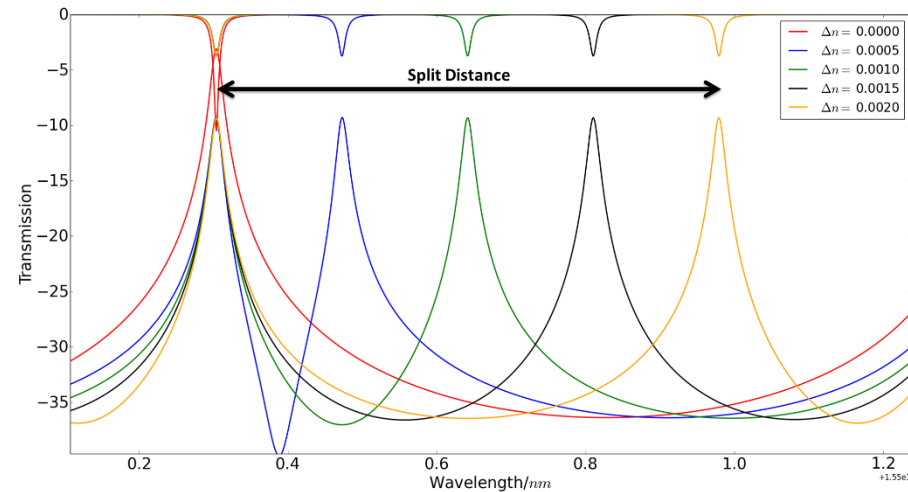
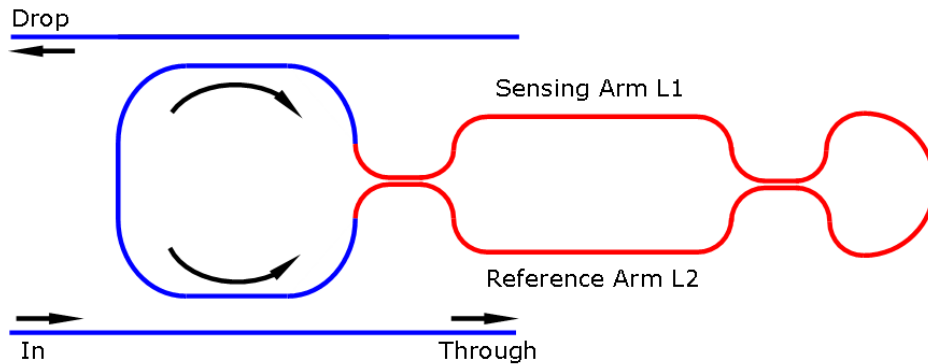


Q. Li et al., Optics express, 17(2), 2008



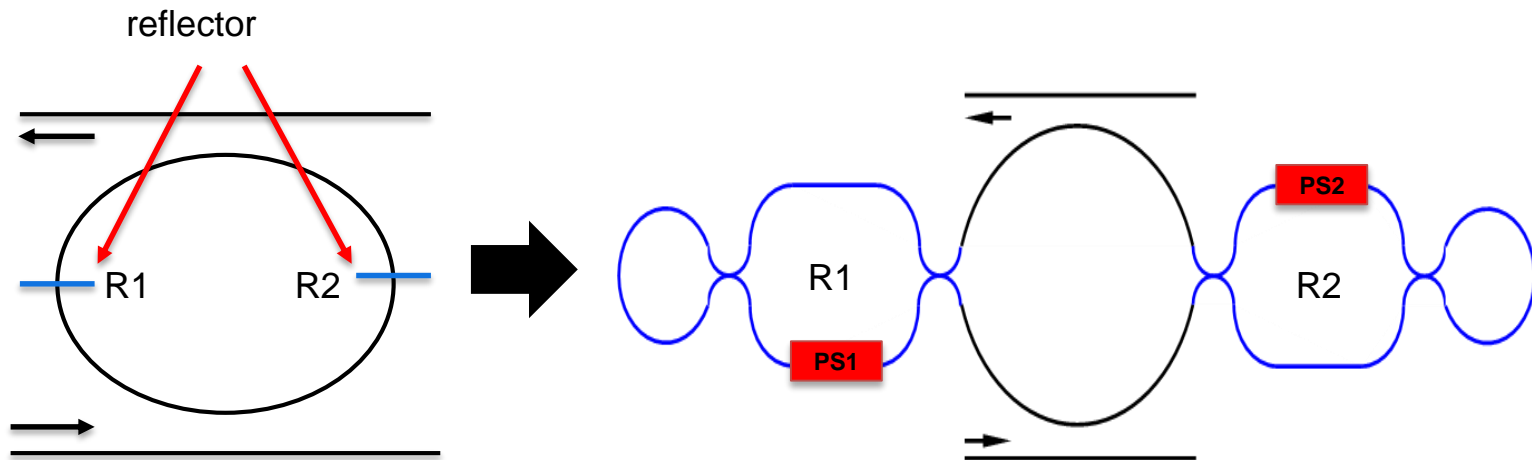
REFLECTIONS ENGINEERING – OTHERS

- Sensing scheme
- Resonance splitting \rightarrow index change
- combines the advantage of MZI sensor and ring sensor
 - Temperature insensitive
 - High resolution



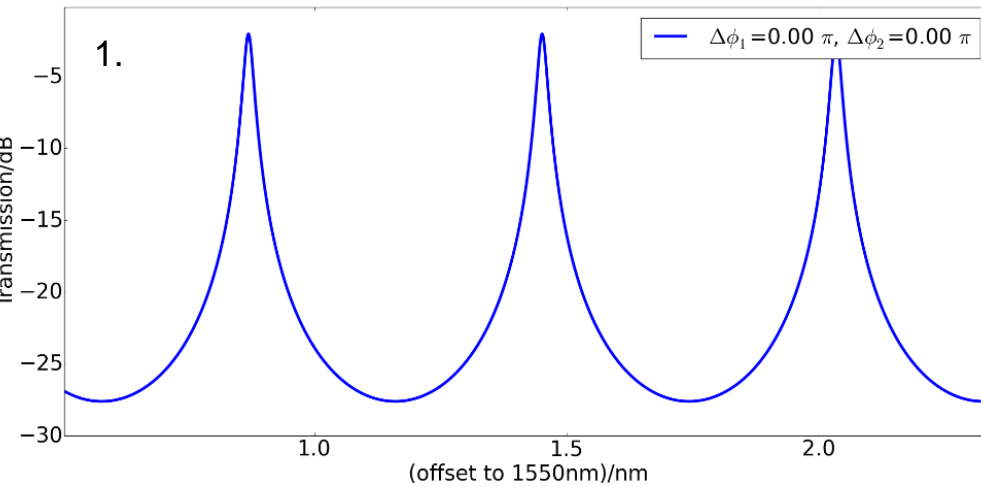
REFLECTIONS ENGINEERING – TWO REFLECTORS

- Two embedded Fabry-Perot cavities will be formed
- Output is an interference pattern of the ring and FP cavities.

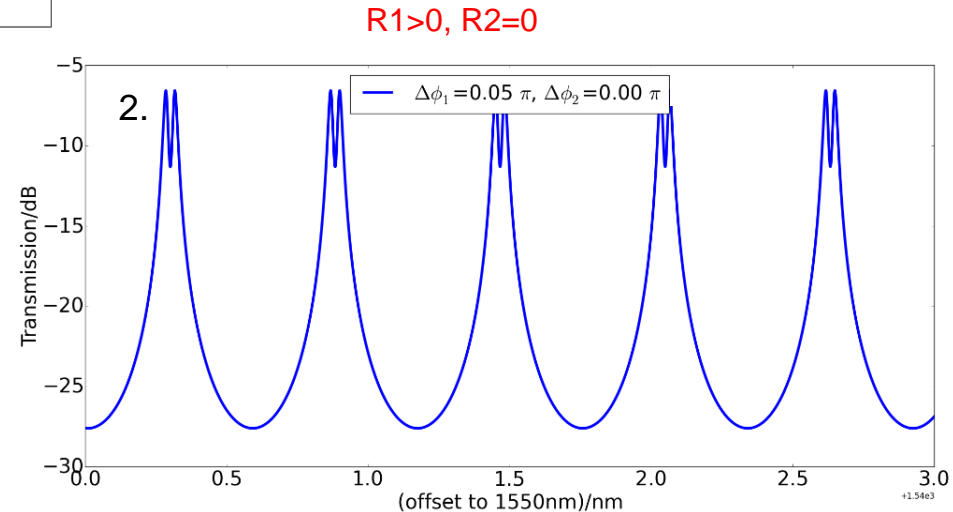


REFLECTIONS ENGINEERING – TWO REFLECTORS

- Simulation - 4 categories
 - Pure Lorentzian resonance ($R_1=R_2=0$)
 - Normal resonance splitting ($R_1>0$, $R_2=0$)

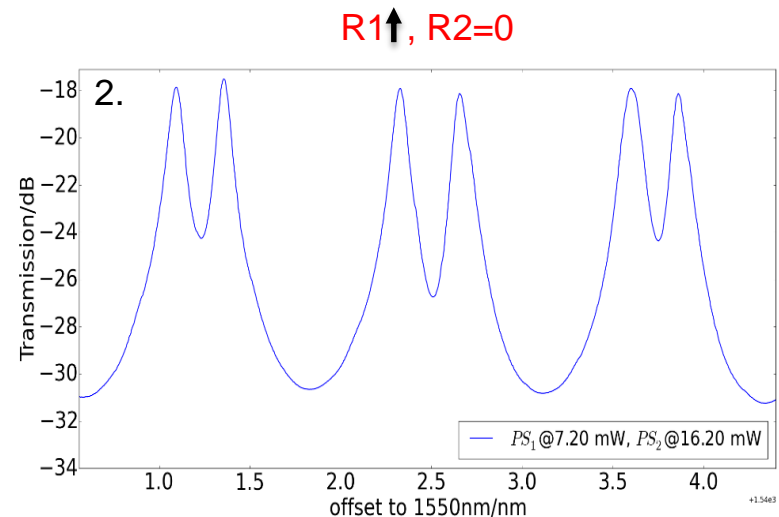
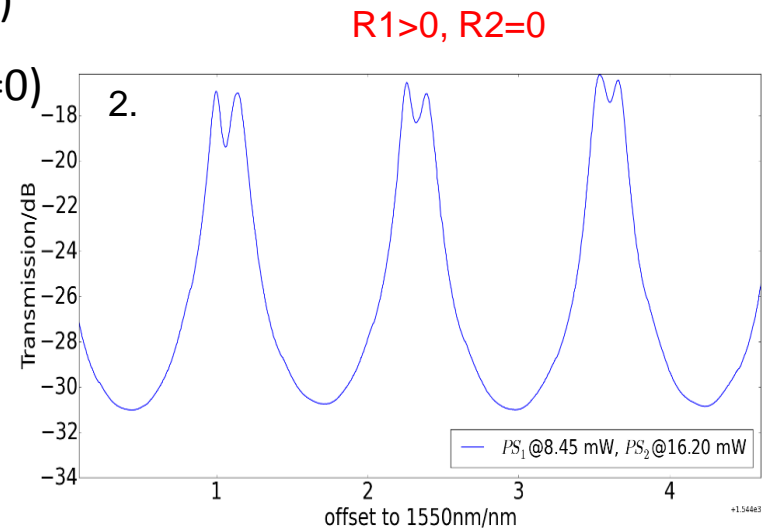
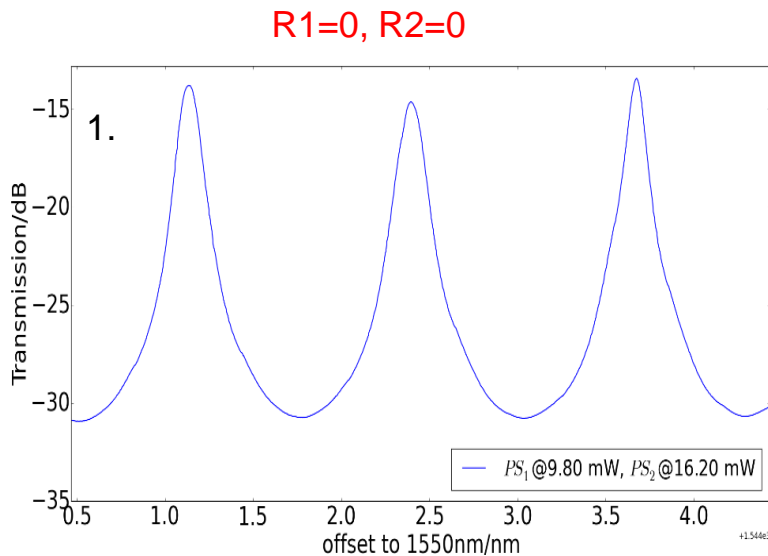


$R_1=R_2=0$



REFLECTIONS ENGINEERING – TWO REFLECTORS

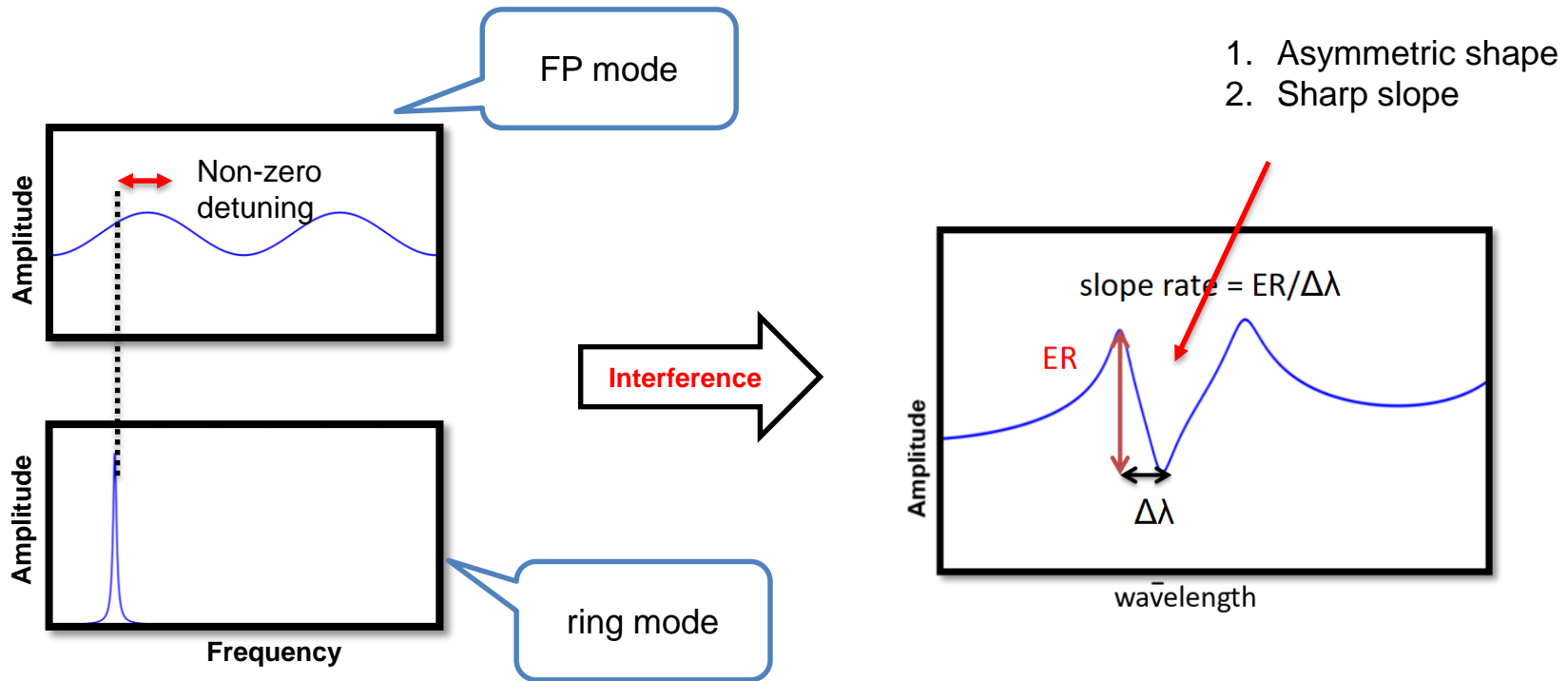
- Measurement
 1. Pure Lorentzian resonance ($R_1=R_2=0$)
 2. Normal resonance splitting ($R_1>0, R_2=0$)



REFLECTIONS ENGINEERING – TWO REFLECTORS

3. Fano resonance ($R1 > 0$, $R2 > 0$) -- Principle

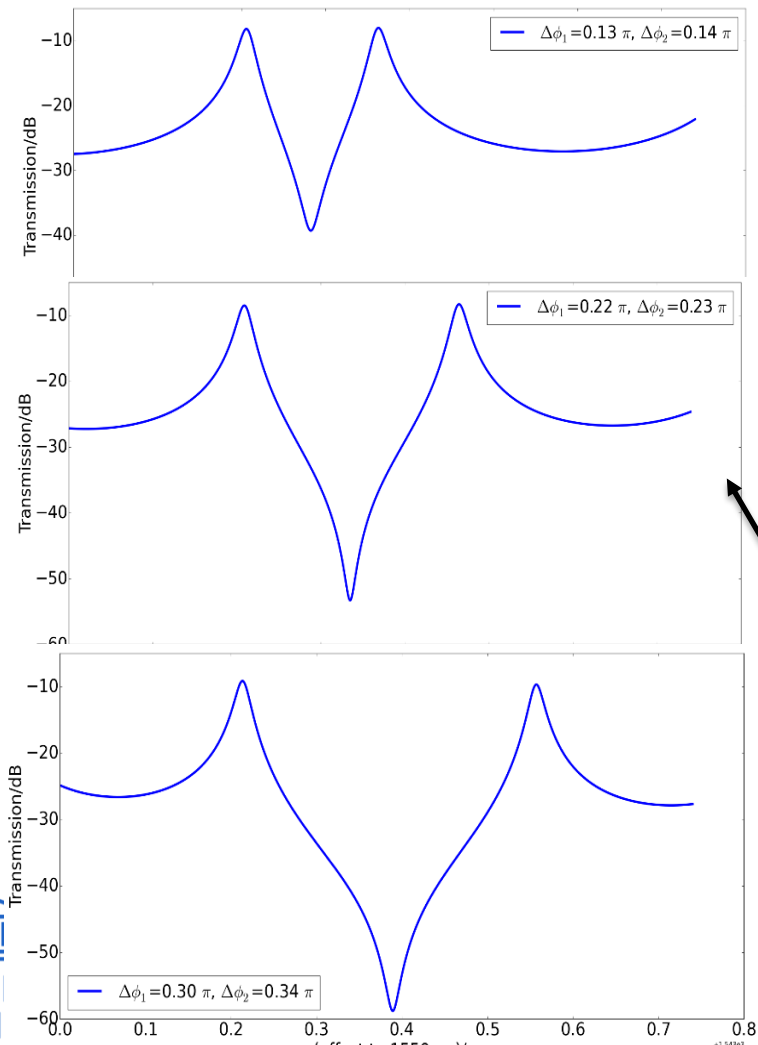
- Principle: Interference between a continuous mode (low Q) and a discrete mode (high Q) with non-zero detuning



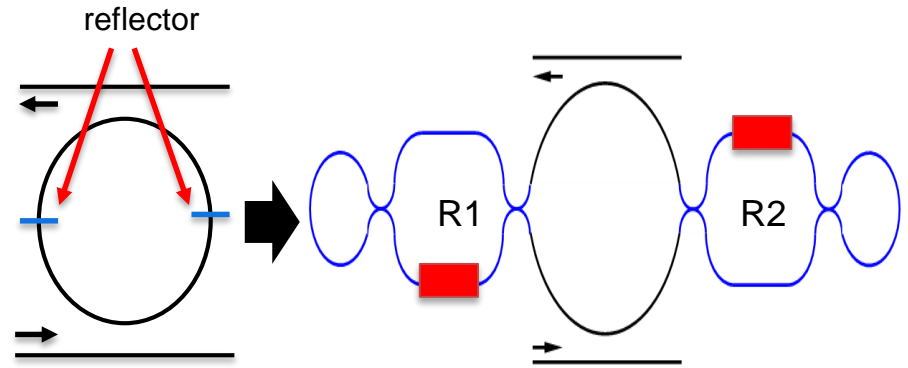
REFLECTIONS ENGINEERING – TWO REFLECTORS

3. Fano resonance – simulation

- Dynamic tuning

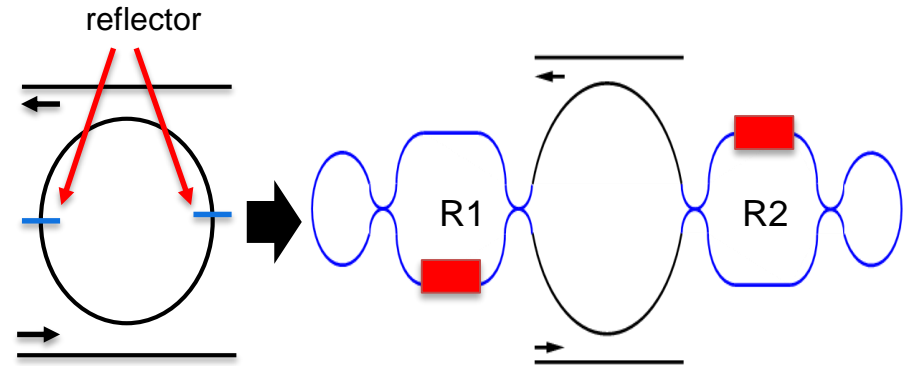
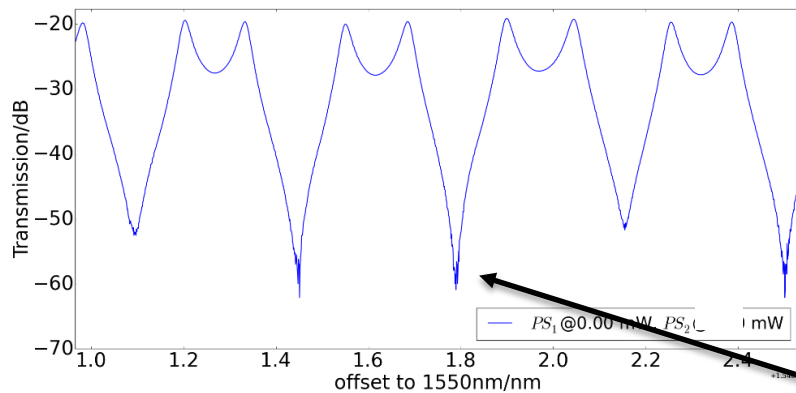
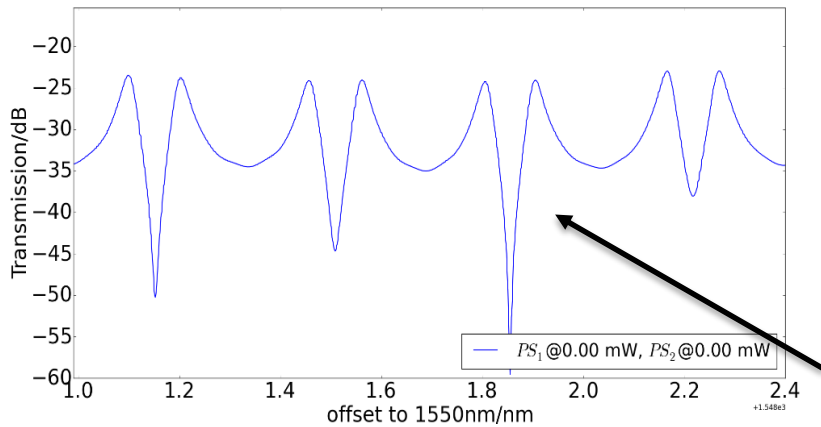


Tunability of Fano resonance



REFLECTIONS ENGINEERING – TWO REFLECTORS

3. Fano resonance – measurements



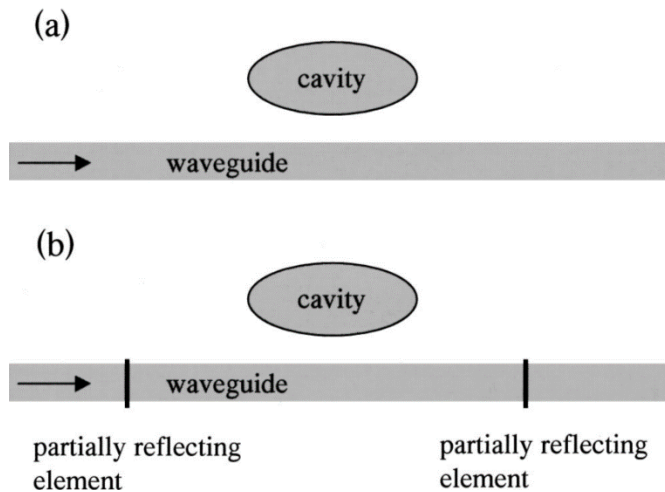
- Max. slope rate > 700dB/nm, with ER~36dB
- Slope rate of a normal silicon ring resonance ~ 60dB/nm

- Max. ER=40dB, with slope rate~400dB/nm

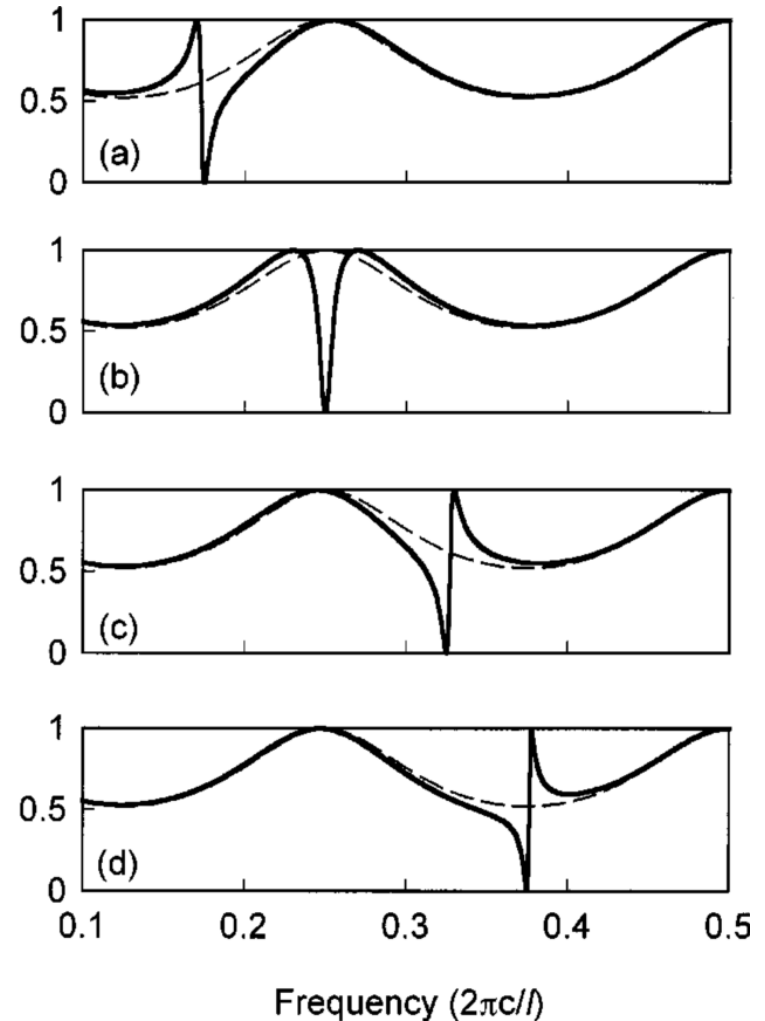
REFLECTIONS ENGINEERING – TWO REFLECTORS

3. Fano resonance – other approaches

- Standing wave cavity + travelling wave cavity



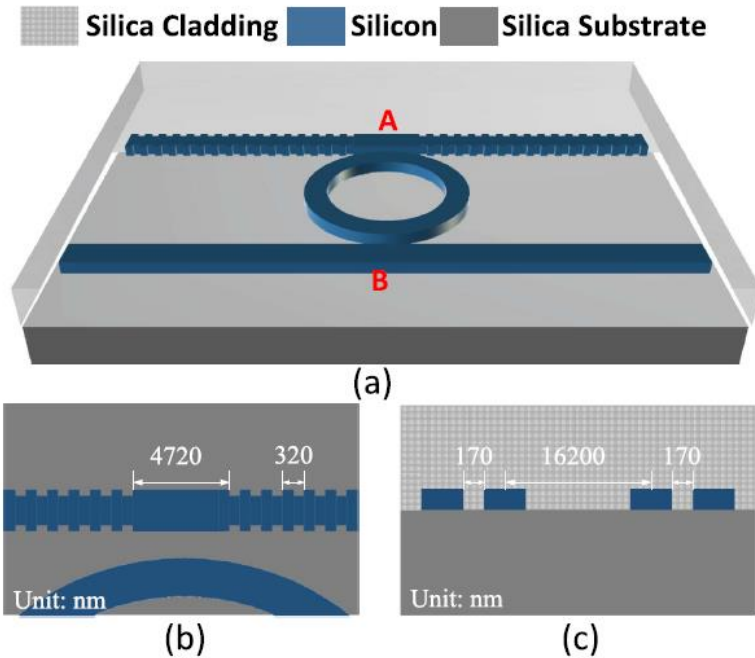
S. Fan et al., APL 80 (6), 908-910, 2002



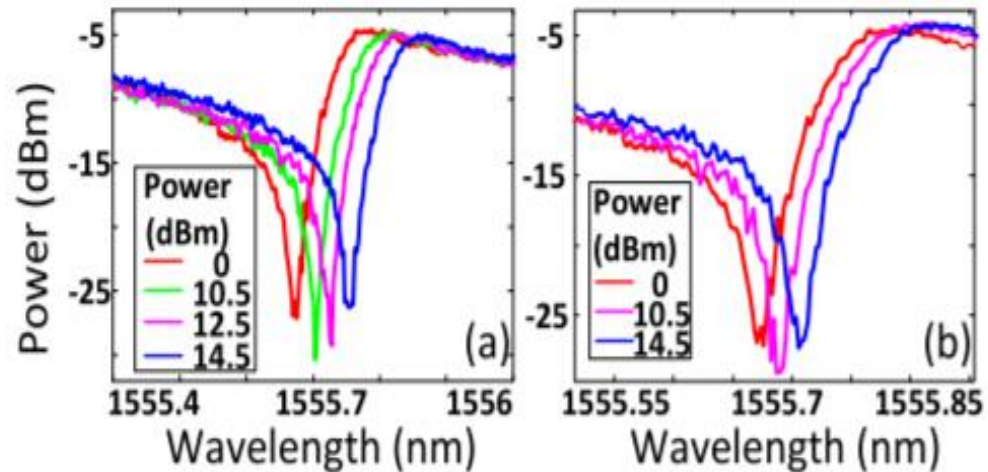
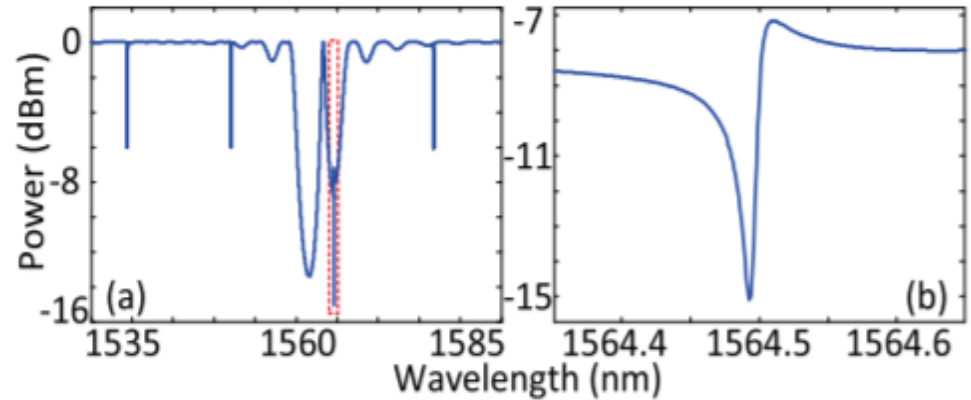
REFLECTIONS ENGINEERING – TWO REFLECTORS

3. Fano resonance – other approaches

- Bragg formed FP cavity with ring cavity
 - Optical tuning
 - Low performance



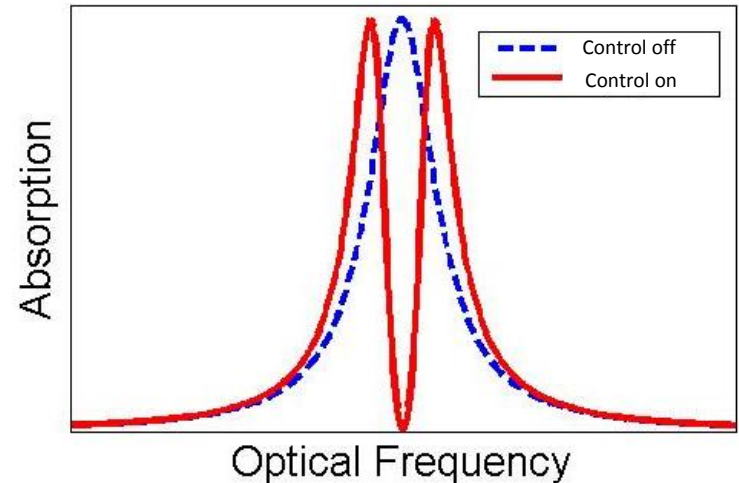
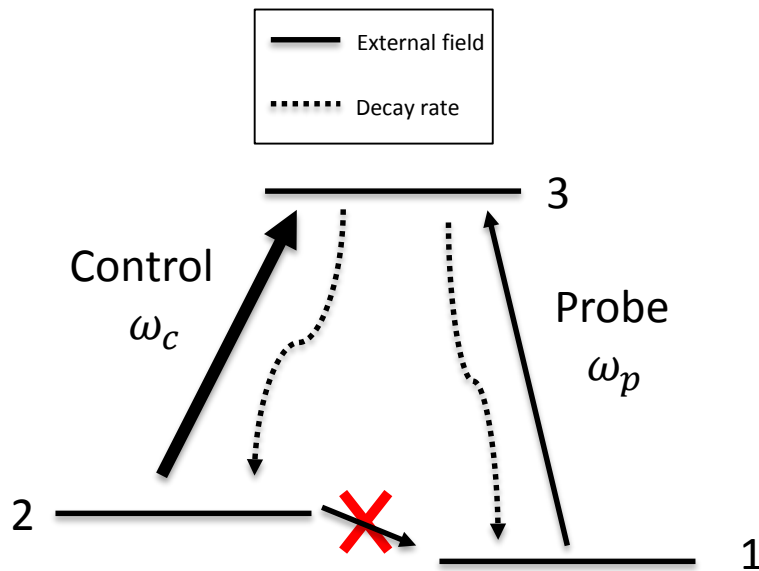
W. Zhang et al., OL Vol. 41, No. 11, 2016



REFLECTIONS ENGINEERING – TWO REFLECTORS

4. Electromagnetically induced transparency (EIT) -- Principle

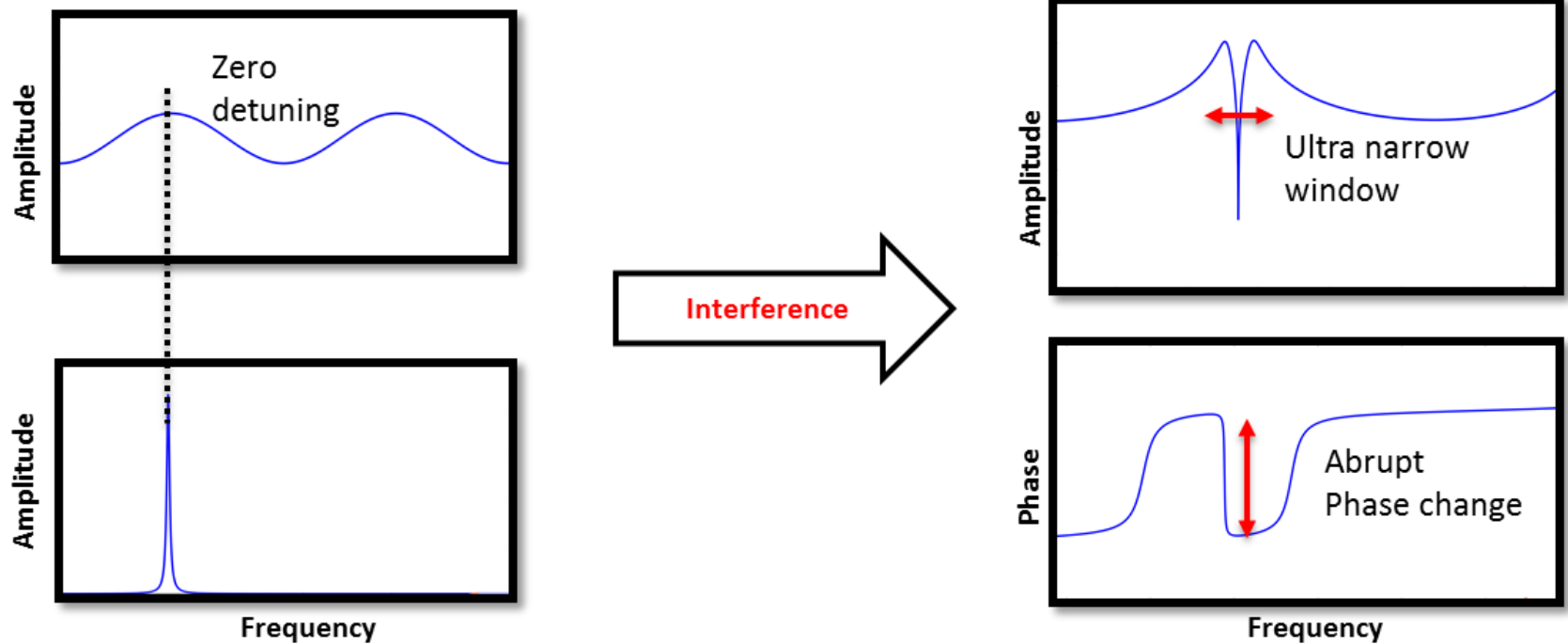
- Principle: destructive interference between two excitation pathways in an atomic systems (from 2 to 3 and from 1 to 3).
- Without control, the absorption of probe shows Lorentzian line, with control, a dip is induced.



REFLECTIONS ENGINEERING – TWO REFLECTORS

4. EIT – principle in optical field

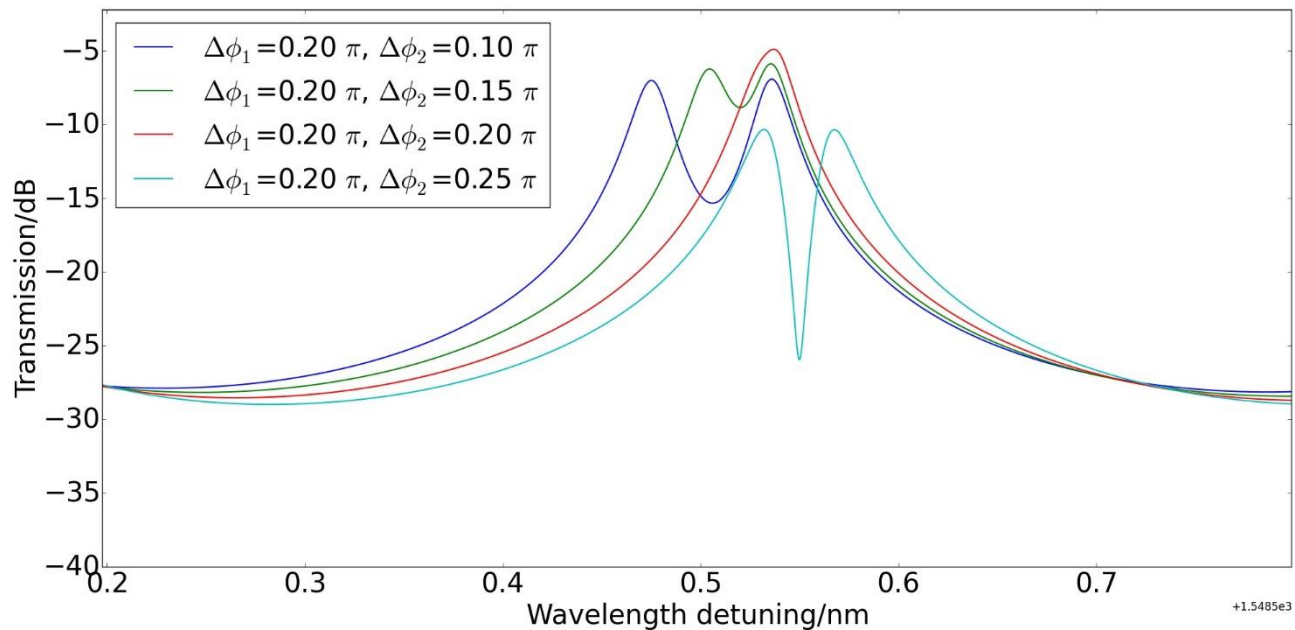
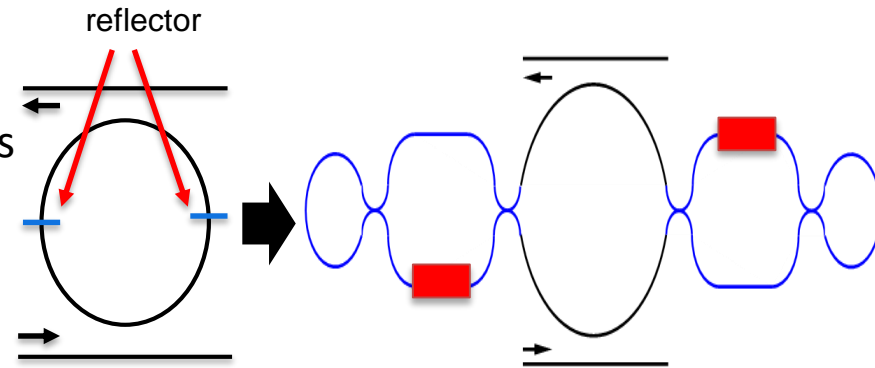
- Principle: fundamentally a Fano resonance, zero-detuning between the smooth mode and discrete mode



REFLECTIONS ENGINEERING – TWO REFLECTORS

4. EIT – simulation

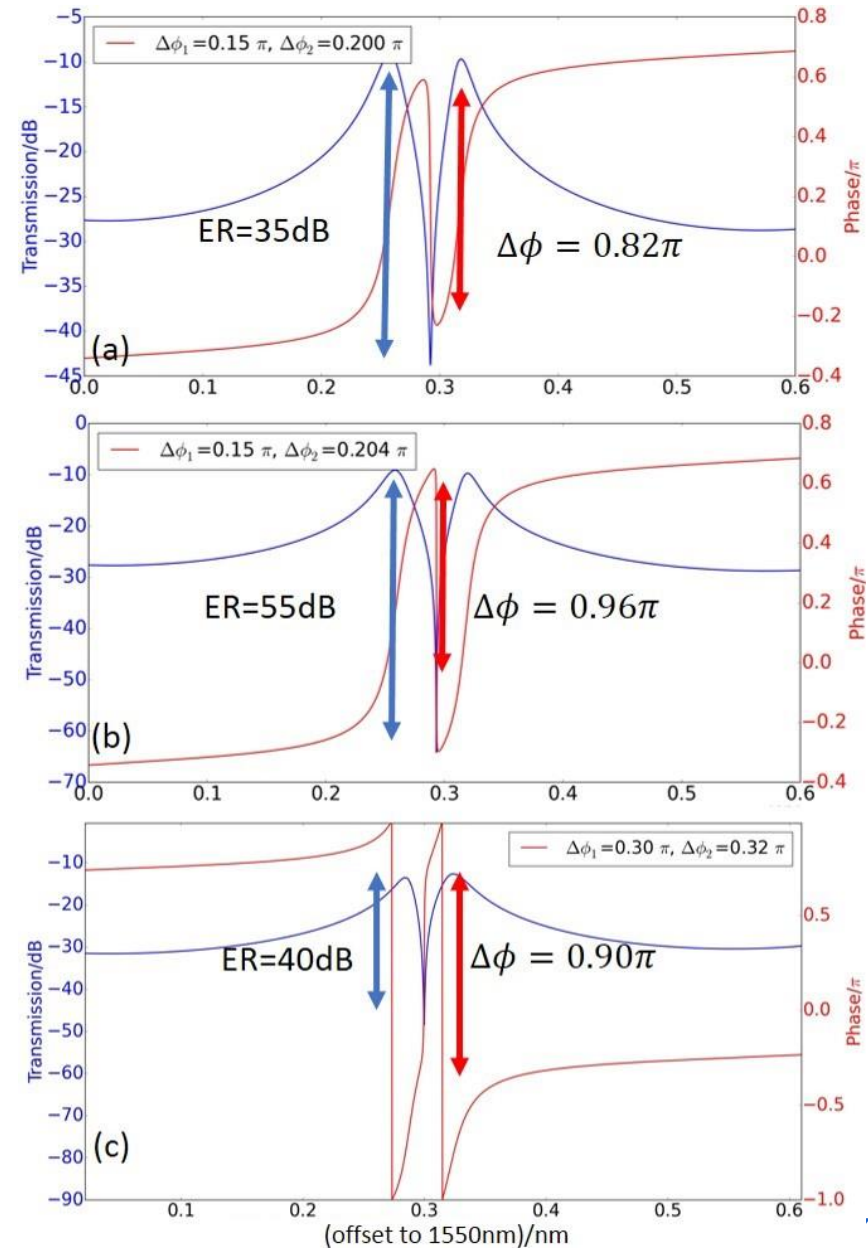
- On the basis of Fano, fine tune reflectors
- First demonstration of transition between Fano and EIT in a single device



REFLECTIONS ENGINEERING – TWO REFLECTORS

4. EIT – simulation

- Key parameters can be further tuned

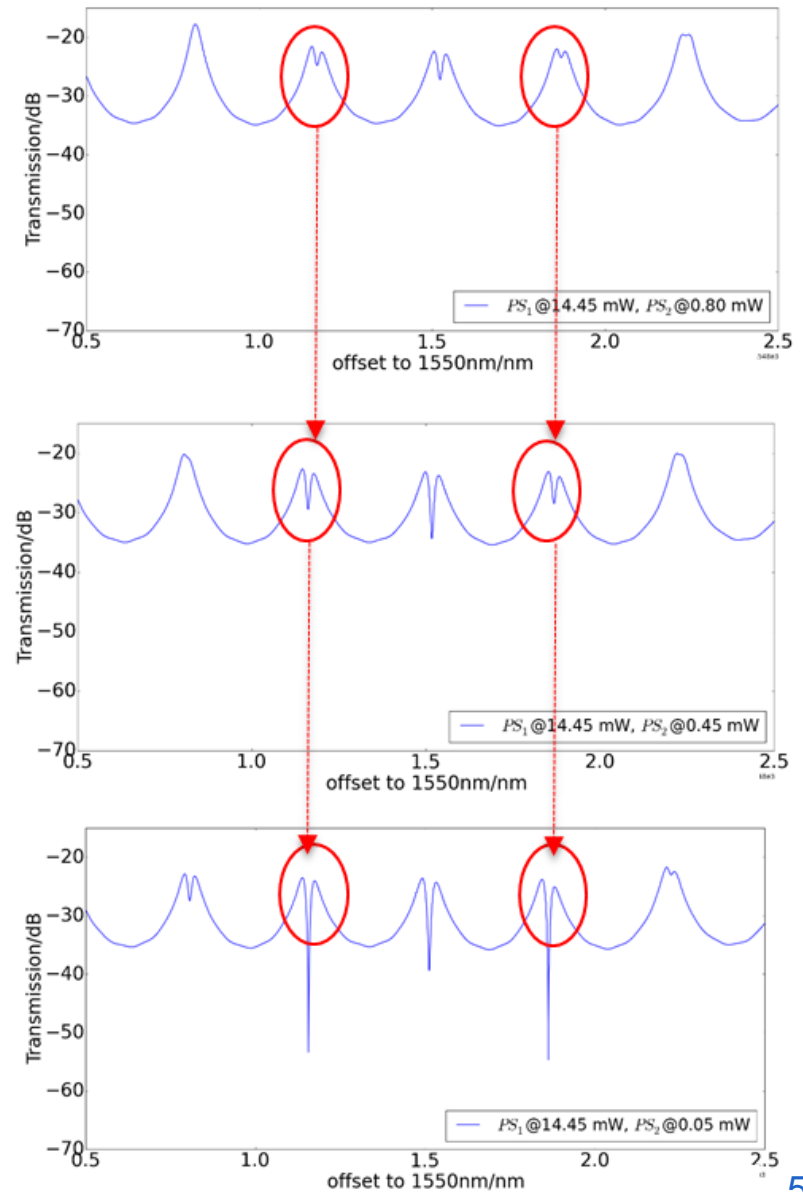
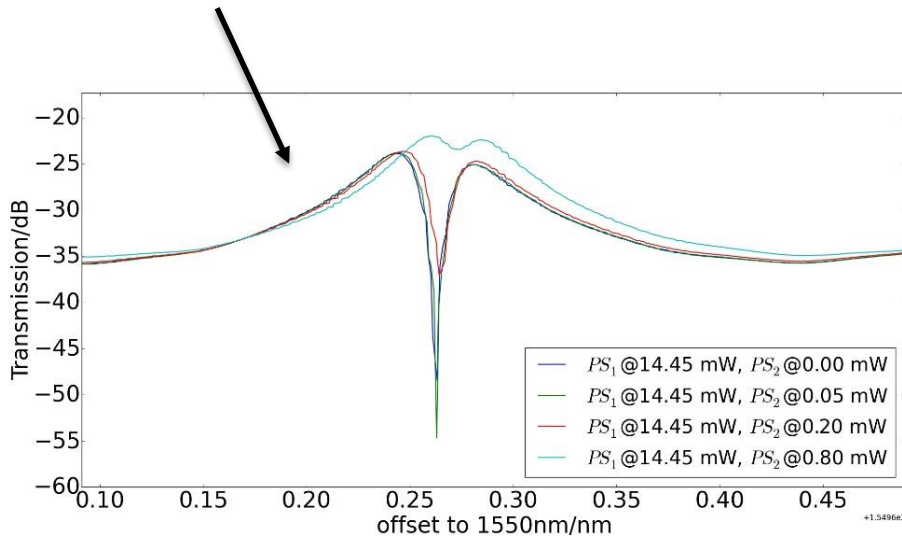


REFLECTIONS ENGINEERING – TWO REFLECTORS

4. EIT – measurements

Power only changes 0.4mW

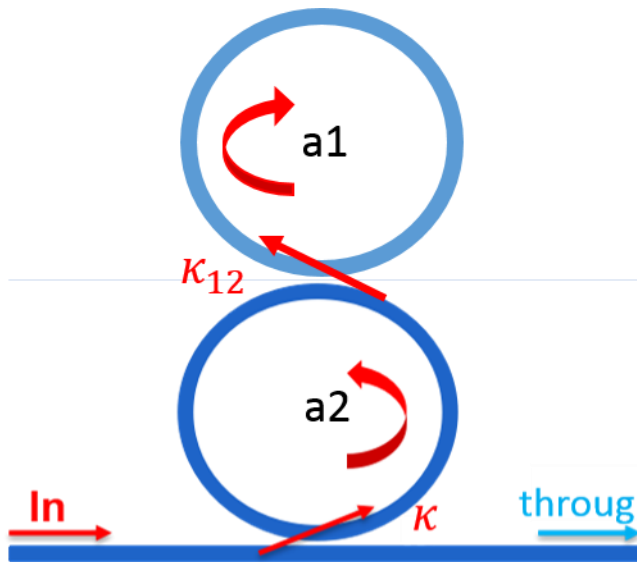
Peak evolves dramatically



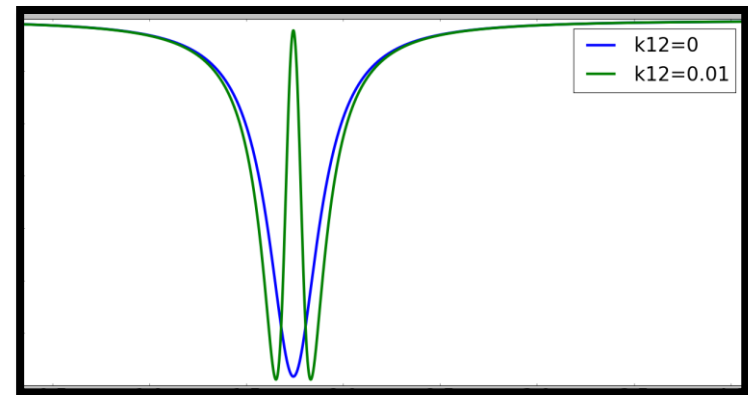
REFLECTIONS ENGINEERING – TWO REFLECTORS

4. EIT – popular approach

- Coupled ring cavities
- Hard to guarantee and tune
- Difficult to engineer loss in silicon photonics

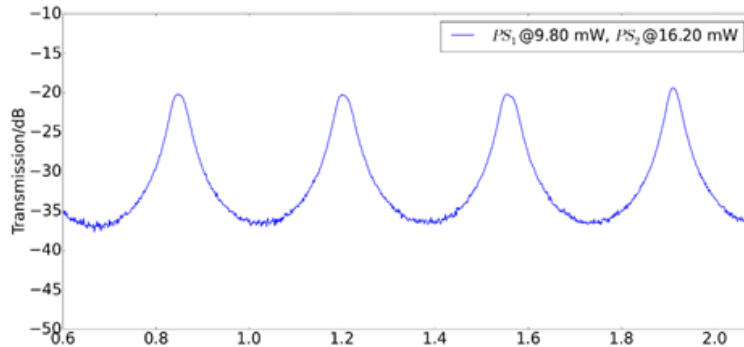


- Different Q factor
- Good alignment

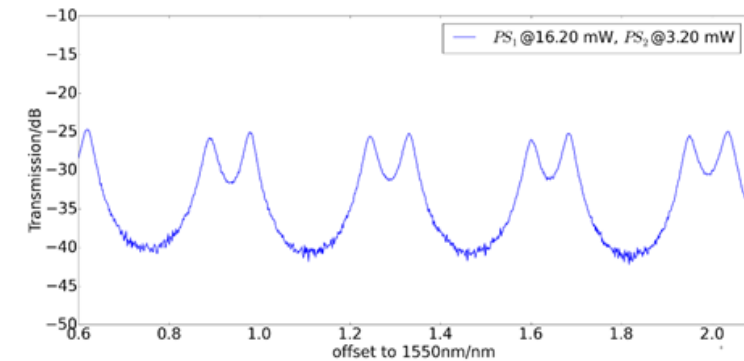
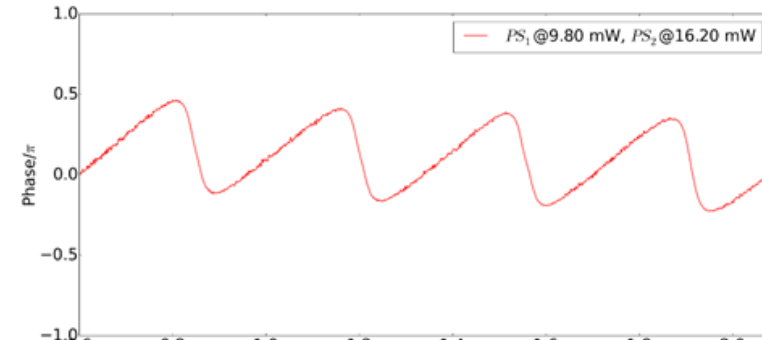


REFLECTIONS ENGINEERING – TWO REFLECTORS

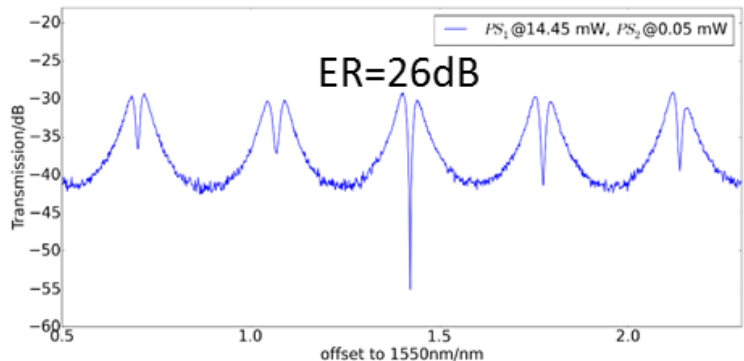
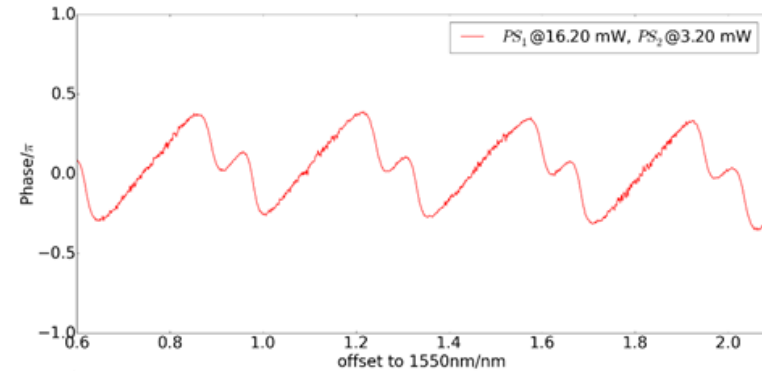
4. EIT – phase measurements



Lorentzian resonance

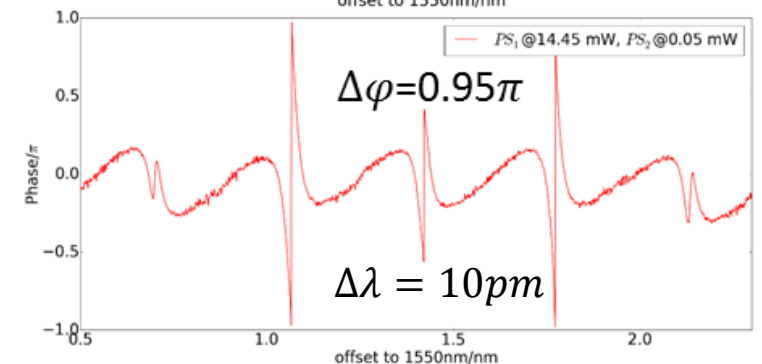


Resonance splitting



EIT

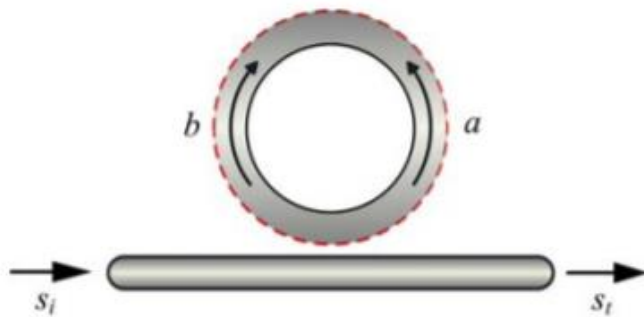
$$n_g > 300$$



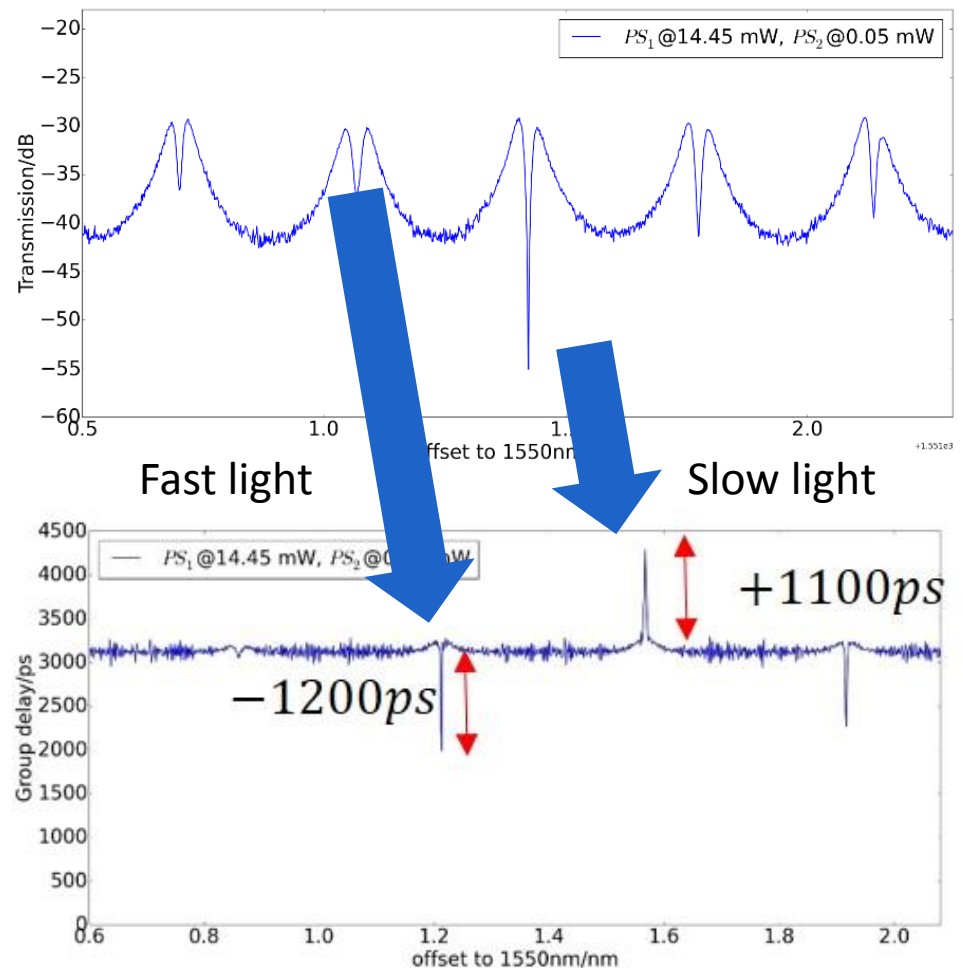
REFLECTIONS ENGINEERING – TWO REFLECTORS

4. EIT – delay measurements

- Slow light at the EIT \rightarrow 10cm silicon waveguide
- Fast light at splitting \rightarrow 10-fold improvement from [1]

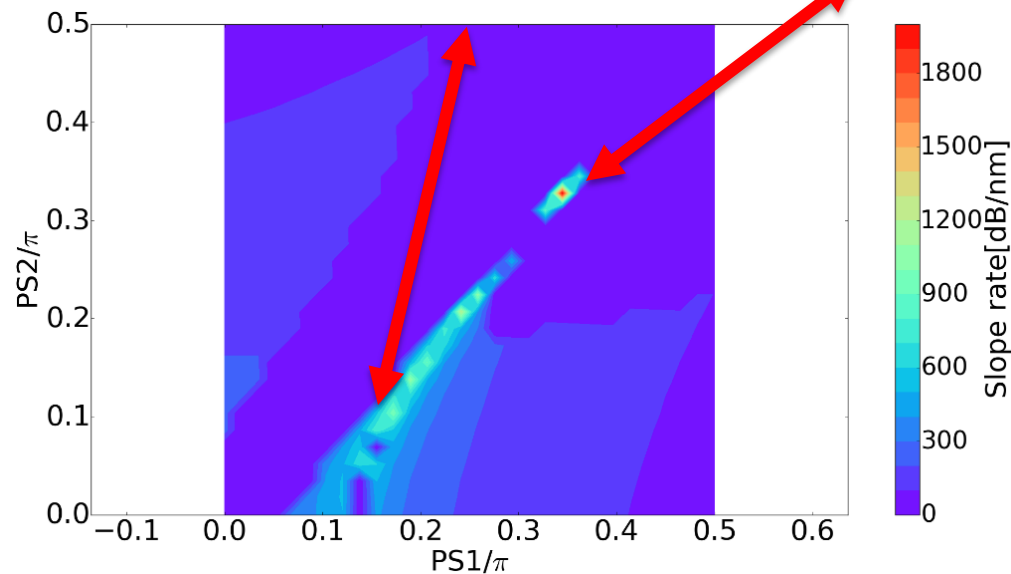
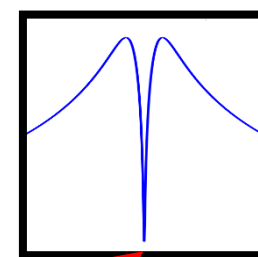
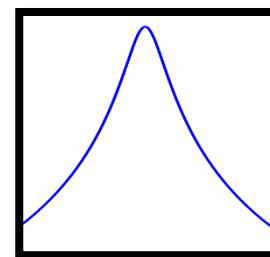
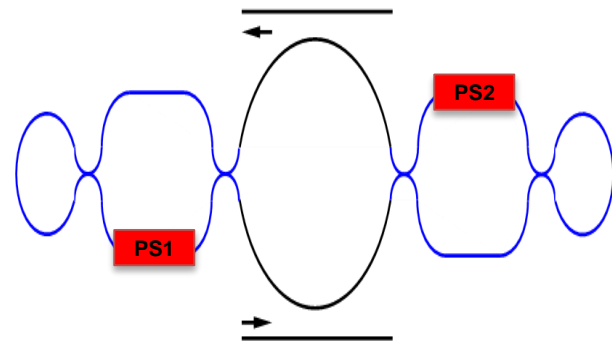
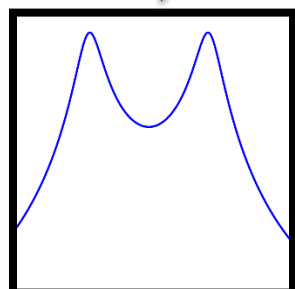
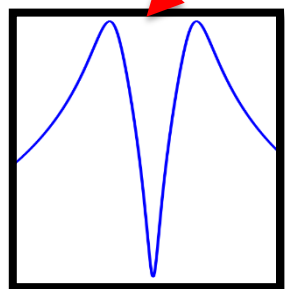
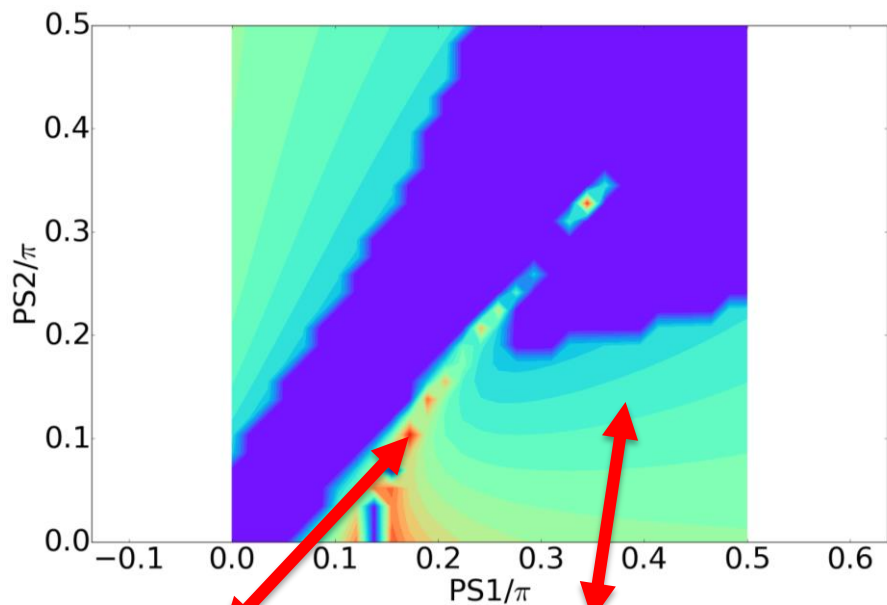


1. Q. Li et al., Optics express, 17(2), 2008



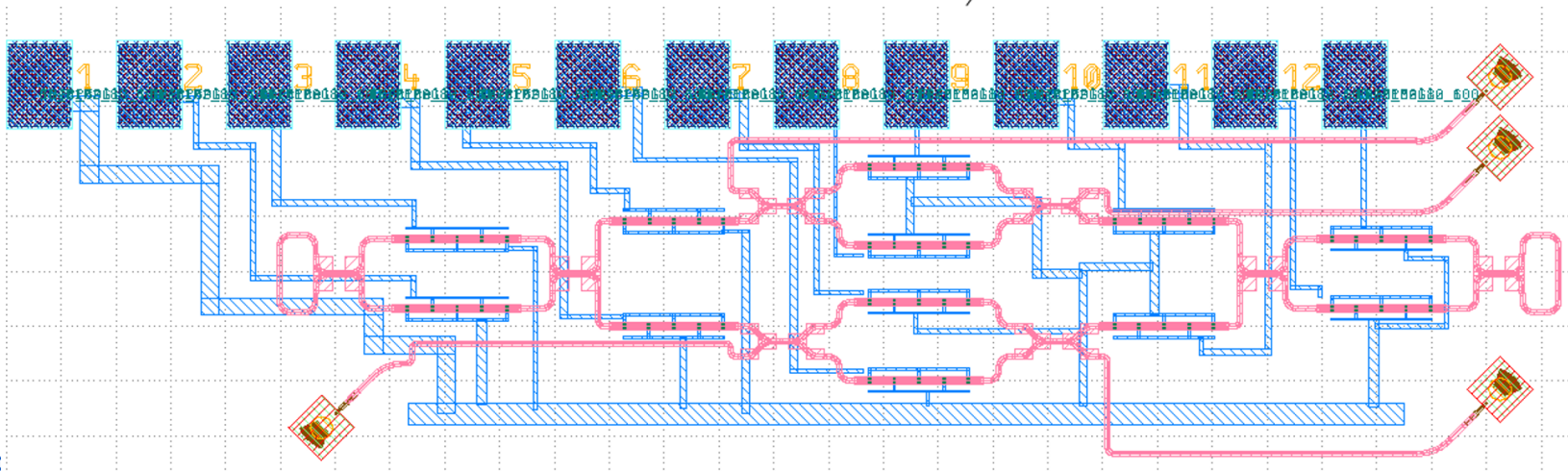
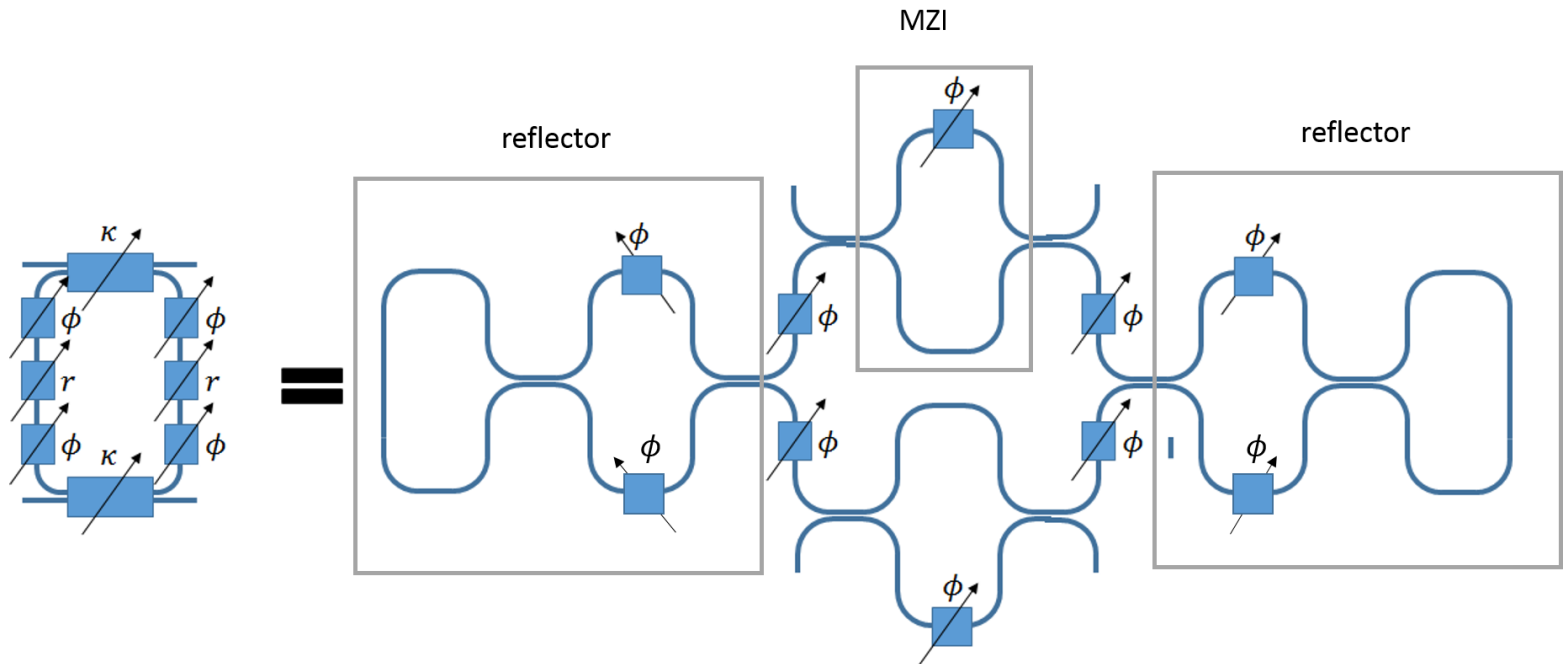
REFLECTIONS ENGINEERING – TWO REFLECTORS

4. Contour plots



GENERIC PROGRAMMABLE RING RESONATOR

- A generic ring with many degrees of freedom



CONCLUSION & OUTLOOK

Conclusion

- Photonics parasitics study
- Model for various resonance splitting of ring resonator
- Turn two unwanted, non-deterministic effects into useful degrees of freedom
 - Internal reflections
 - Backcoupling

Outlook

- Programmable ring resonator
- Nonreciprocal transmission by reflections engineering in ring resonator

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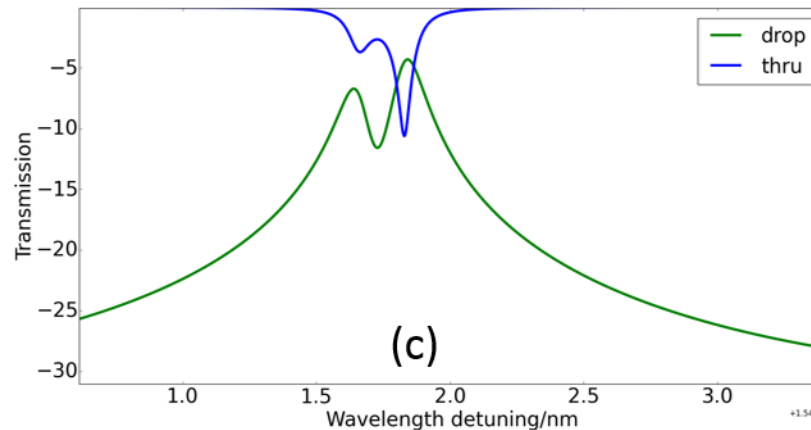
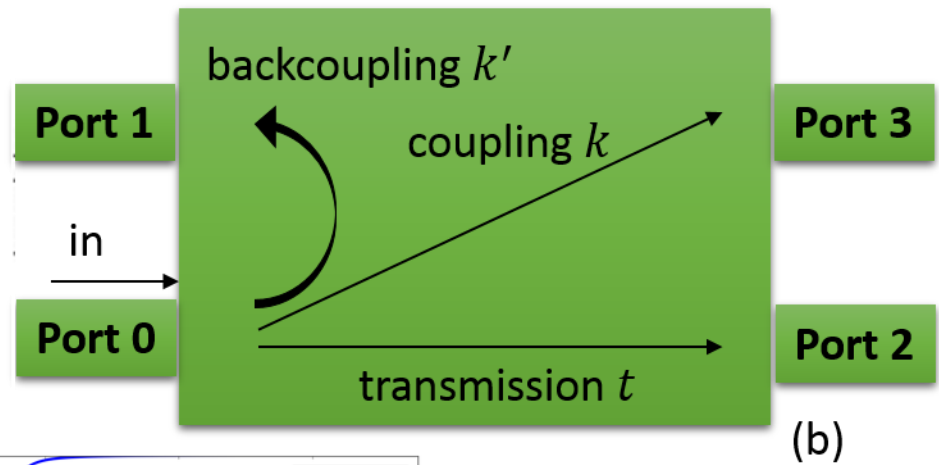
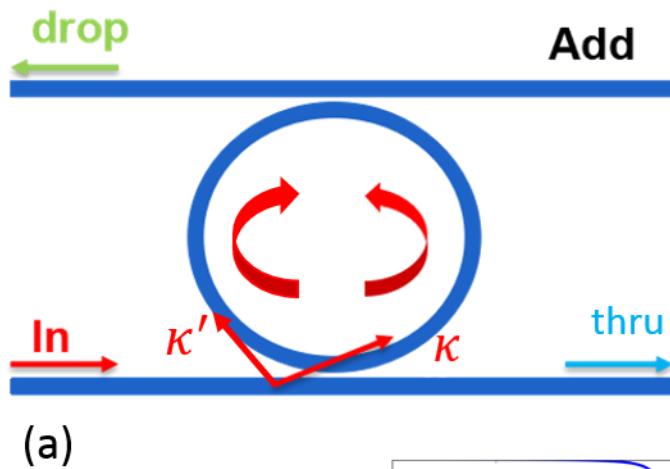


Firstname Lastname

www.photonics.intec.ugent.be

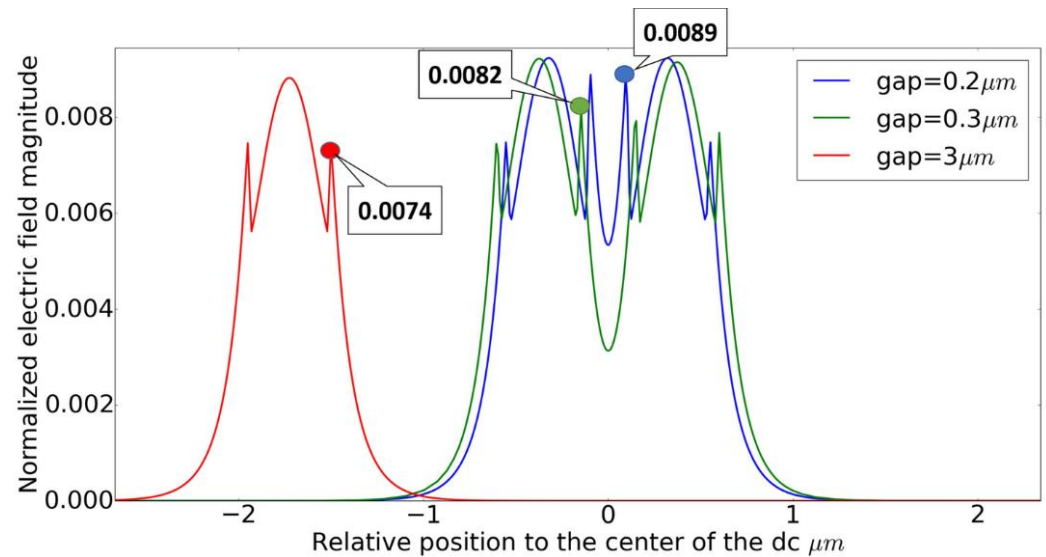
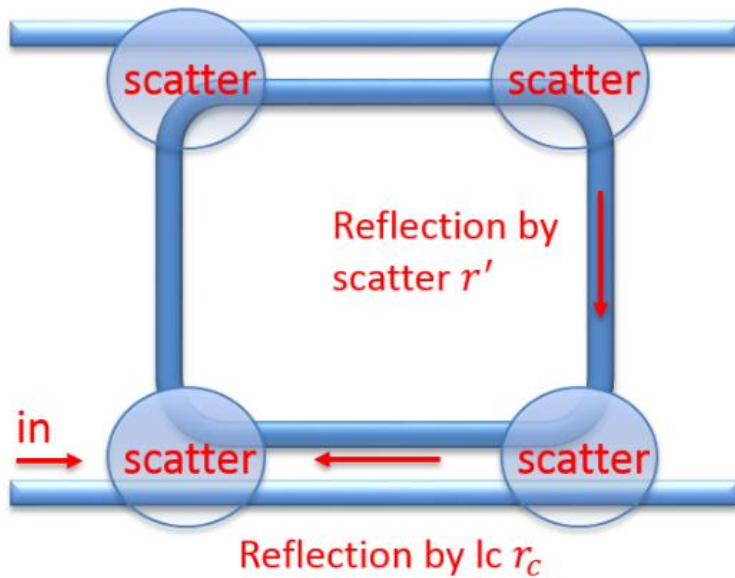
PARASITICS IN SILICON MICRORING

- Origin for asymmetric resonance splitting
 - Backcoupling at the couplers
 - Contribution from input to both modes (CW and CCW)



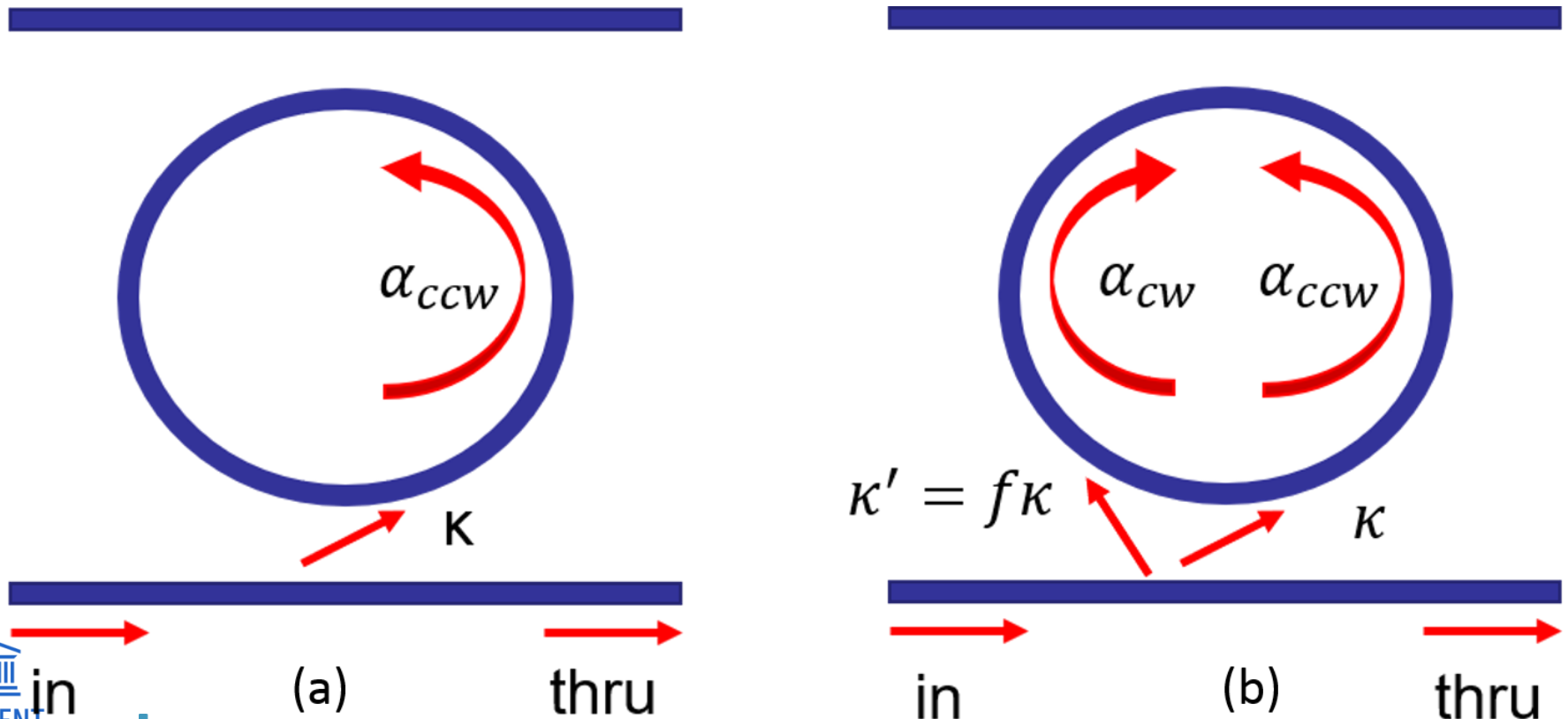
PARASITICS IN SILICON MICRORING

- Quantitative analysis
 - Couplers contribute to backscattering



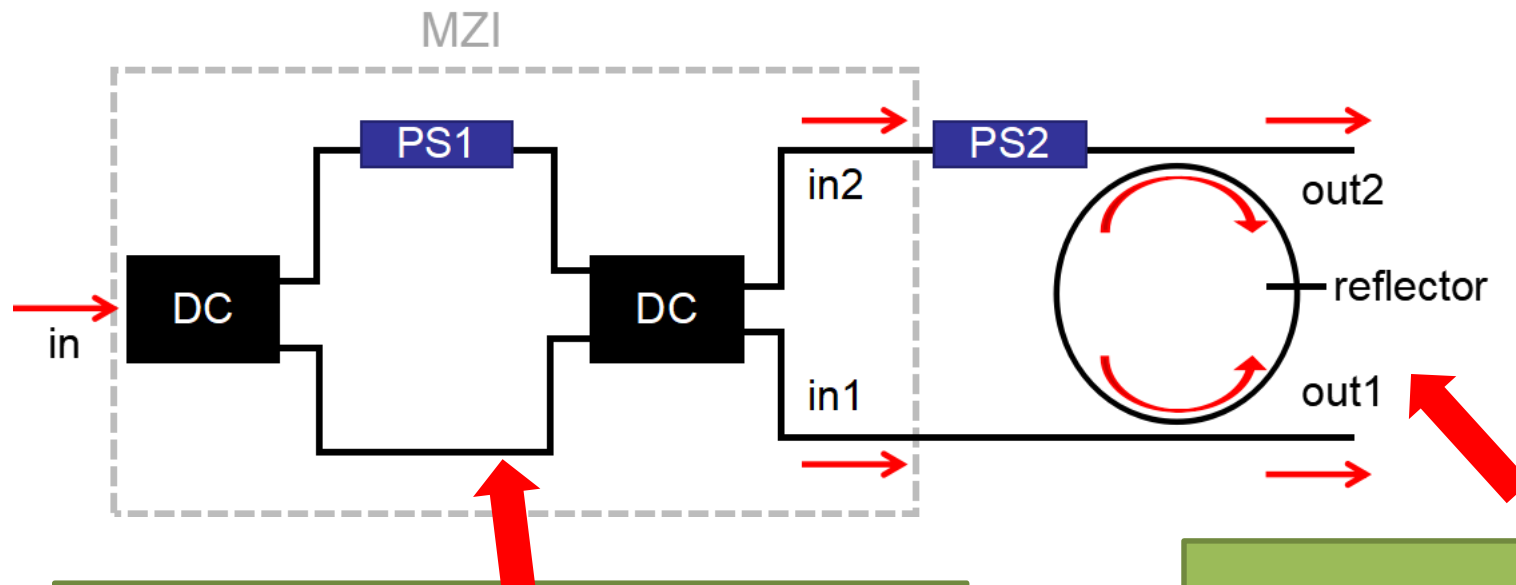
2ND DEGREE OF FREEDOM - BACKCOUPLING

- Two detrimental and non-deterministic parasitics in microrings
 - Internal reflections - affects splitting distance
 - Backcoupling - affects peak asymmetry
 - Need both to control a split resonance



2ND DEGREE OF FREEDOM - BACKCOUPLING

- Unrealistic to directly control the backcoupling of a conventional DC
- PS1 changes backcoupling/coupling ratio; PS2 changes phase contrast



- MZI splits input into two beams, each couples to one of the two modes
- Tuning the split ratio of MZI is analogous to tune the backcoupling/forward

- Two modes can be coupled through backscattering or intentional reflector

coupling